

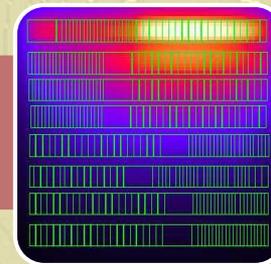
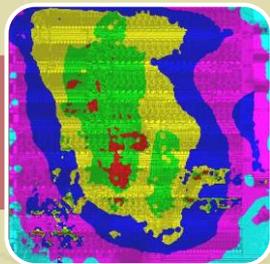
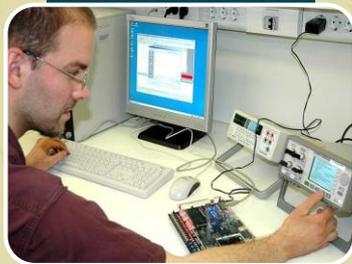
Budapest Műszaki és  
Gazdaságtudományi  
Egyetem

# Elektronikus Eszközök Tanszéke

## Minőségbiztosítás a mikroelektronikában

### Termikus tranziens tesztelés és alkalmazásai (SEMI-THERM kurzus alapján)

Dr. Poppe András



Short Course 4

# Transient Measurements to Extract Resistances and Material Properties with hands-on demonstrations

Instructors:

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MicReD unit, Budapest, Hungary

**Basic concepts:  $R_{th}$ ,  $Z_{th}$ ,  $\Psi$**

# What thermal metric and why? $R_{th}$

- A semiconductor device package can be well characterized for **steady-state operation** by its *thermal resistance*
  - The thermal resistance is a number which tells us how many degrees of junction temperature elevation is caused if a unit dissipation applied to the device
  - Power packages have large, exposed cooling tabs supporting heat-sunk thermal management solutions: thermal resistance as a metric is not problematic
    - There is a major, *dominant heat-flow path* from the junction to this cooling surface, resulting in an *essentially 1D* heat-flow
    - The *junction-to-case* thermal resistance ( $R_{thJC}$  or  $\Theta_{JC}$ ) is a usual characteristic of such packages
- Thermal resistance is a thermal metric used
  - To characterize “goodness” of a package
    - Should allow fair comparison between different vendors’ products
  - Support simple system level thermal design
- Can be measured by simple tools as well as can be derived from transient measurements

# What thermal metric and why? $Z_{th}$

- For the dynamic properties, the *thermal impedance* is the right characteristic:
  - The usual representation of the thermal impedance is the *junction temperature transient* obtained a response to a unit-height power step at the junction
  - The thermal impedance carries *all information about the heat-flow path* such as
    - **thermal capacitance/resistance distribution** along the heat-flow path
      - Through this structural analysis is possible such as detection die attach problems and/or delamination/degradation of other thermal interfaces
    - effective thermal impedance in dynamic mode of device operation
      - PWM dimmed DC LEDs, AC driven LEDs, switching mode circuits (IGBTs)
- The thermal impedance is a unique characteristic of a package but can be represented in different forms
  - Conventional  $Z_{th}(t)$  diagrams
  - Structure functions
  - Dynamic (transient) compact thermal network models
  - Complex locus in frequency domain
  - Pulsed thermal resistance diagrams
- Thermal resistance is derived from thermal impedance; both require the amount of physical measurement time

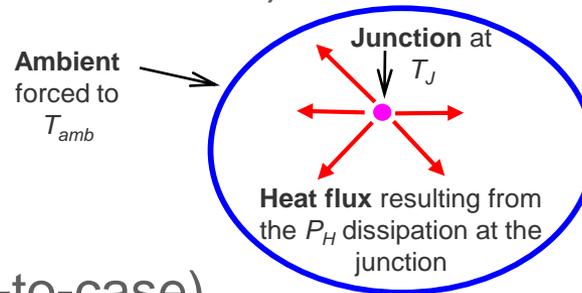
# Definition of thermal resistance?

**Required conditions** to be able to define  $R_{th}$  between two points in space:

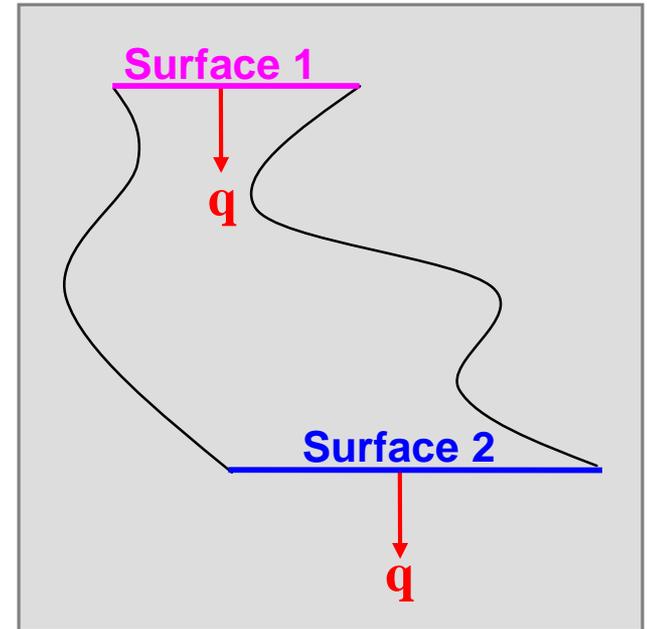
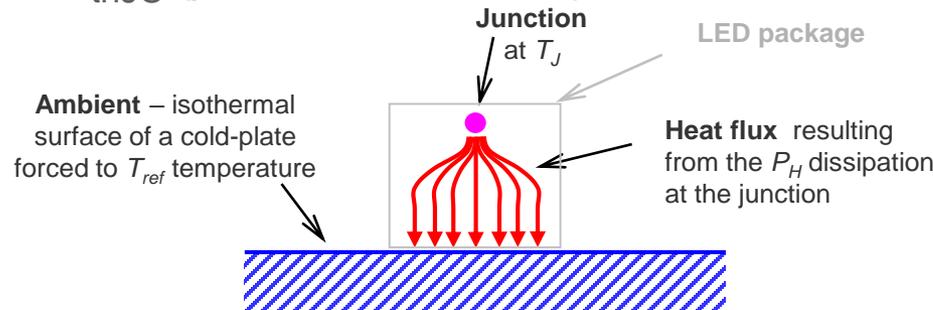
1. surfaces must be isothermal
2. the entire heat-flux  $q$  entering the heat-flow path at **Surface 1** must leave at **Surface 2**

■ Real life situations: the above conditions are well met:

—  $R_{thJA}$  (junction-to-ambient)



—  $R_{thJC}$  (junction-to-case)



Same conditions apply also for *driving point* thermal impedances...

# A few words about thermal resistance

- Original definition in the JEDEC JESD51-1 document

EIA/JEDEC Standard No. 51-1  
Page 3

## 2. MEASUREMENT BASICS

The thermal resistance of a semiconductor device is generally defined as:

$$R_{JX} = \frac{T_J - T_X}{P_H}$$

where  $R_{JX}$  = thermal resistance from device junction to the specific environment (alternative symbol is  $\theta_{JX}$ ) [ $^{\circ}\text{C}/\text{W}$ ]  
 $T_J$  = device junction temperature in the steady state test condition [ $^{\circ}\text{C}$ ]  
 $T_X$  = reference temperature for the specific environment [ $^{\circ}\text{C}$ ]  
 $P_H$  = power dissipated in the device [W]

- Classically, for Si semiconductor diodes:  $R_{th} = \Delta T_J / (I_F \times V_F)$  (1a)
- For LEDs, consider the radiant flux:  $R_{th-r} = \Delta T_J / (I_F \times V_F - P_{opt})$  (1b)

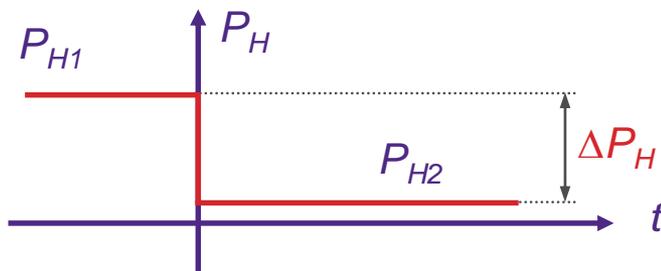
# Junction temperature – performance indicator

- Calculation:  $T_J = R_{thJ-X} \cdot P_H + T_X$  (2)
  - $R_{thJ-X}$  junction-to-reference\_X thermal resistance supplied by the LED vendor
  - $P_H$  heating power measured/calculated by the user
  - $T_X$  reference temperature (un)specified by the LED user
- Used in the design process to decide if the foreseen cooling is sufficient or not...
  - in case of LEDs, prediction of “hot lumens” is also required

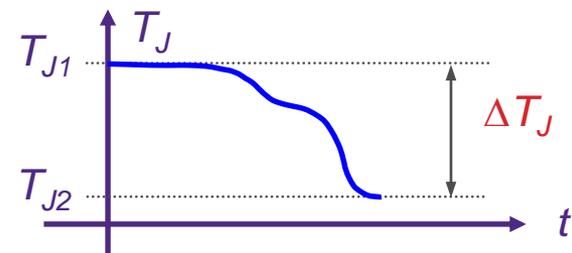
## Differential formulation of the thermal resistance

$$R_{thJ-X} = \frac{T_J - T_X}{P_H} = \frac{[\Delta T_J]_X}{P_H}$$

Instead of spatial difference (temperature values at junction and reference point) temporal difference of the junction temperature can be used

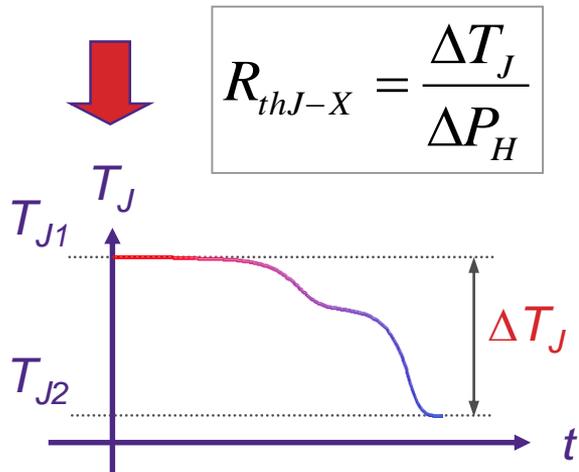
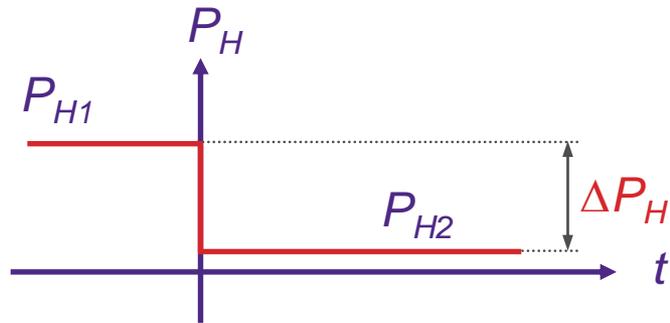


$$R_{thJ-X} = \frac{\Delta T_J(\infty)}{\Delta P_H}$$



# Differential formulation of the thermal resistance

- Alternate formulation: instead of spatial difference, we can also calculate with a **temporal difference** of the junction temperature (temp. transient):



$$R_{thJ-X} = \frac{\Delta T_J}{\Delta P_H}$$

$$T_{J1} = R_{th J-X} \cdot P_{H1} + T_X \quad (4a)$$

$$T_{J2} = R_{th J-X} \cdot P_{H2} + T_X \quad (4b)$$

$$T_{J2} - T_{J1} = R_{th J-X} \cdot (P_{H2} - P_{H1}) \quad (5)$$

Let  $T_{J1} = T_J(t_1)$  and  $T_{J2} = T_J(t_2)$ :

$$R_{th J-X} = [T_J(t_2) - T_J(t_1)] / (P_{H2} - P_{H1}) \quad (6)$$

$$R_{th J-X}(t) = \Delta T_J(t) / \Delta P_H \quad (7)$$

$$R_{th J-X}(t) = \Delta T_J(t) / \Delta P_H$$

is called **Z<sub>th</sub> curve**

If  $t_1=0$  and  $t_2=\infty \rightarrow R_{th J-X} = \Delta T_J / \Delta P_H$

If  $P_{H2} = 0$ , then  $T_{J2} = T_X$

The background features a central dark blue gradient. At the top, there is a green-to-blue gradient with numerous thin, white, radial lines emanating from the center, creating a sunburst effect. A similar pattern is visible at the bottom, though in a darker blue shade.

# **The JEDEC thermal testing standards**

# Why to use standards?

- Our goals by using standards is to make sure that what we do is
  - Commonly understood by others
    - ➔ standards are publicly available by anybody
  - Is repeatable by others
    - ➔ standards can be implemented by anybody
  - Is compatible with what others do
    - ➔ if most vendors / end-users apply the same standards, results can be compared
- Measurement standards
  - Provide definitions of **terms/quantities/metrics**
  - Define **test methods and procedures**
  - Define **test environments**
  - Define **data reporting**
- Standard thermal tests reflect characteristics of test devices and conditions, not real-life applications
  - One has inherently to **simplify conditions compared to real-life**, otherwise the goals (common understanding & reproducibility) can not be guaranteed

# Standards make measurements reproducible

- Real life conditions must be simplified for standardized measurements
  - Good standards provide metrics which are close to real life conditions
  - Deviation from real-life conditions must be on the "safe" side
- Example for simplification of real life conditions

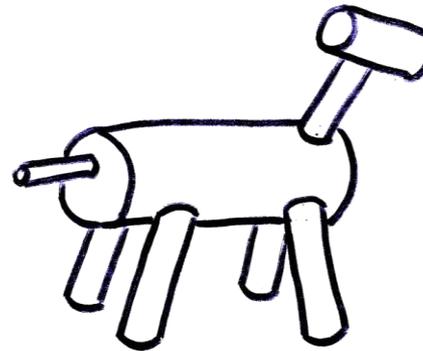
Real life horse



Too many individual, particular details

- color
- sex, muscles, teeth, etc

"Standard" horse



No individual details, but major characteristics of a real horse maintained

- has got four legs,
- has got a body, a neck, a head and a tail
- weight and form factor close to an average horse

Original standard horse example from Bruce Guenin, chairman of the JEDEC JC15 Committee on standardization of thermal characterization of packaged semiconductor devices

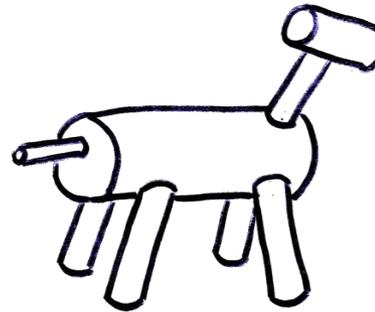
# Example from electronics cooling: power transistor

- How test conditions of power transistors can be standardized?

Real life horse



"Standard" horse



Implementation of the "Standard" horse

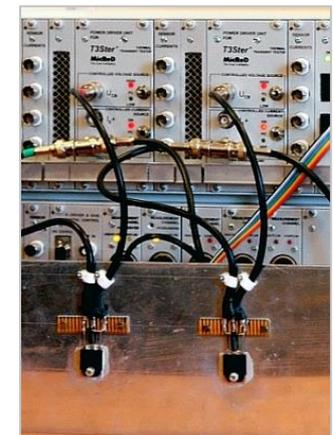
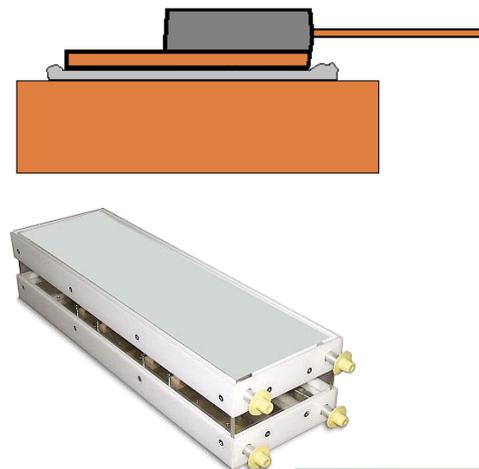
Standard features  
Additional features



Real life application environment of **power transistors**: attached to a forced air cooled heat-sink



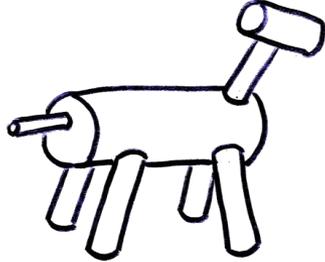
Standard test condition of **power transistors**: attached to a liquid cooled cold plate



# JEDEC thermal characterization standards

## ■ Classical standards: JESD51- series of documents

"JEDEC standard" horse

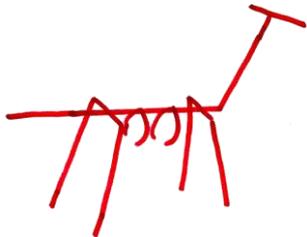


"**JEDEC standard STATIC horse**": JESD51-\* series (1,2,3,4, etc) provide

- terms and definitions
- basic test methods (electrical test methods: static / dynamic)
- test environments (natural convection, forced air) and test boards
- data reporting guidelines

JESD51 – overview document

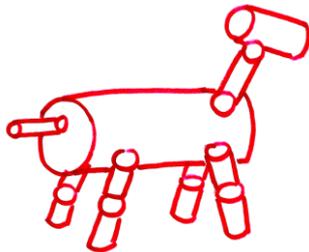
## ■ Some “new” JEDEC thermal standards:



"**JEDEC standard horse models**": JESD15-\* series for thermal compact modeling of packages

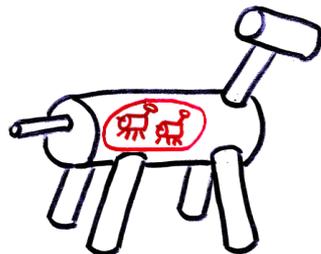
- compact modeling overview
- 2R and DELPHI models

Work on standard model library file format in progress



"**JEDEC standard DYNAMIC horse**": JESD51-14 – the first thermal transient testing standard using structure functions

- new standard for junction-to-case thermal resistance measurement
- defines a cold plate as test environment
- defines thermal transient measurement and structure function analysis as test method



**Extension of JESD51-\* series standards to account for multi-chip packages**

- JESD51-3x documents extend definitions of **environmental conditions and test boards for multi-die packages**

# List of JEDEC thermal characterization standards

- Below we give the comprehensive list of JEDEC thermal measurement and modeling standards:

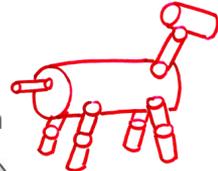


## Classical set of standards for steady-state measurements:

- JESD51 **Methodology** for the Thermal Measurement of Component Packages (Single Semiconductor Device) (1995)
- JESD51-1 Integrated Circuits Thermal Measurement Method - Electrical **Test Method** (Single Semiconductor Device) (1995)
- JESD51-2A Integrated Circuits Thermal Test Method **Environmental Conditions** - **Natural Convection** (Still Air) (2008)
- JESD51-3 Low Effective Thermal Conductivity **Test Board** for **Leaded Surface Mount Packages** (1996)
- JESD51-4 **Thermal Test Chip Guideline** (Wire Bond Type Chip) (1997)
- JESD51-5 Extension of Thermal **Test Board** Standards for Packages with Direct Thermal Attachment Mechanisms (1999)
- JESD51-6 Integrated Circuit Thermal Test Method **Environmental Conditions** - **Forced Convection** (Moving Air) (1999)
- JESD51-7 **High Effective Thermal Conductivity Test Board** for **Leaded Surface Mount Packages** (1999)
- JESD51-8 Integrated Circuit Thermal Test Method **Environmental Conditions** - **Junction-to-Board** (1999)
- JESD51-9 **Test Boards** for **Area Array Surface Mount Package** Thermal Measurements (2000)
- JESD51-10 **Test Boards** for **Through-Hole Perimeter Leaded Package** Thermal Measurements (2000)
- JESD51-11 **Test Boards** for **Through-Hole Area Array Leaded Package** Thermal Measurements (2001)
- JESD51-12 **Guidelines for Reporting** and Using Electronic Package Thermal Information (2005)
- JESD51-13 Glossary of **Thermal Measurement Terms and Definitions** (2009)

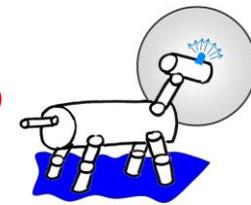
## The first transient measurement standard:

- JESD51-14 **Transient Dual Interface Test Method** for the Measurement of the Thermal Resistance Junction to Case of Semiconductor Devices with Heat Flow Through a Single Path (2010)



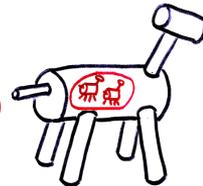
## LED thermal testing standards:

- JESD51-5x **Anew subgroup of thermal testing standards aimed at power LEDs** (2012)



## Extension of existing standards to multi-chip packages:

- JESD51-31 Thermal **Test Environment** Modifications for **Multi-Chip Packages** (2008)
- JESD51-32 Extension to JESD51 **Thermal Test Board** Standards to Accomodate **Multi-Chip Packages** (2010)



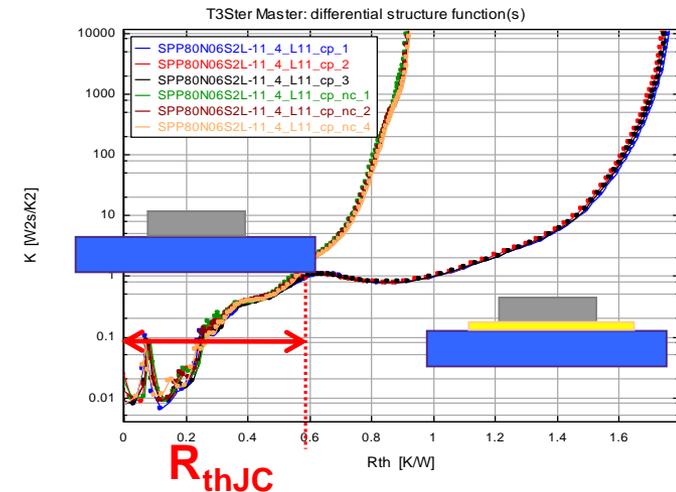
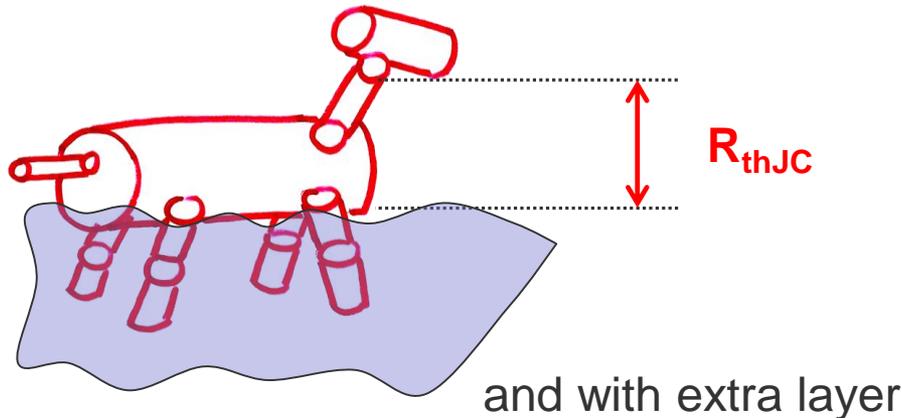
## Compact modeling guidelines:

- JESD15-1 Compact Thermal Model Overview (2008)
- JESD15-2 **Terms and Definitions** for Modeling Standards (not yet launched)
- JESD15-3 Two-Resistor Compact **Thermal Model Guideline** (2008)
- JESD15-4 DELPHI Compact **Thermal Model Guideline** (2008)



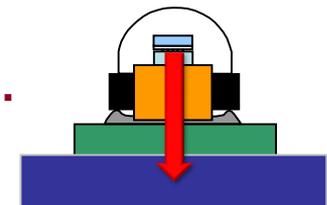
# New standard "horses" – $R_{thJC}$ with transient (2010)

- JESD51-14:  $R_{thJC}$  measurement with the dual thermal interface method
  - Measure twice: without



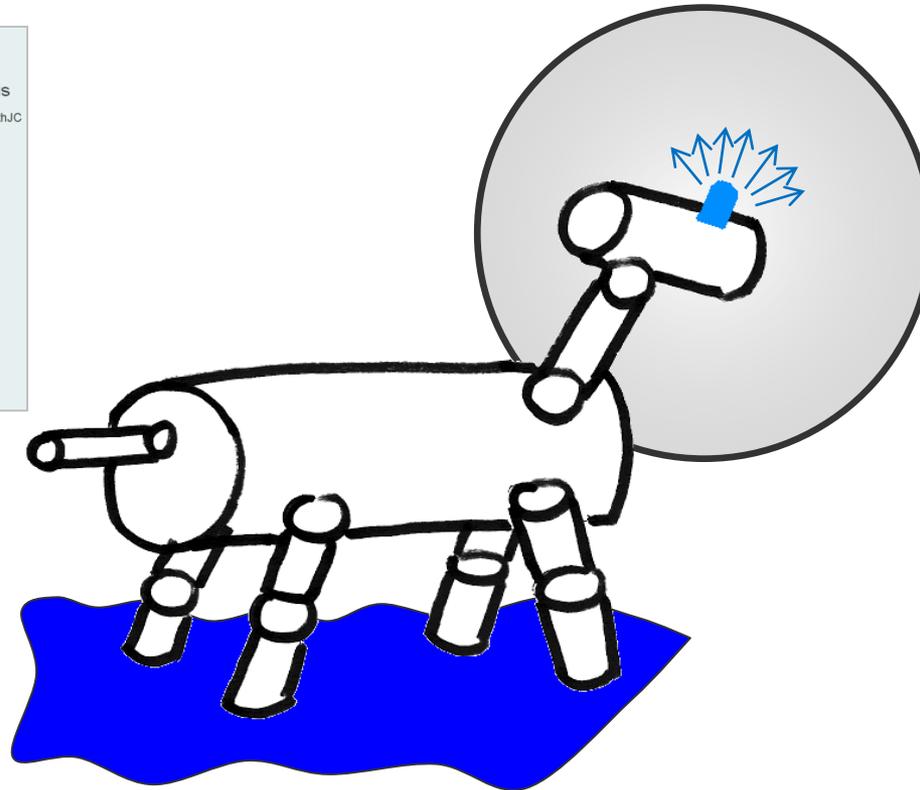
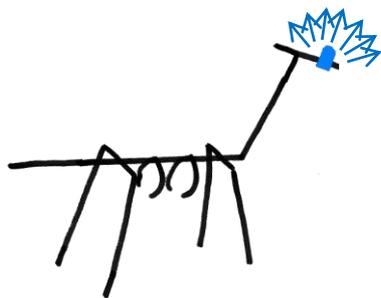
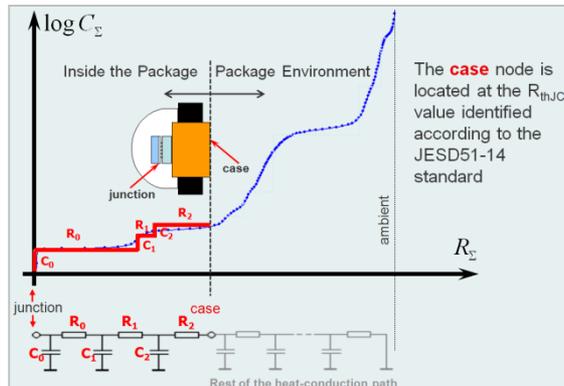
- Location of deviation with respect to the junction defines  $R_{thJC}$

- Published in November 2010
- Applicable to power semiconductor device packages with an exposed cooling surface and a single heat-flow path
- **This condition is valid power LEDs as well, thus**
- **JESD51-14 well applicable to LEDs provided that, ....**



# New standard "horses" – LED testing (2012)

- JESD51-50, 51, 52, 53 series LED thermal testing guidelines



Measure the emitted light as well to account for the actual heating  
Measure on cold-plate to assure thermal steady-state for light measurements

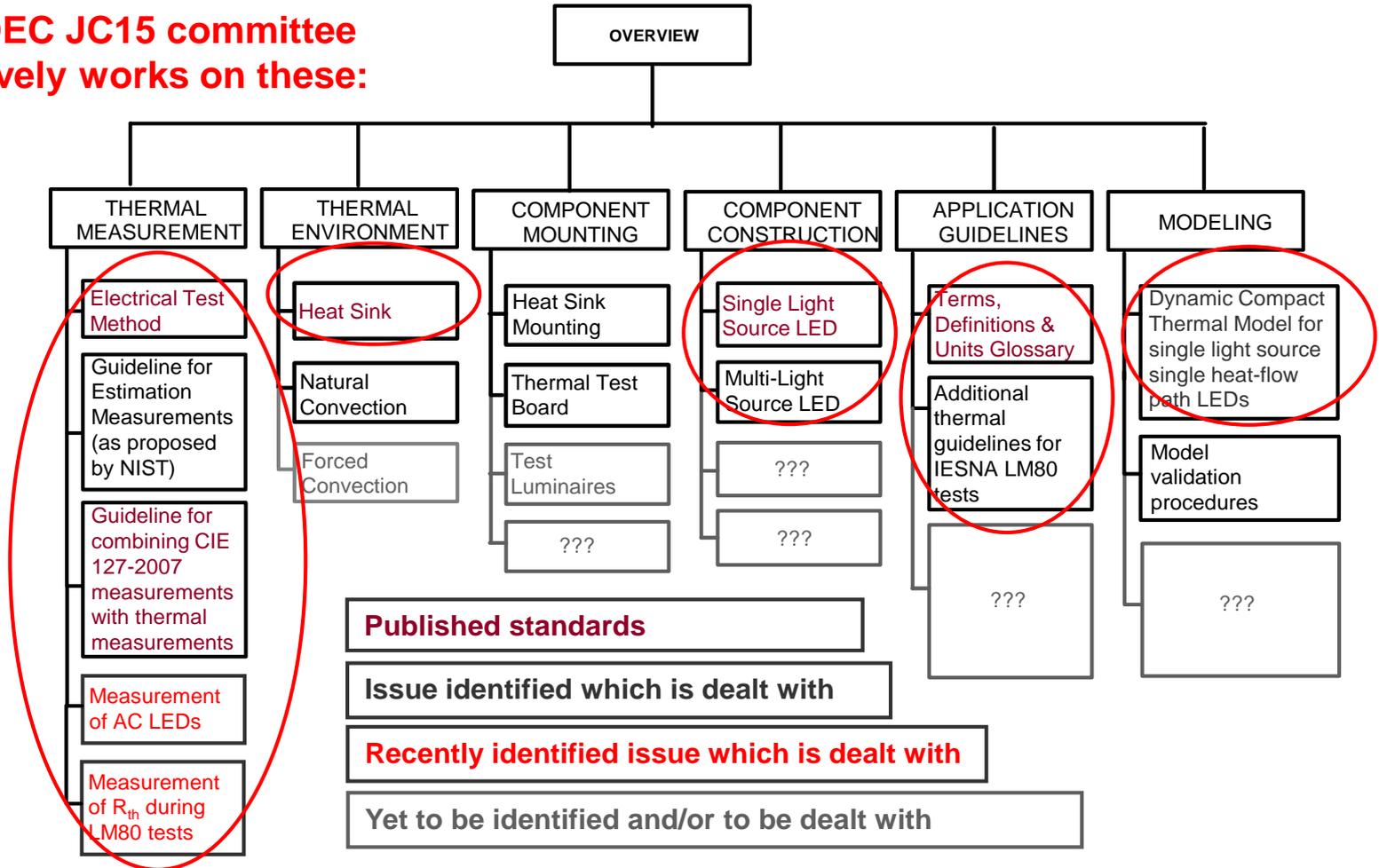
- This combined with a JESD51-14 compliant  $R_{thJC}$  measurement allows test based compact thermal modeling of power LED packages

Will be discussed later today...

# Approach of the JEDEC JC15 committee

- JESD51-50: LED thermal testing overview document

**JEDEC JC15 committee actively works on these:**



# Standards are downloadable from [www.jedec.org](http://www.jedec.org):

Standards & Documents Search: jesd51 | JEDEC - Internet Explorer

http://www.jedec.org/standards

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## Standards & Documents Search: jesd51

Results 1 - 20 of 23

### Results

Title	Document #	Date
<b>TEST BOARDS FOR AREA ARRAY SURFACE MOUNT PACKAGE THERMAL MEASUREMENTS:</b>	JESD51-9	Jul 2000
<b>TEST BOARDS FOR THROUGH-HOLE PERIMETER LEADED PACKAGE THERMAL MEASUREMENTS:</b>	JESD51-10	Jul 2000

This standard covers the design of printed circuit boards (PCBs) used in the thermal characterization of ball grid array (BGA) and land grid array (LGA) packages. It is intended to be used in conjunction with the JESD51 series of standards that cover the test methods and test environments. JESD51-9 was developed to give a figure-of-merit of thermal performance that allows for accurate comparisons of packages from different suppliers. It can be used to give a first order approximation of system performance and standards, allows for comparisons of the various package families.

**Committee(s):** JC-15.1

Free download.  or  required.

This standard covers the design of printed circuit boards (PCBs) used in the thermal characterization of Dual-Inline Packages (DIP) and Single-Inline Packages (SIP). It is intended to be used in conjunction with the JESD51 series of standards that cover the test methods and test environments. JESD51-10 was developed to give a figure-of-merit of thermal performance that allows for accurate comparisons of packages from different suppliers. It can be used to give a first order approximation of system performance and, in conjunction with the other JESD51 PCB standards, allows for comparisons of the various package families.

**Committee(s):** JC-15.1

Free download.  or  required.

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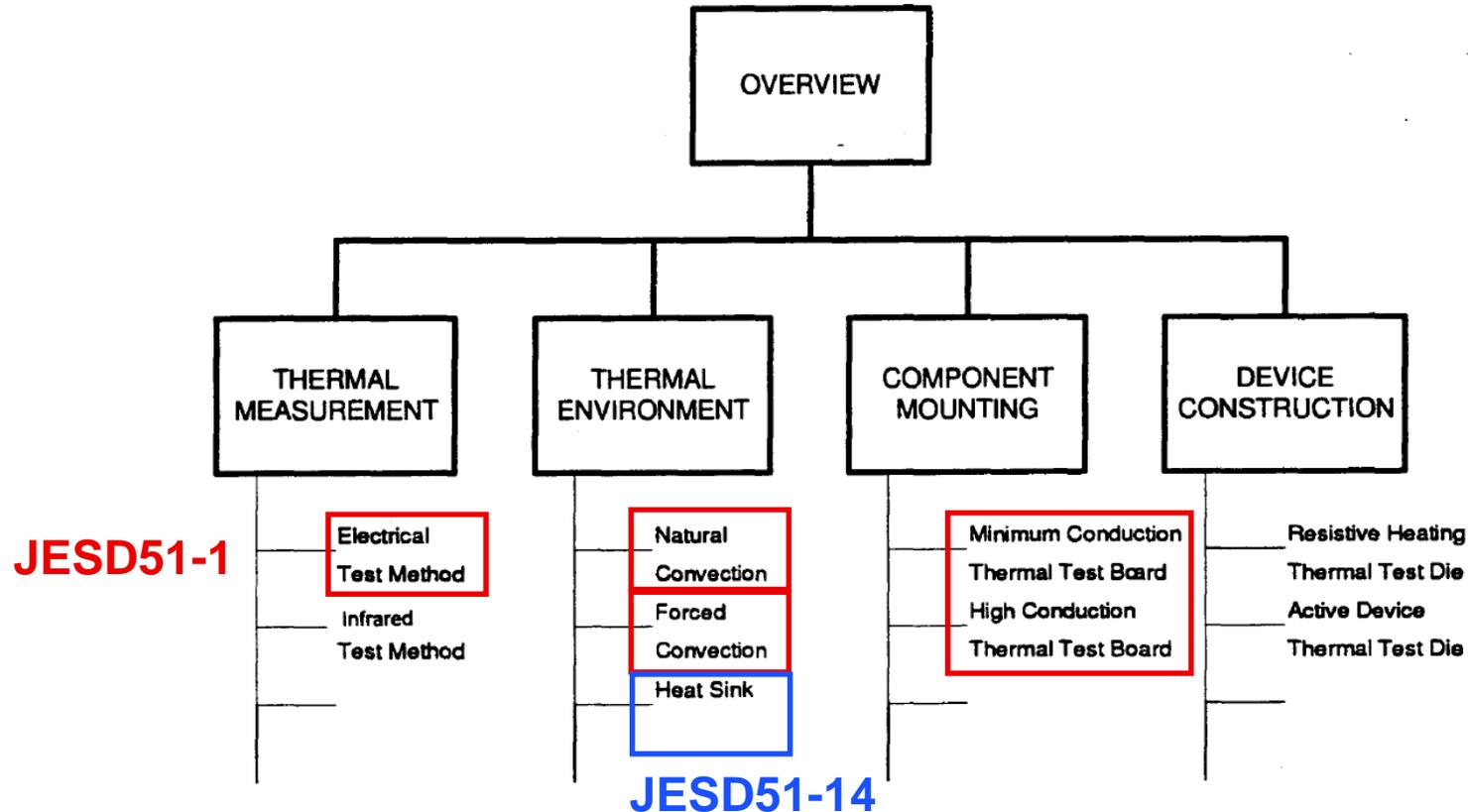
**Committees**

JC-15: Thermal Characterization Techniques for Semiconductor Packages (23)

**Registration is required**

# The JESD51 standard – overview document

- The thermal testing standards follow a modular structure:



Each group will have one or more applicable documents to reflect different thermal measurement requirements. Because environmental conditions, component mounting approaches and device construction techniques and processes will change as technology changes, additional documents will be added to these groups as the needs arise and standards established. As appropriate, each of

# The JE51-1 electrical test method

- **Direct measurement of a single temperature:**  
average temperature, good time resolution
  - **Electrical test method** – to measure junction temperature:
    - Temperature measured by the change of a **temperature sensitive parameter** of the semiconductor (TSP) device (e.g. diode forward voltage, MOSFET threshold voltage)
    - Measures the junction temperature through an electrical signal of the TSP
    - Needs calibration
    - Two test methods: **static** and **dynamic** test method
  - **Thermocouples**
    - Large, error due to alternate heat-flow via the thermocouple itself
    - Used typically to measure / monitor environmental conditions
- **Thermal transient measurements are based on the electrical test method**
  - smart implementation of the JE51-1 **static test method**
  - completed with structure function analysis adds extra value: ***insight into the details of the heat-flow path***

# A few words about the thermal resistance

## ■ Original definition in the JEDEC JESD51-1 document

EIA/JEDEC Standard No. 51-1

Page 3

### 2. MEASUREMENT BASICS

The thermal resistance of a semiconductor device is generally defined as:

$$R_{JX} = \frac{T_J - T_X}{P_H} \quad (1)$$

- where  $R_{JX}$  = thermal resistance from device junction to the specific environment (alternative symbol is  $\theta_{JX}$ ) [ $^{\circ}\text{C}/\text{W}$ ]  
 $T_J$  = device junction temperature in the steady state test condition [ $^{\circ}\text{C}$ ]  
 $T_X$  = reference temperature for the specific environment [ $^{\circ}\text{C}$ ]  
 $P_H$  = power dissipated in the device [W]

The device junction temperature in the test condition can be determined by:

$$T_J = T_{J0} + \Delta T_J \quad (2)$$

- where  $T_{J0}$  = initial device junction temperature before heater power is applied [ $^{\circ}\text{C}$ ]  
 $\Delta T_J$  = change in junction temperature due to heater power application [ $^{\circ}\text{C}$ ]

The Electrical Test Method (ETM), described herein, makes use of a temperature-sensitive parameter (TSP) to sense the change in temperature of the junction operating area due to the application of electrical power to the device-under-test (DUT). In equation terms,

$$\Delta T_J = K \times \Delta TSP \quad (3)$$

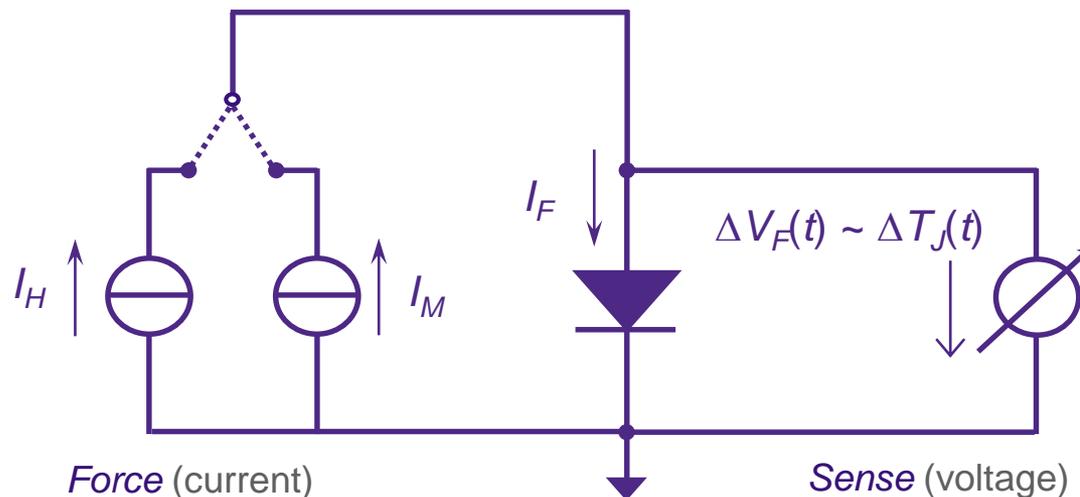
- where  $\Delta TSP$  = change in temperature-sensitive parameter value [mV]  
 $K$  = constant defining relationship between changes in  $T_J$  and TSP [ $^{\circ}\text{C}/\text{mV}$ ]

# How do we know $\Delta T_J(t)$ ?

- PN junctions' forward voltage under forced current condition can be used as a very accurate thermometer
- The change of the forward voltage (TSP – temperature sensitive parameter) should be carefully calibrated against the change of the temperature (see JEDEC JESD51-1 and MIL-STD-750D)
  - In the calibration process the  $S_{VF}$  temperature sensitivity of the forward voltage is obtained

$$V_F(I_M, t) = V_{Fi}(I_M) + S_{VF} \cdot [T_J(t) - T_J(0)]$$

$$S_{VF} = 1/K$$



- Forward voltage change due to temperature change is measured using a 4 wire setup (Kelvin setup)

# The static test method

- According to the JESD51-1 document two test methods are defined: **dynamic test method** and **static test method**

- **Static test method or *continuous measurement*:**

- Switch on heating at the junction
  - Wait for the steady state be reached (when junction is hot)
  - Measure the junction temperature and identify the heating power
- Switch off the heating
  - Wait for the steady state be reached (when junction is cool)
  - Measure the junction temperature

Assumption of the standard:

- At cold steady-state 0 power is applied → junction temperature is equal to the temperature of the ambient (reference environment)

As we shall see, this assumption is not really needed

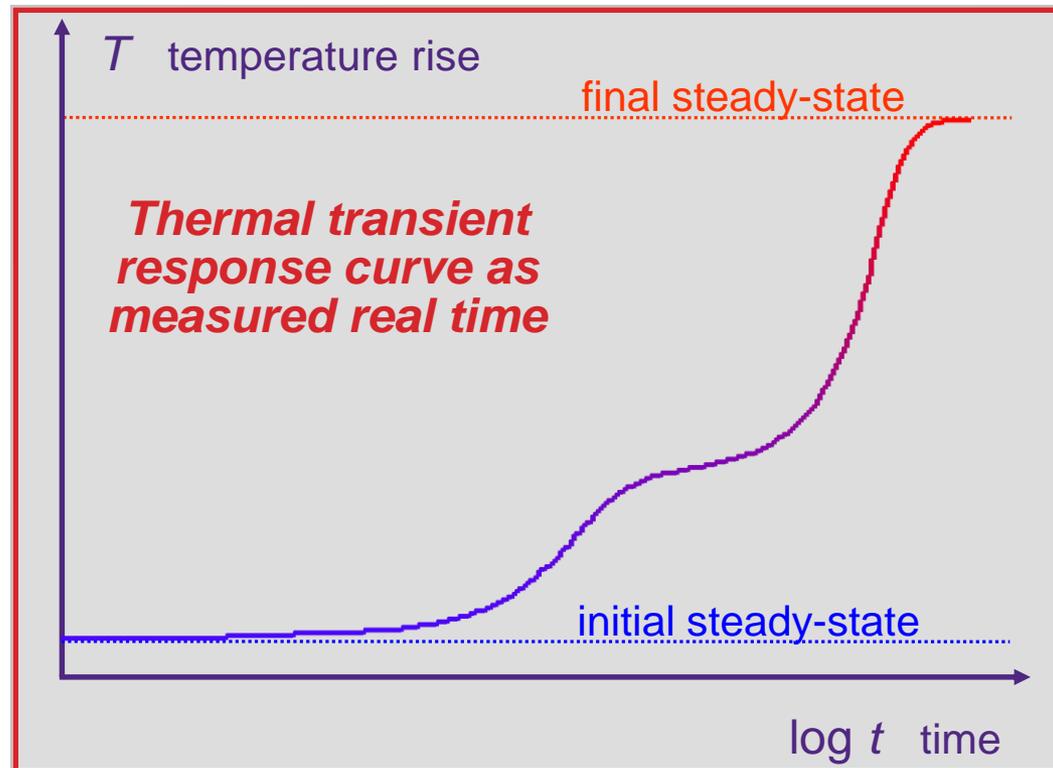
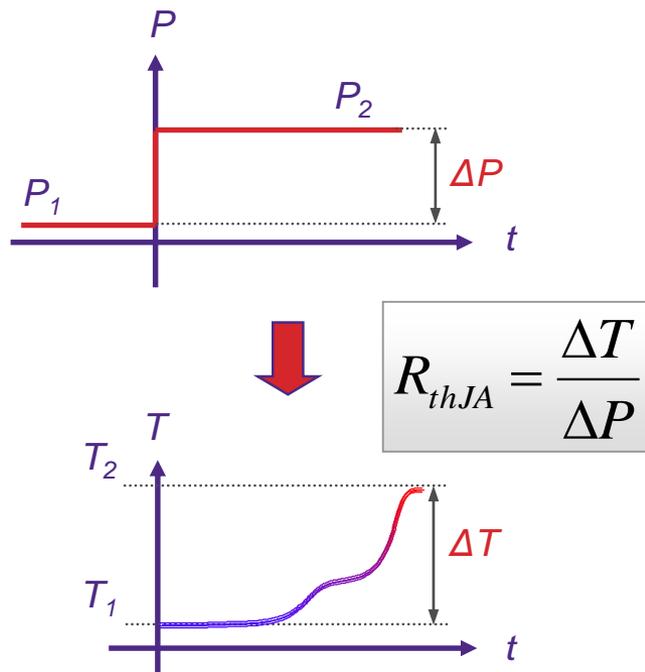
- Extension of the basic static test method: **real transients**
  - **Measure the actual change of the junction temperature** after the power is switched off (or on) **continuously**, resulting in a **real junction temperature transient**
  - Completely **differential approach** in which switching off or on the power is symmetrical
  - Measurement is followed by mathematical post processing resulting in **structure functions** and other descriptive functions

# The principle of the extended static test method

- Due to switching the power, temperature changes:

Switch the power on (or off) in *steady state* and wait for the *other steady state* to occur.

While waiting for reaching the other steady-state, **measure (record) the real transient** continuously, as it takes place.



# Measurement of $\Delta T_j(t)$ continuously "on-the-fly":

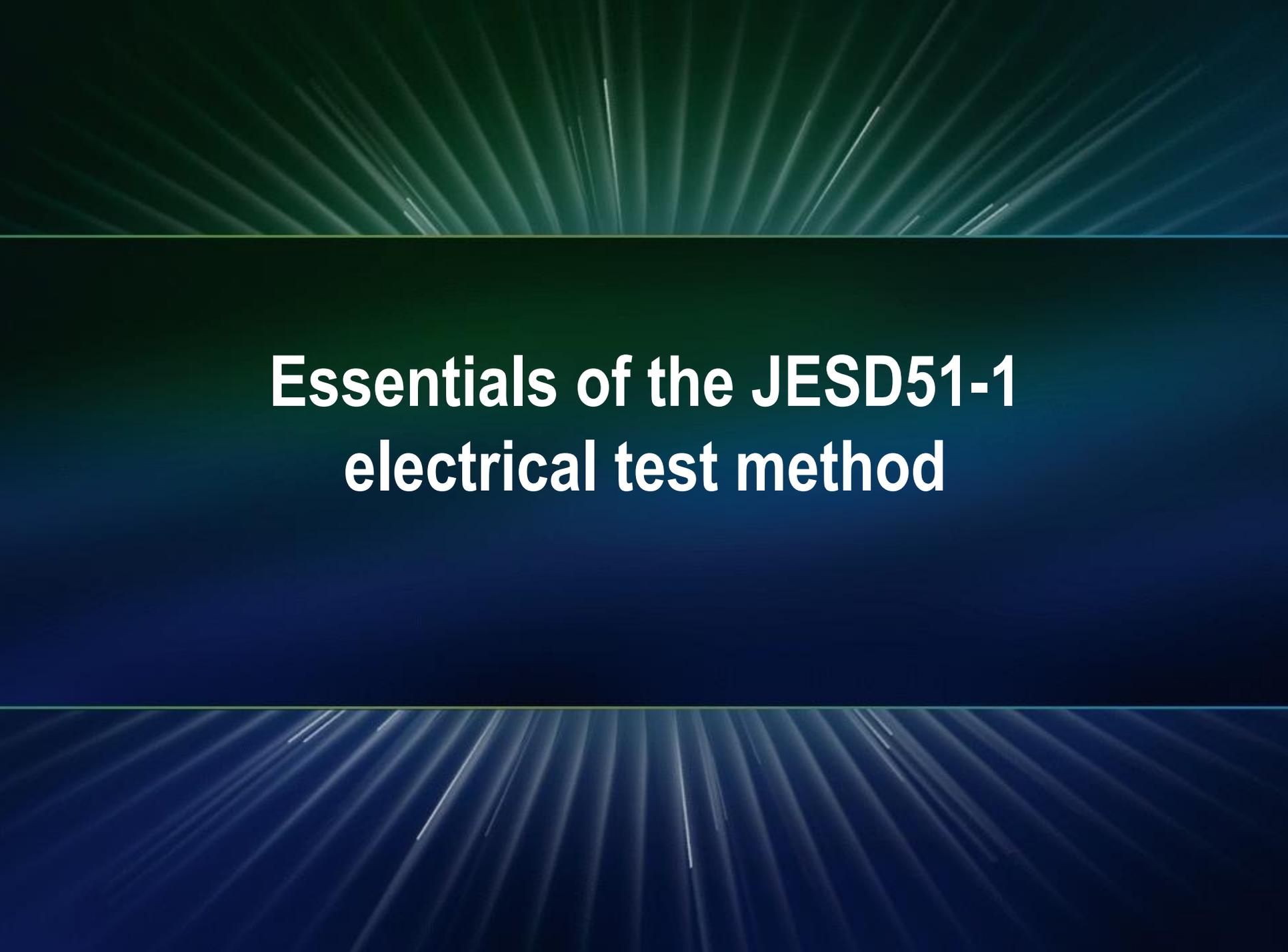
- ***This test method is less problematic:*** the JESD51-1 document does not prescribe detailed procedures to avoid problems
- In the static test method ***only one switching*** takes place:
  - switch ON the power: *capture a heating transient – continuously*
  - switch OFF the power: *capture a cooling transient – continuously*
- After changing the heating power in a step-wise manner ***no further switching takes place***
  - no problems related to  $t_{MD}$  selection – no measurement delay is needed

## 2.2 COOLING TIME CONSIDERATIONS

*JESD51-1 document*

COOLING TIME considerations are NOT applicable to the Static Mode of testing because the monitoring of the temperature-sensitive parameter occurs on a continuous basis while the heating power is applied to the DUT.

- the only concern is the possible electrical transient at  $t=0+$



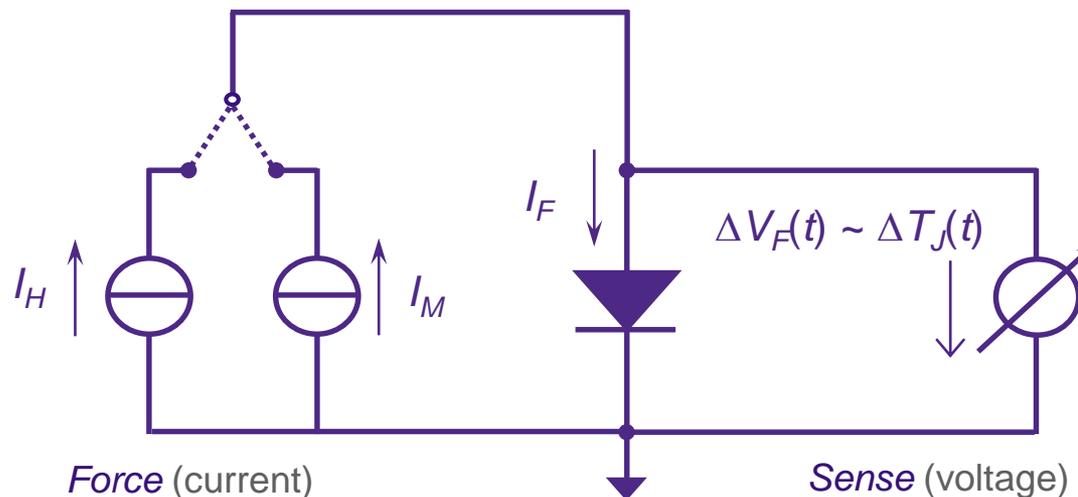
# **Essentials of the JESD51-1 electrical test method**

# How do we know $\Delta T_J(t)$ ?

- PN junctions' forward voltage under forced current condition can be used as a very accurate thermometer
- The change of the forward voltage (TSP – temperature sensitive parameter) should be carefully calibrated against the change of the temperature (see JEDEC JESD51-1 and MIL-STD-750D)
  - In the calibration process the  $S_{VF}$  temperature sensitivity of the forward voltage is obtained

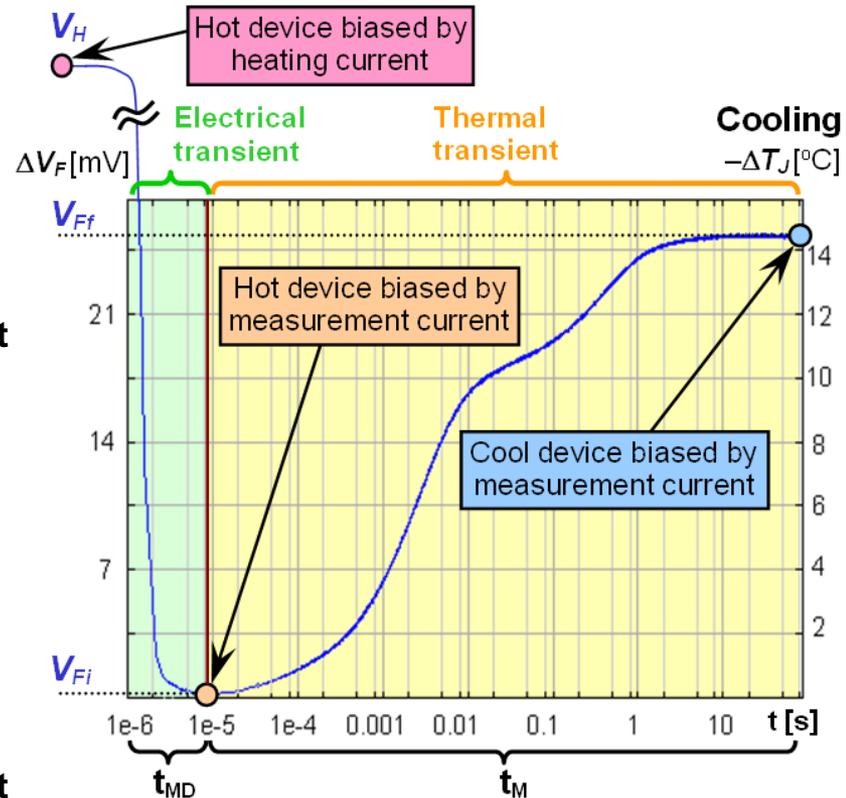
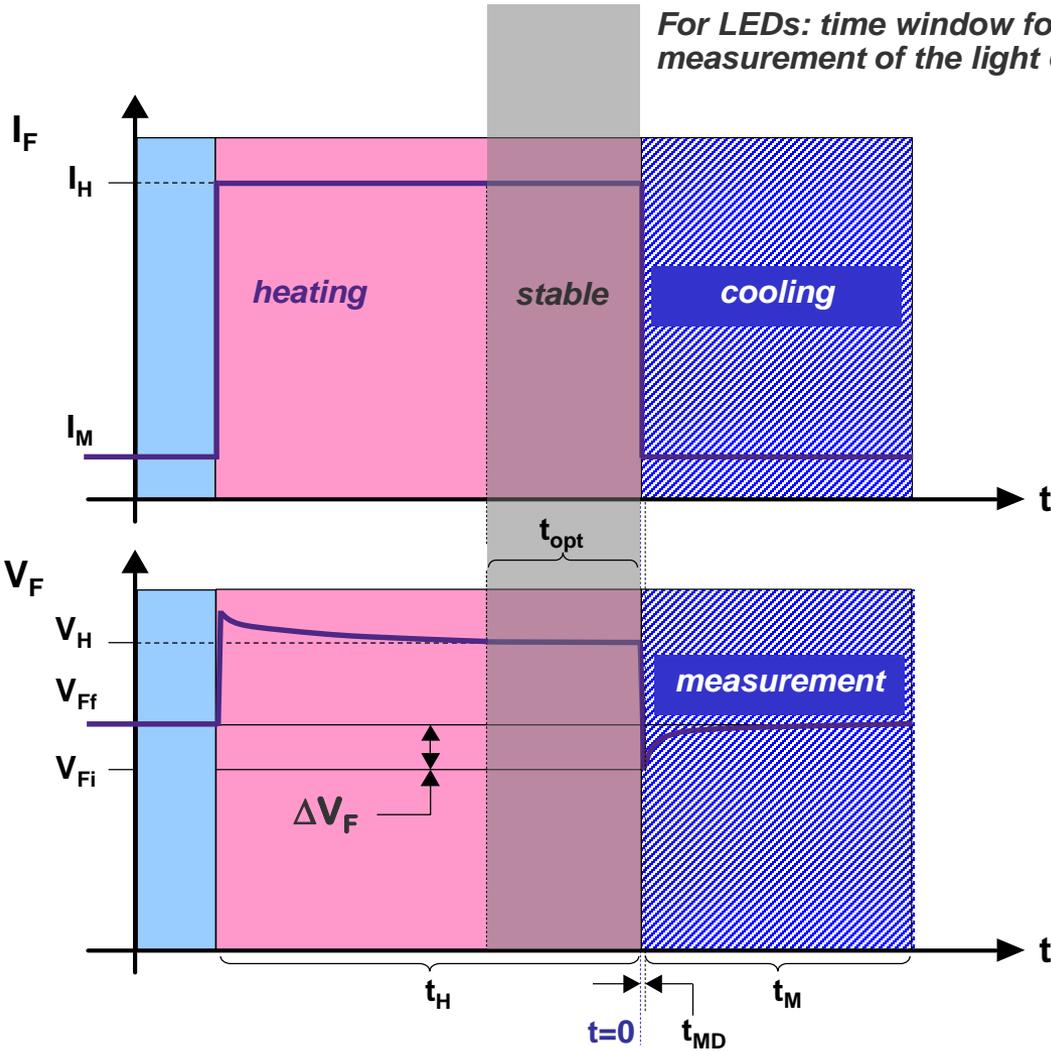
$$V_F(I_M, t) = V_{Fi}(I_M) + S_{VF} \cdot [T_J(t) - T_J(0)]$$

$$S_{VF} = 1/K$$

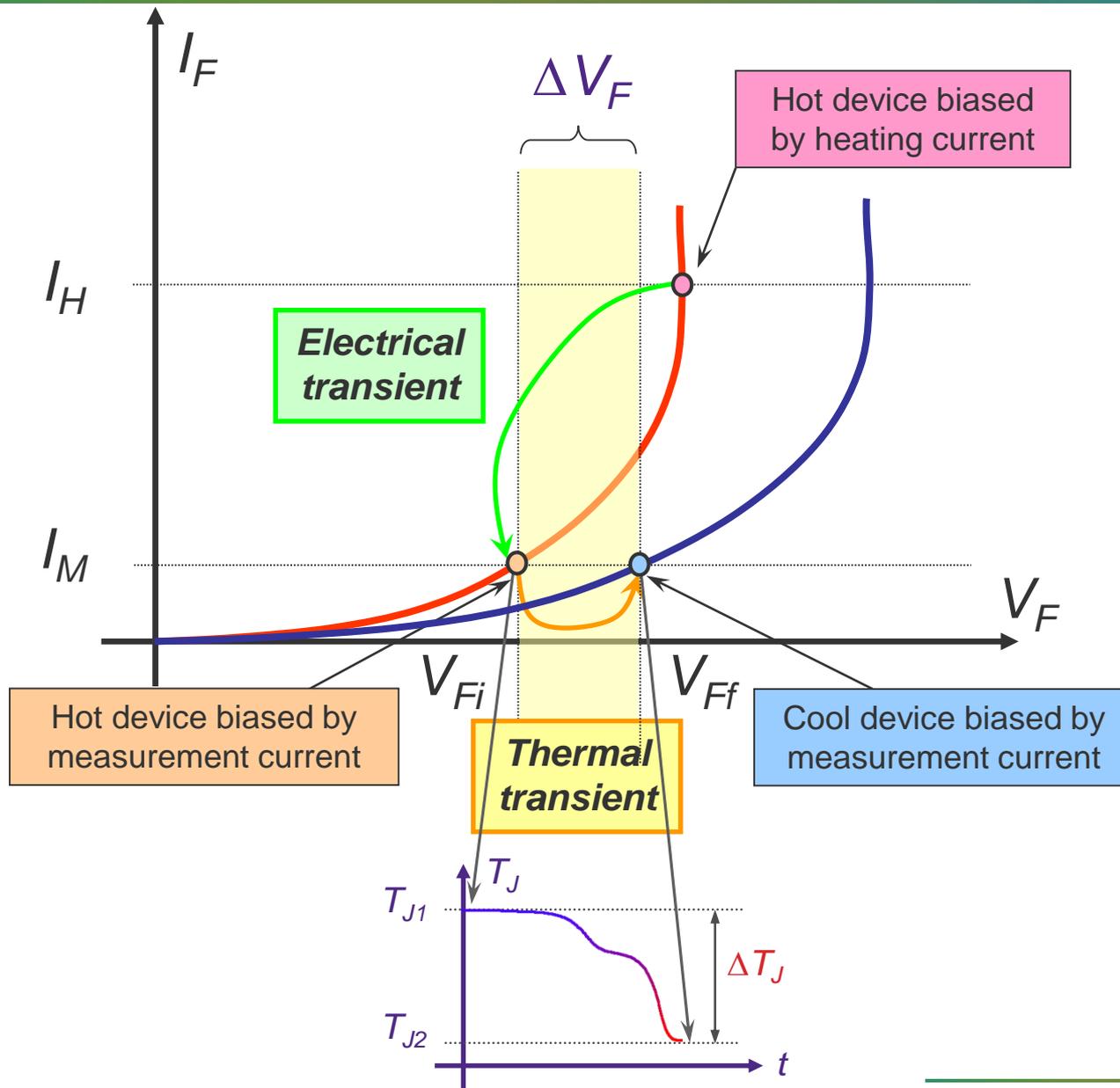


- Forward voltage change due to temperature change is measured using a 4 wire setup (Kelvin setup)

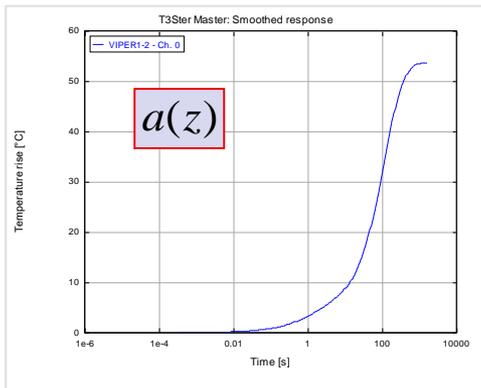
# The measurement waveforms



# The transient processes in the I-V characteristic:



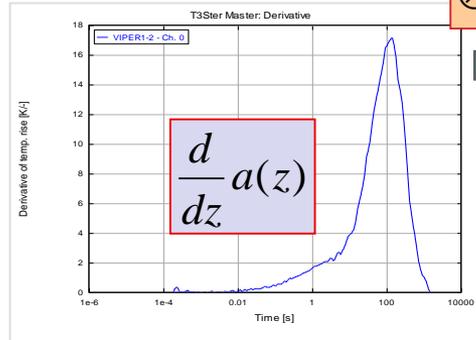
# Converting $Z_{th}$ curves to *structure functions*



Measured thermal impedance curve

$$\frac{d}{dz}$$

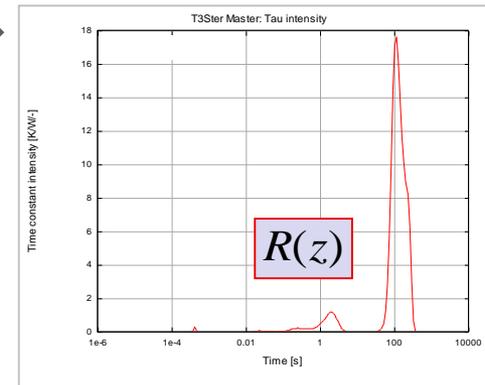
Numerical derivation



Derivative of the thermal impedance curve

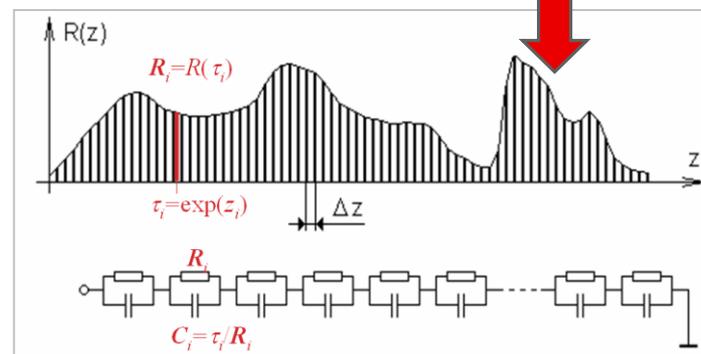
$$\otimes^{-1} w_z(z)$$

Numerical deconvolution

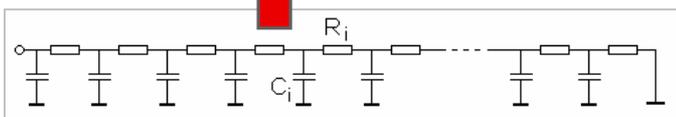
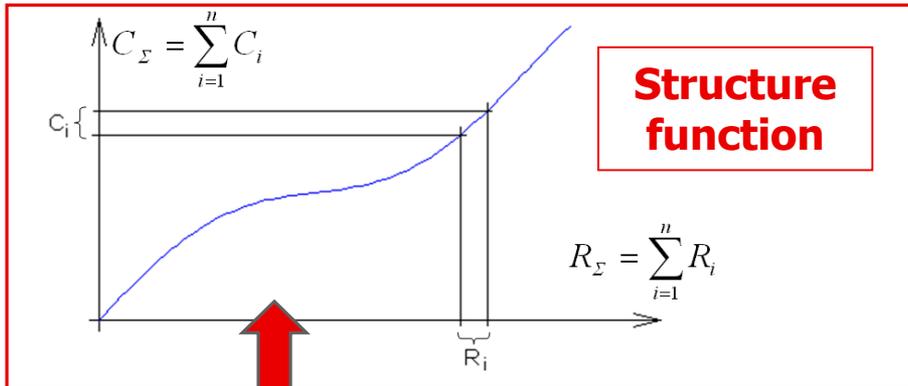


Time-constant spectrum

Discretization



Foster model of the impedance

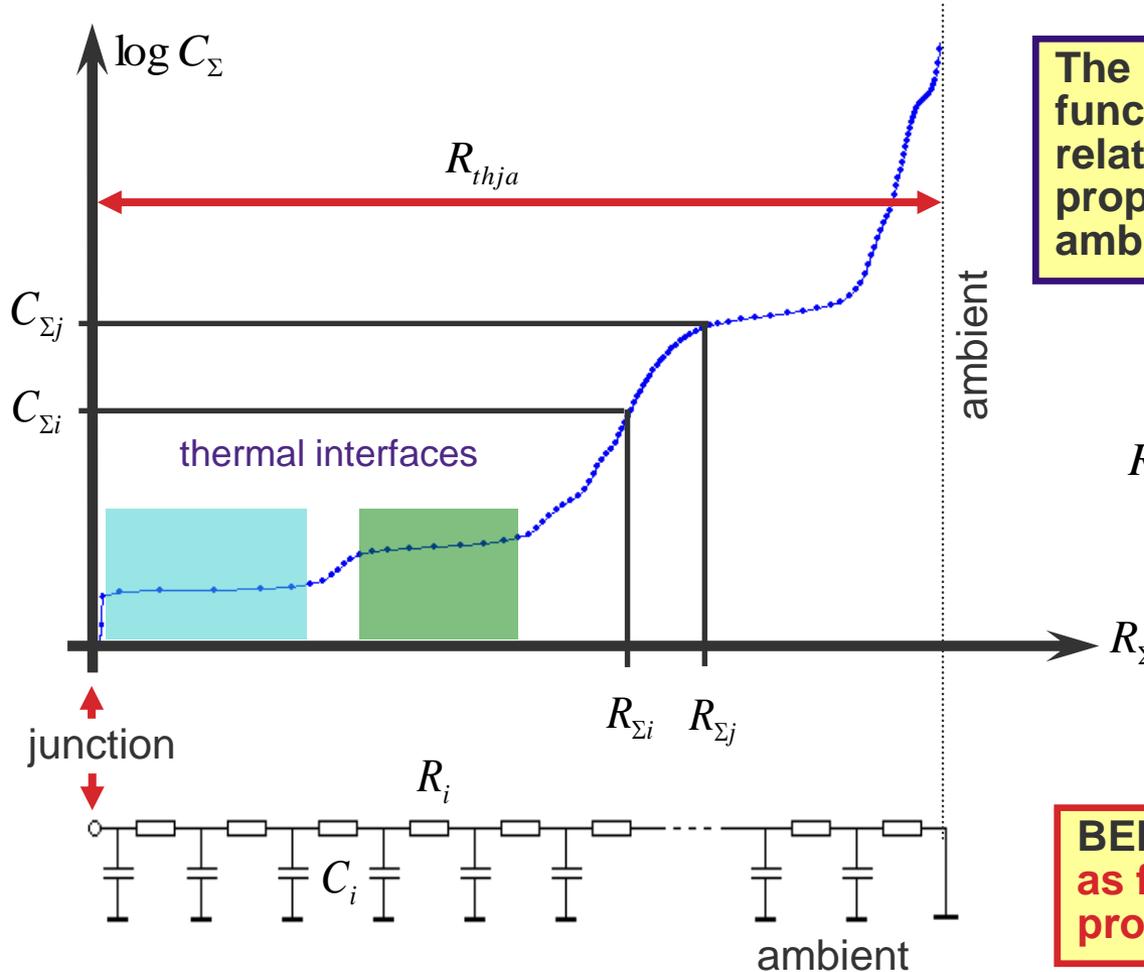


Cauer model of the impedance

Transformation

# The Structure Function

The *structure function* is the **graphical representation** of the *network model of the thermal impedance* of the junction-to-ambient heat-flow path.



The shape of the structure function is in a one-to-one relationship with the properties of the junction-to-ambient heat-flow path.

$$R_{\Sigma n} = \sum_{i=1}^n R_i \quad C_{\Sigma n} = \sum_{i=1}^n C_i$$

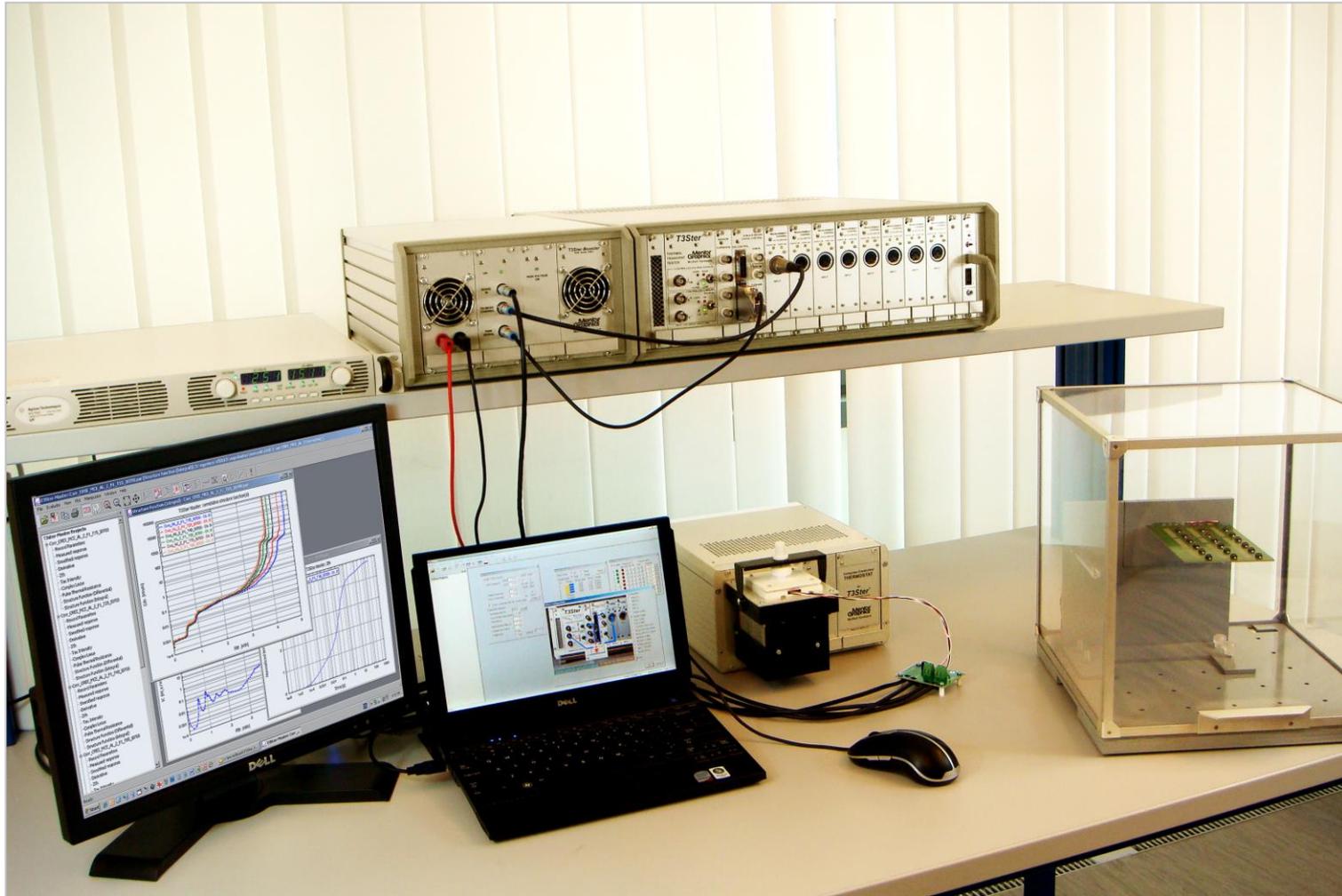
**BENEFIT:** same testing time as for steady-state, but provides much details...

The *structure function* illustrates the **way how heat flows** through a package.

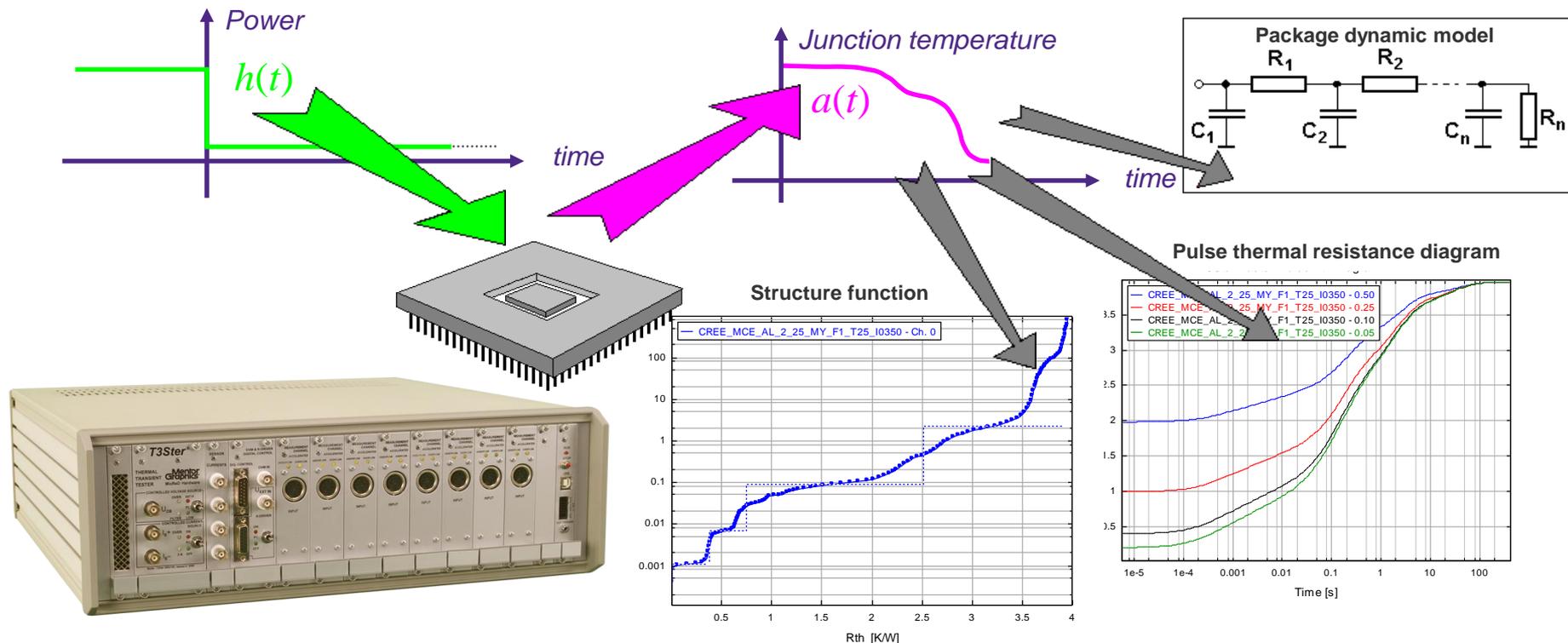
# Mentor Graphics MicReD implementation: T3Ster

- The JEDEC JESD51-1 static test method is implemented by the **T3Ster** equipment (thermal transient tester) and its measurement software
  - real-time measurement of actual junction temperature transients either in heating mode or in cooling mode
    - for diodes cooling mode is recommended (since higher accuracy available this way)
    - for transistors, thermal test dies with separate heaters and sensors both heating and cooling modes are recommended
  - K-factor calibration is provided
- Measured transients are post-processed by the **T3Ster Master** software, providing
  - structure functions and
  - other alternate representations of the measured thermal impedance such as
    - complex loci
    - time-constant spectra
    - pulsed thermal resistance diagrams
    - dynamic compact thermal network models

# Mentor Graphics MicReD implementation: T3Ster



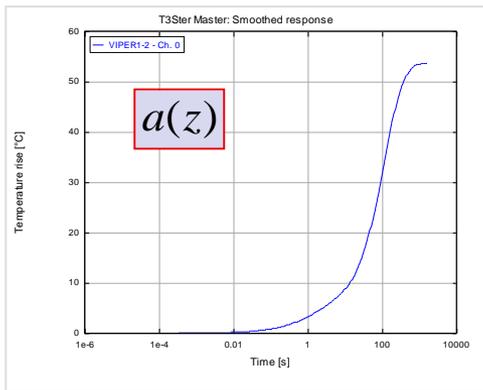
# Summary of thermal transient testing using T3Ster



- The  $h(t)$  step-wise change in heating is applied at the junction (abrupt switching)
- The  $a(t)$  temperature response at the junction is being measured (unit-step response function) while linearity is assumed
- All available information is extracted from  $a(t)$  using sophisticated mathematical procedures
  - structure function, derivative of structure function
  - compact dynamic thermal models
  - pulsed thermal resistance / complex locus (frequency domain representation)

# The structure functions

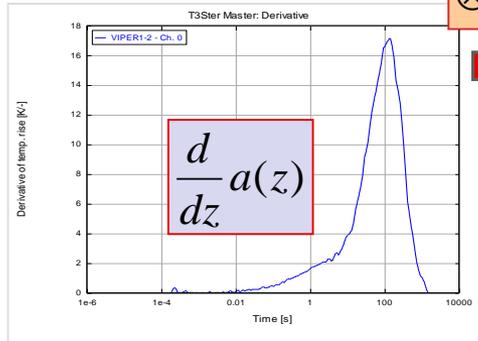
# How Do We Get Them in the *T3Ster* software?



Measured thermal impedance curve

$$\frac{d}{dz}$$

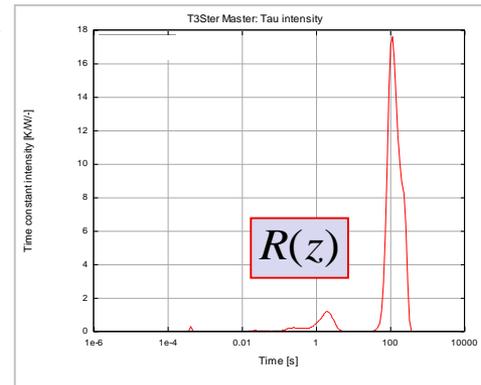
Numerical derivation



Derivative of the thermal impedance curve

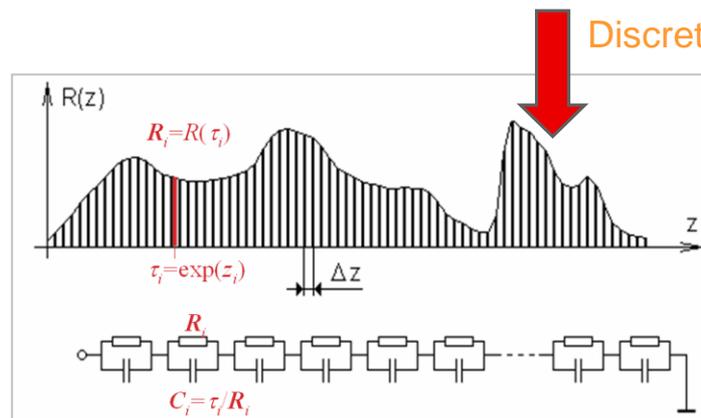
$$\otimes^{-1} w_z(z)$$

Numerical deconvolution

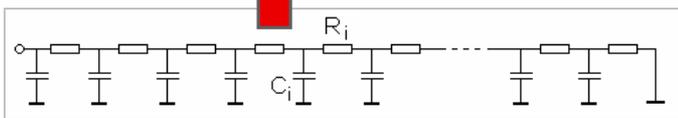
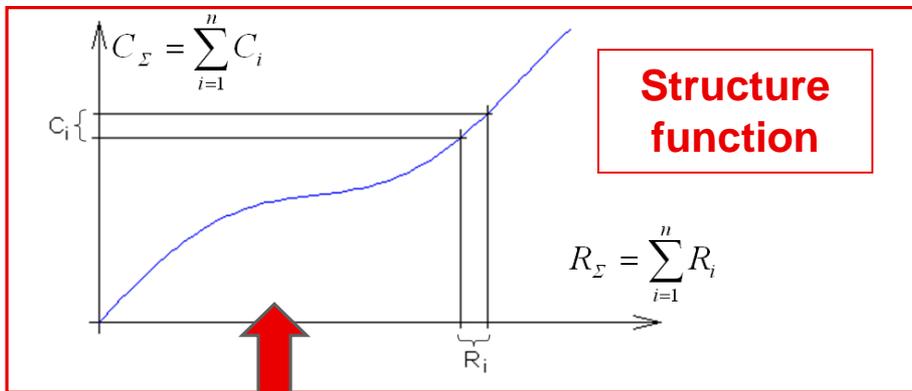


Time-constant spectrum

Discretization



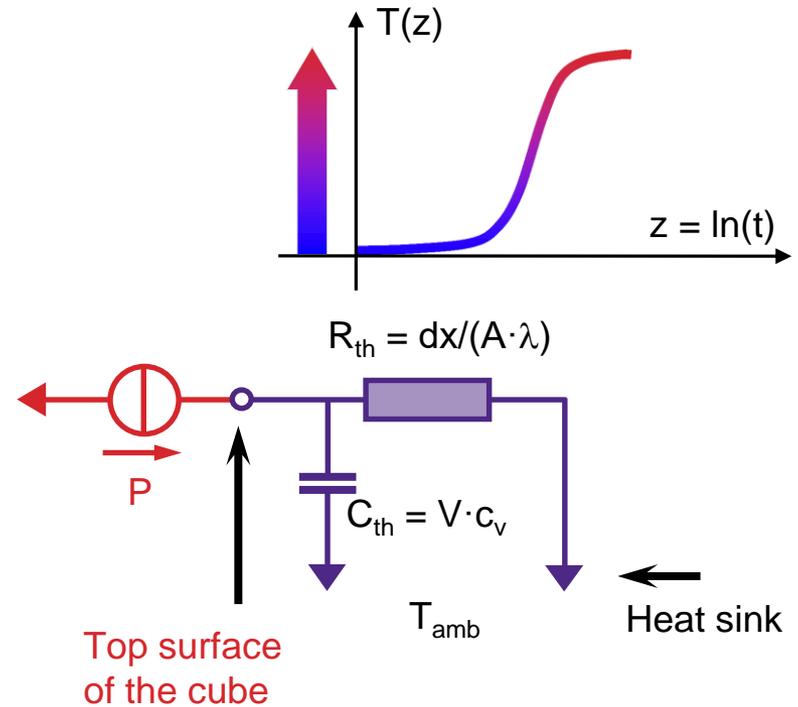
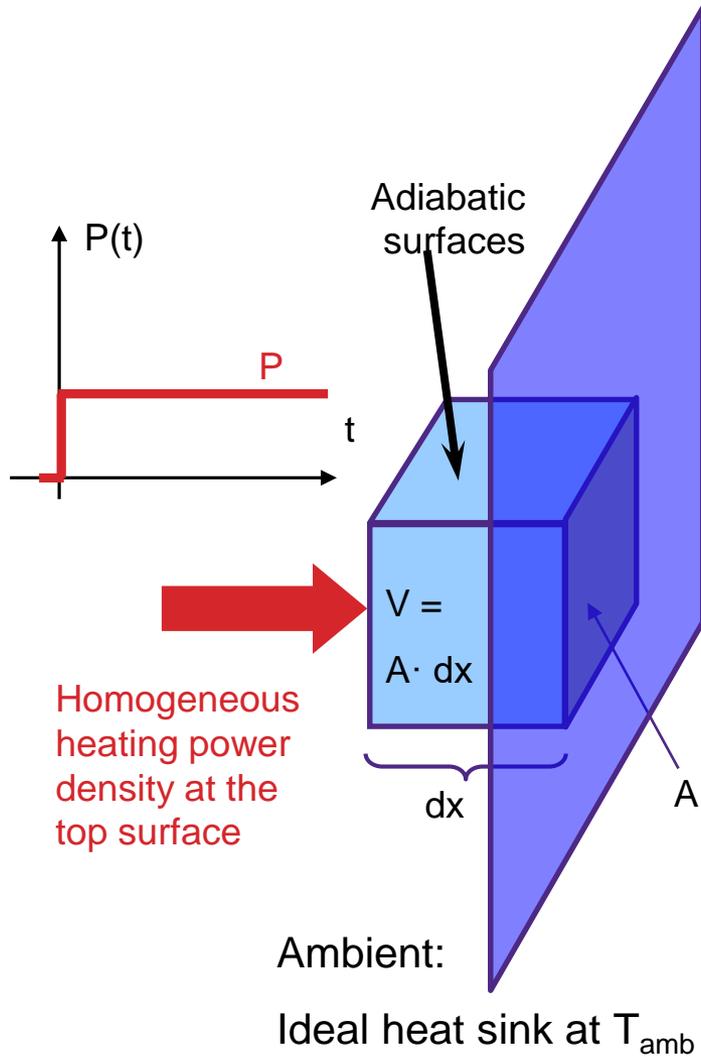
Foster model of the impedance



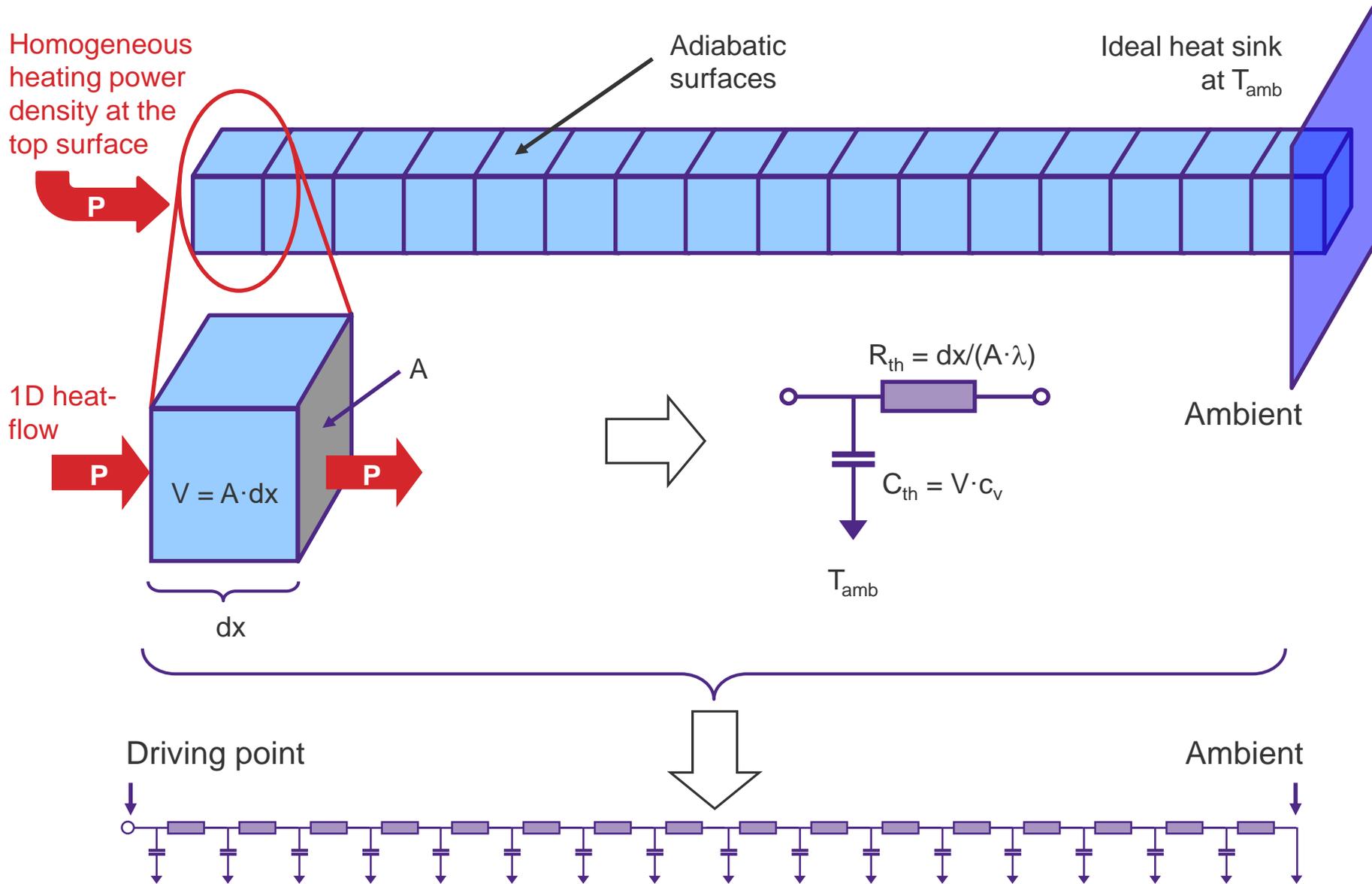
Cauer model of the impedance

Transformation

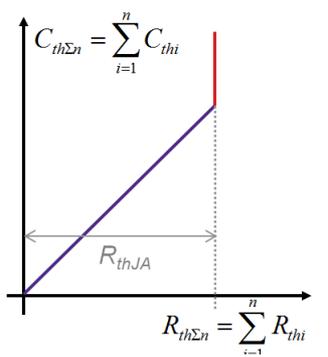
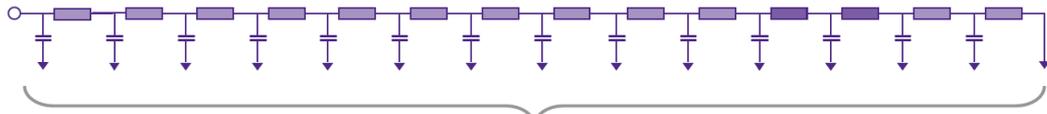
# Introduction to the structure functions



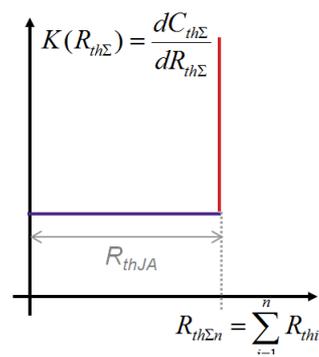
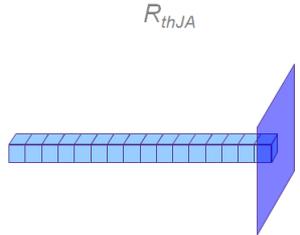
# Introduction to the structure functions



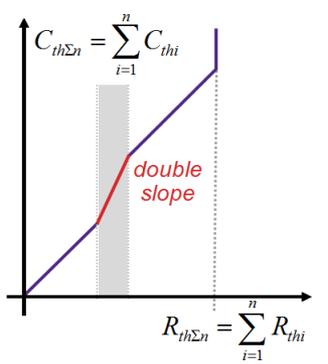
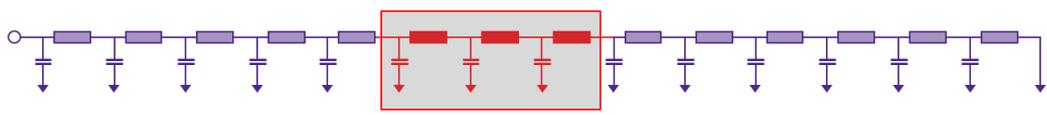
# Introduction to the structure functions



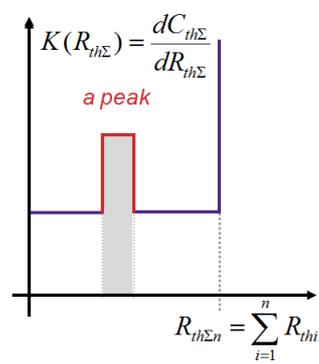
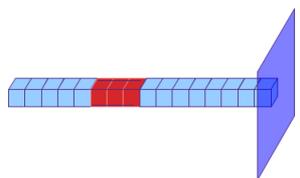
Structure function



Derivative of structure function



Structure function

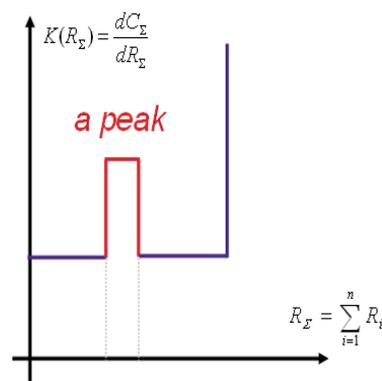
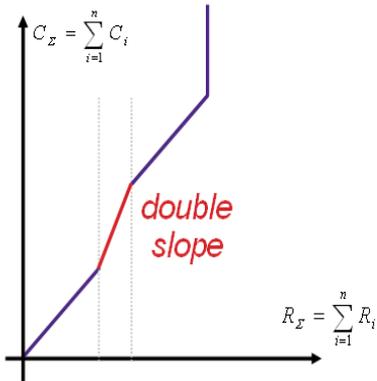
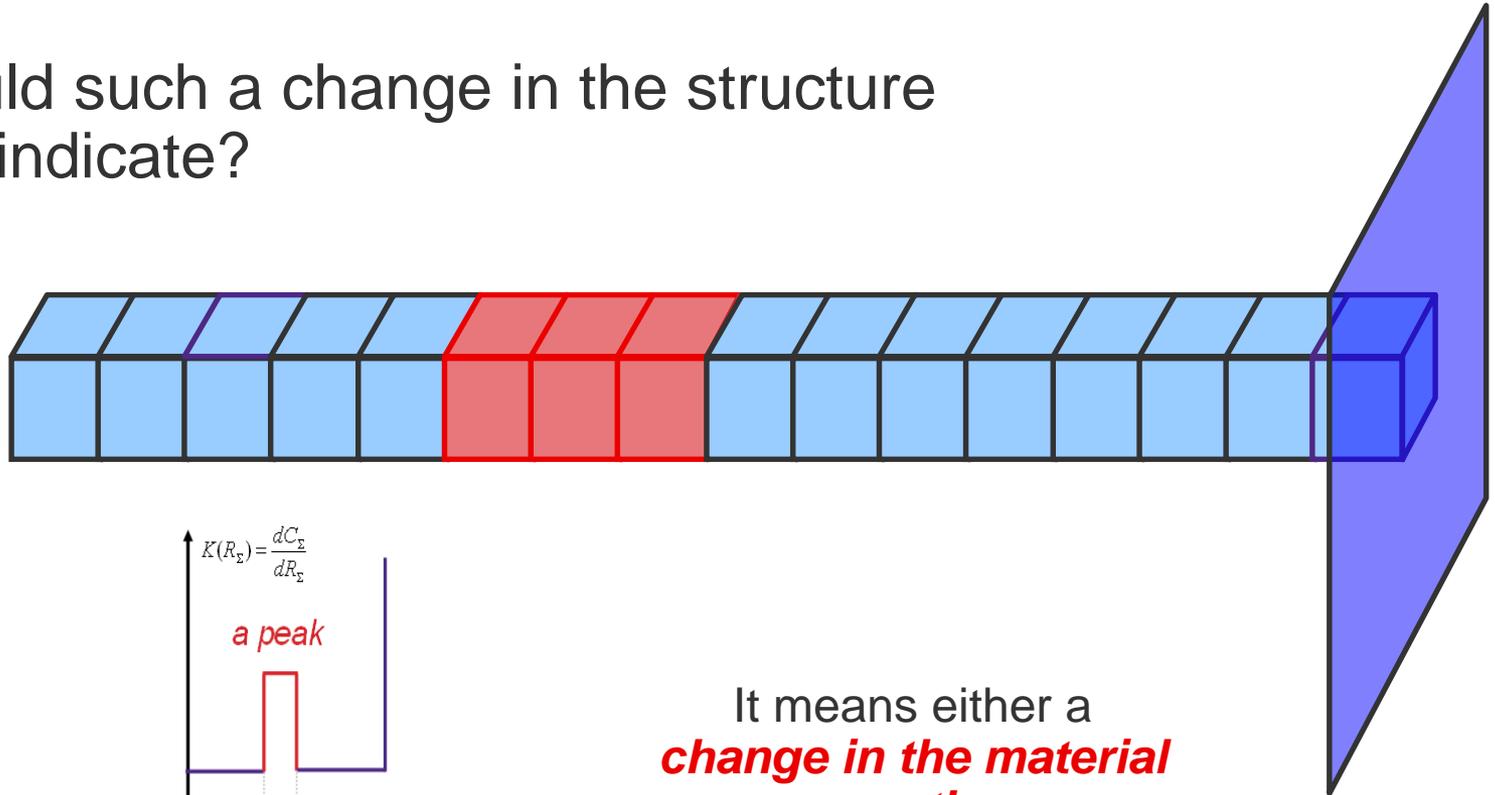


Derivative of structure function

Structural or material property changes are clearly indicated both by the cumulative and the differential structure functions

# Introduction to the structure functions

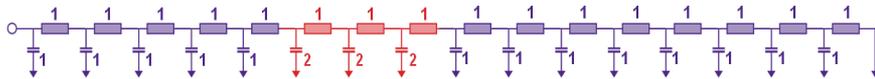
What would such a change in the structure functions indicate?



It means either a **change in the material properties...**

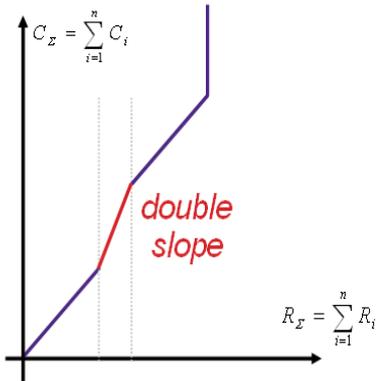
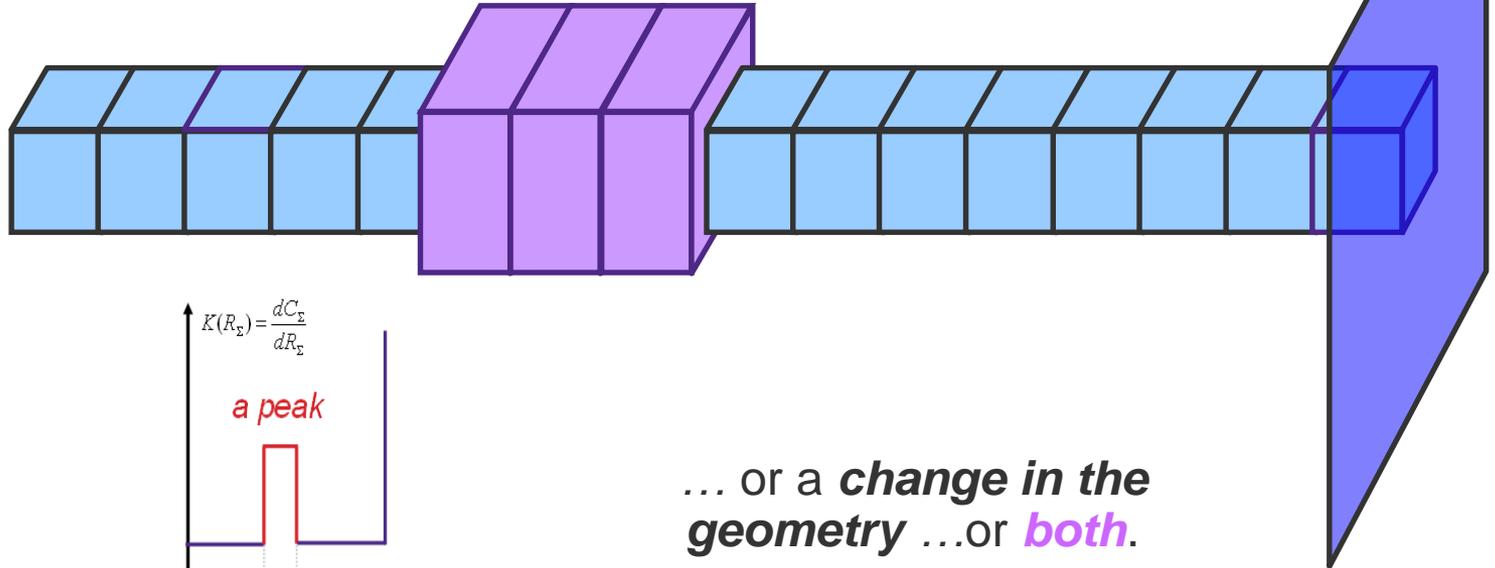
Structure function

Derivative of structure function

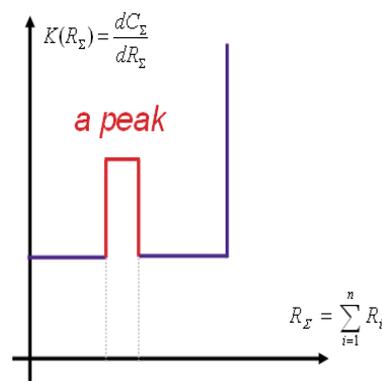


# Introduction to the structure functions

What would such a change in the structure functions indicate?

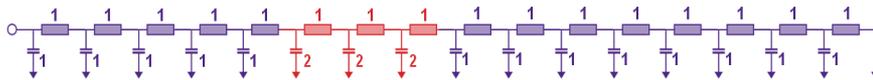


Structure function



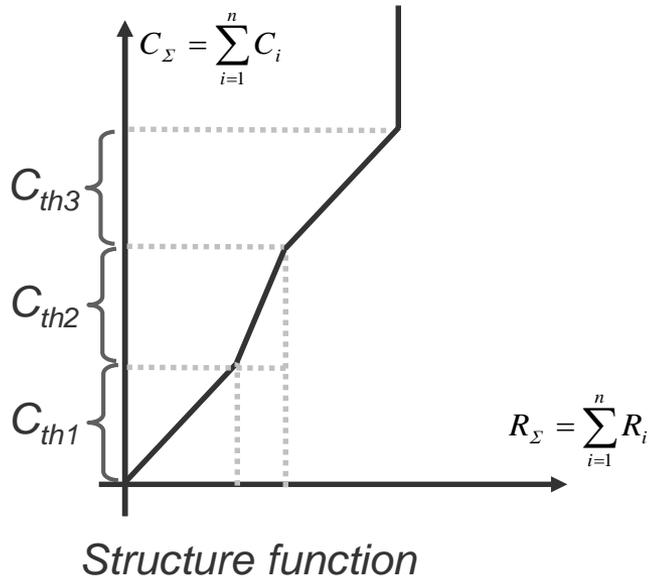
Derivative of structure function

... or a **change in the geometry** ... or **both**.

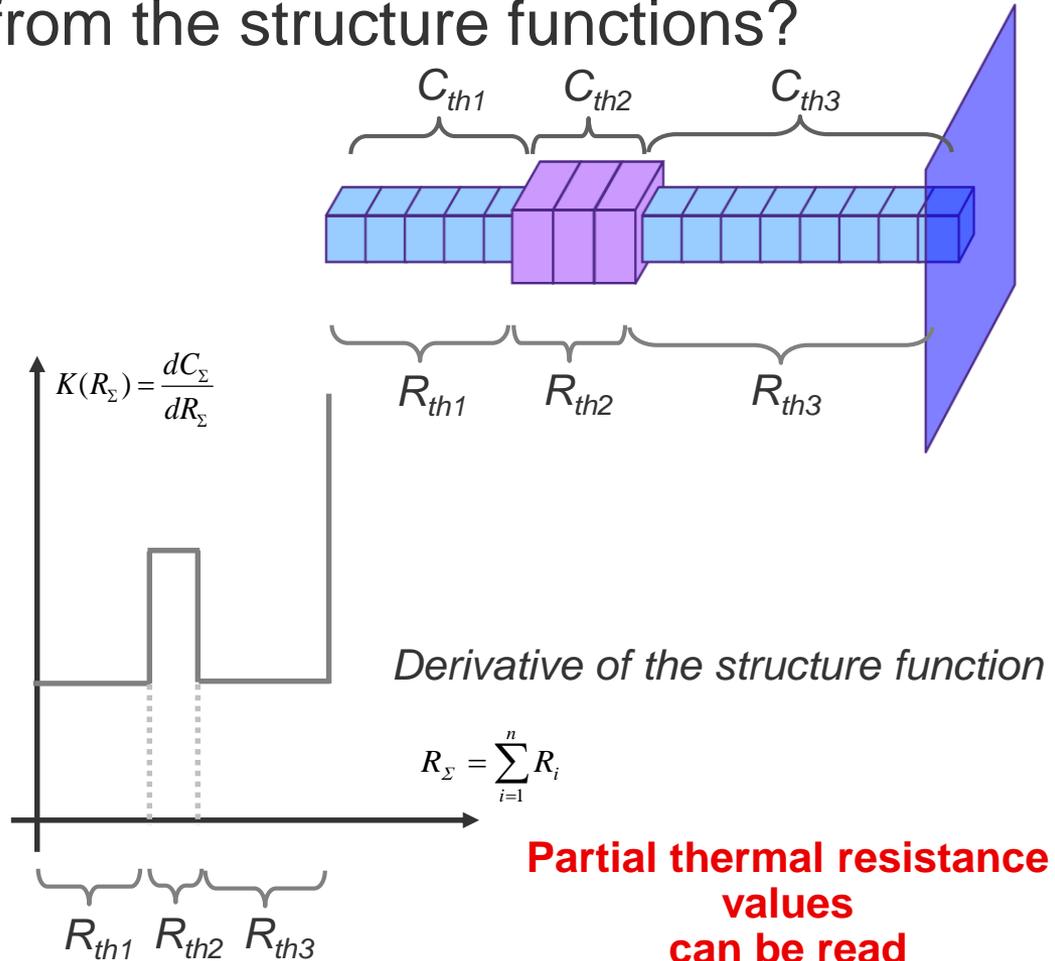


# Introduction to the structure functions

What values can we read from the structure functions?

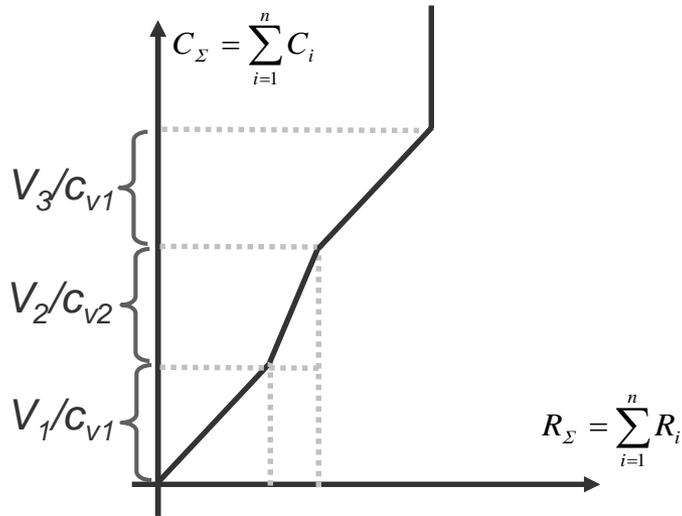


**Thermal capacitance values can be read**



# Introduction to the structure functions

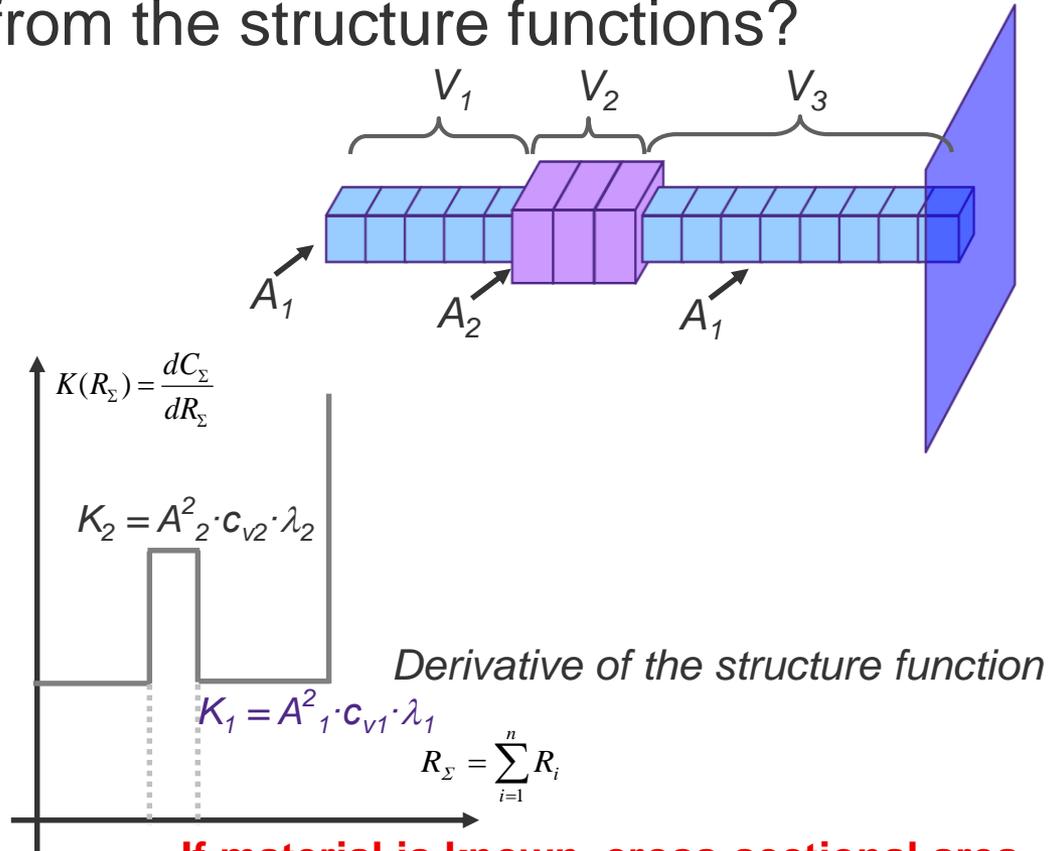
What values can we read from the structure functions?



Structure function

**If material is known,  
volume can be identified.**

If volume is known, volumetric thermal capacitance can be identified.



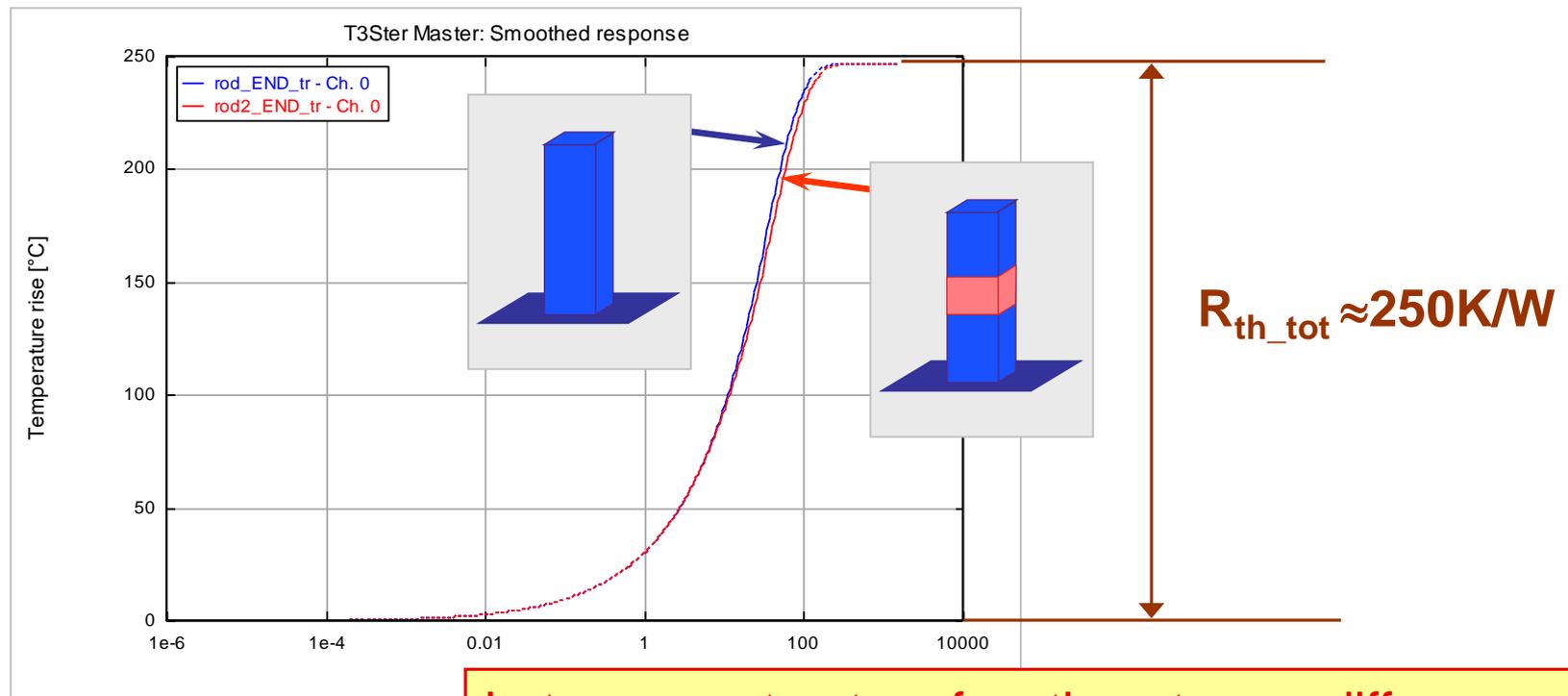
Derivative of the structure function

**If material is known, cross-sectional area  
can be identified.**

If cross-sectional area is known, material parameters ( $c_v \cdot \lambda$ ) can be identified.

# Simulation Experiment for Rods

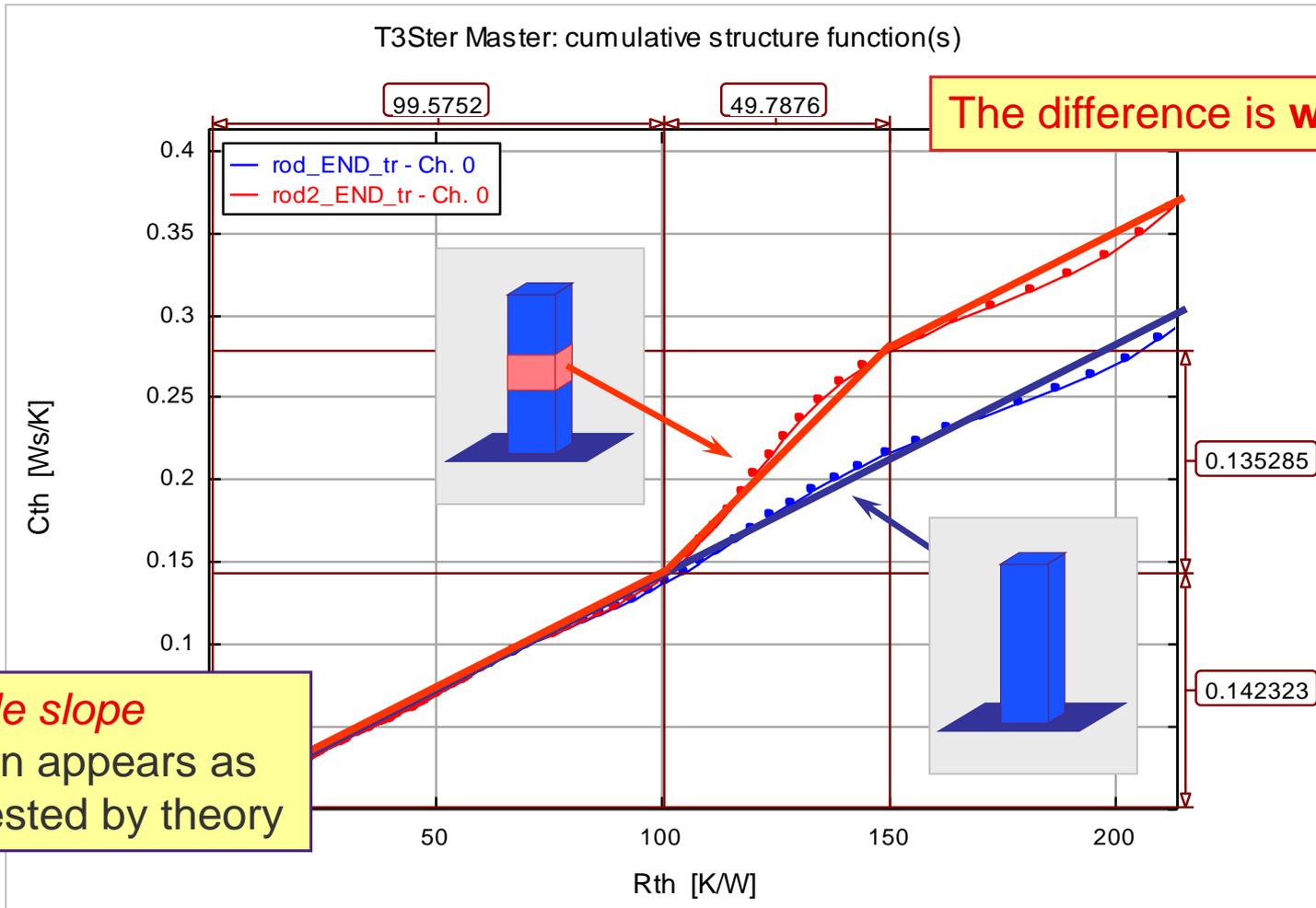
- A Cu rod of  $1 \times 1 \text{ mm}^2$  cross-sectional area and 100mm length was simulated ( $\lambda=402 \text{ W/mK}$ ,  $C_v=3.4 \times 10^6 \text{ W/m}^3\text{K}$ )  $\Rightarrow R_{th\_tot} \approx 250 \text{ K/W}$
- **Change applied:** 40mm normal Cu, 20mm with double  $C_v$  value, 40mm normal Cu



Let us use structure functions to see differences!

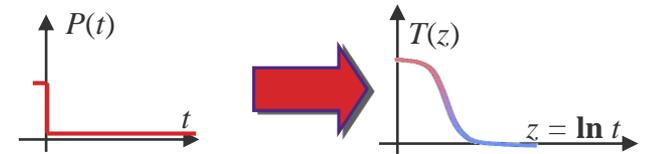
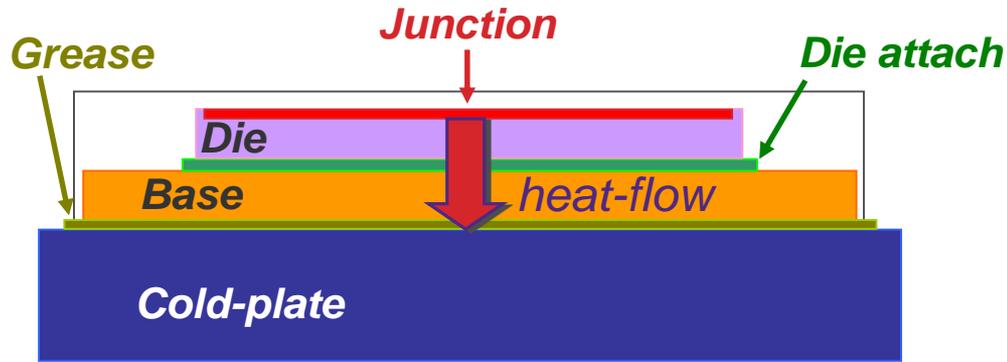
# Simulation Experiment for Rods

- The same results in structure functions:



# Structural / network model of the heat-flow path

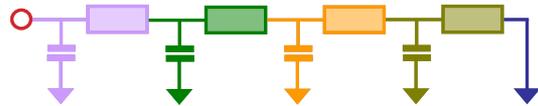
## The Structure Function



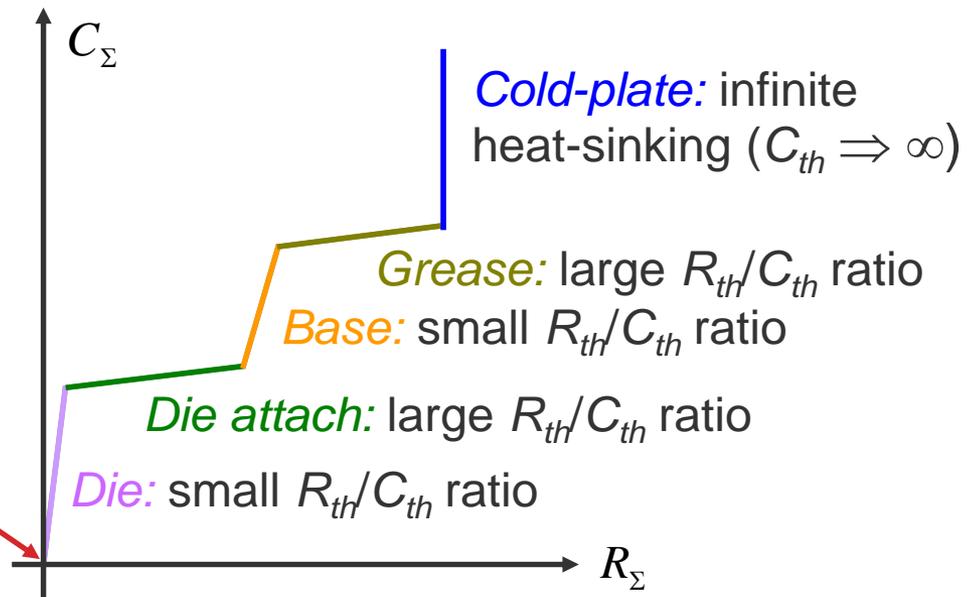
We measure the **thermal transient at the junction...**

...and we convert it into the **cumulative structure function and a compact model:**

Allows structural analysis and modeling...



**Junction:** is always in the origin

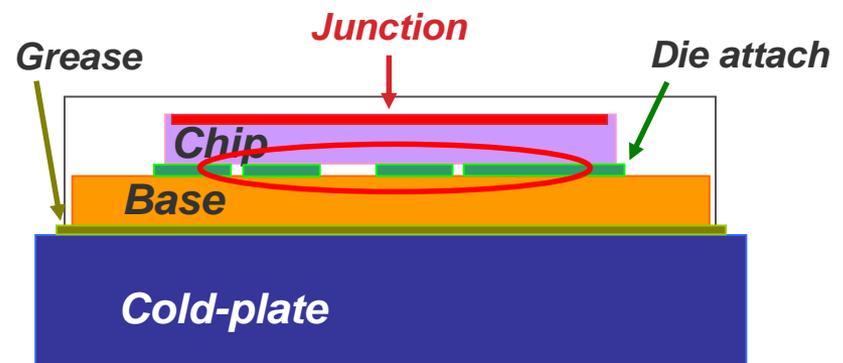
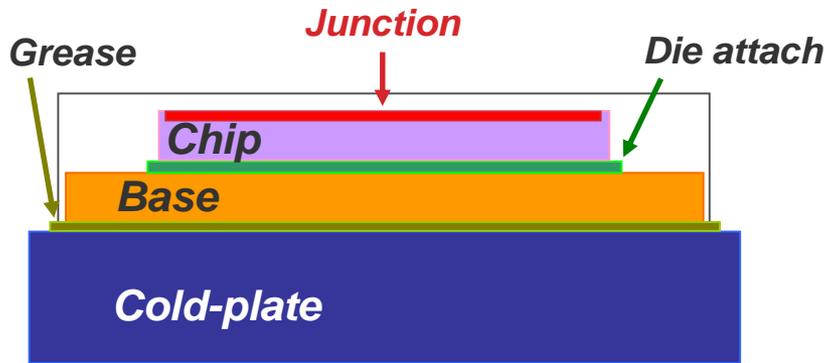


# Application in QA (failure analysis)

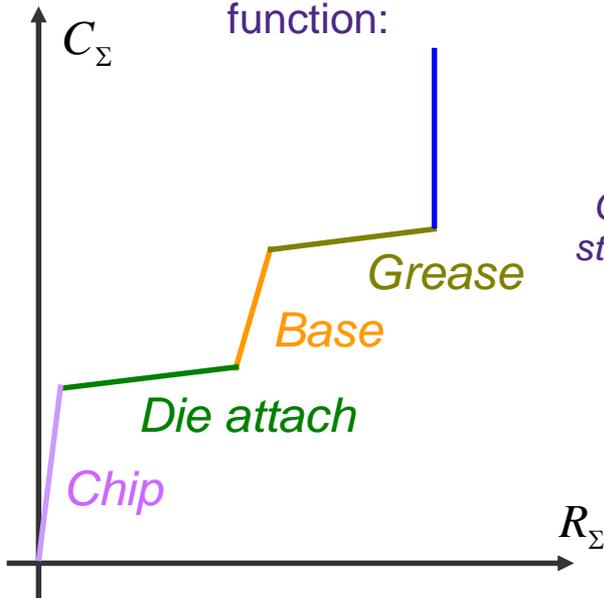
## The Structure Function

Reference device with good DA

Unknown device with suspected DA voids



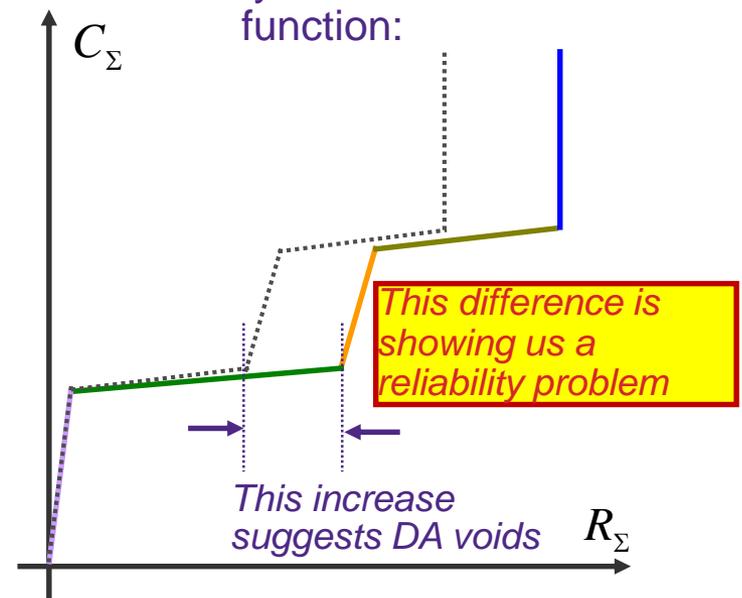
Identify its structure function:



Copy the reference structure function into this plot



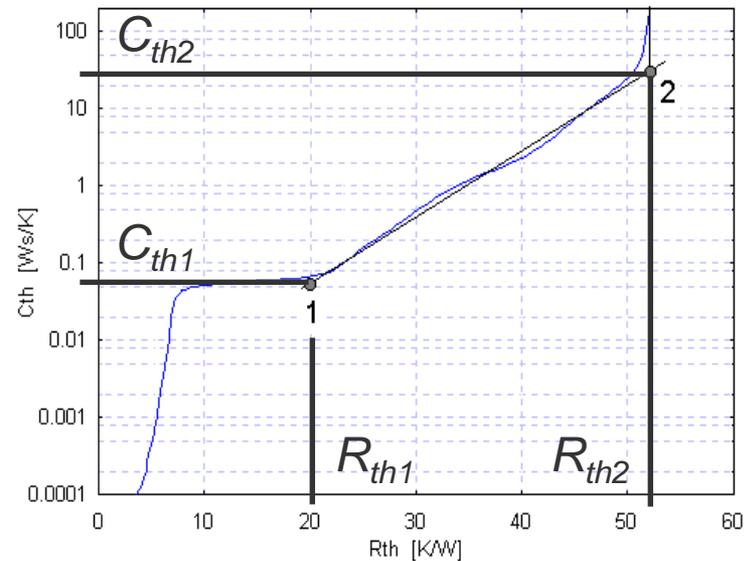
Identify its structure function:

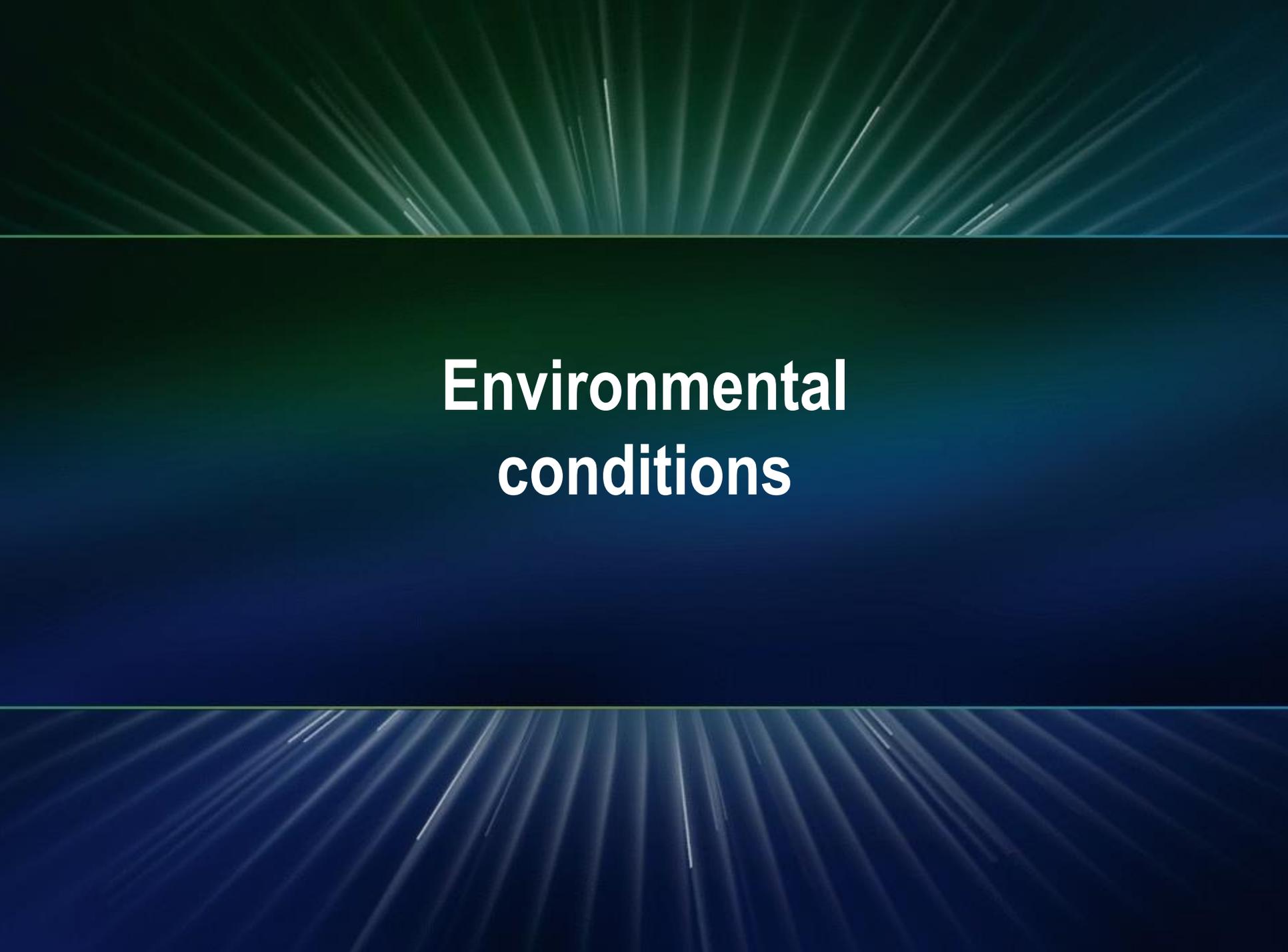


# Features of Structure Functions

- For certain types of 1D spreading, analytical formulae can be given
- For “ideal” cases structure functions can be given even by analytical formulae
  - for a rod:  $C_{\Sigma} = const \cdot R_{\Sigma}$
  - for radial spreading in a disc of  $w$  thickness and  $\lambda$  thermal conductivity:

$$\lambda w = \frac{1}{4\pi} \frac{\ln(C_{th2} / C_{th1})}{R_{th2} - R_{th1}}$$





# **Environmental conditions**

# JEDEC standard test conditions

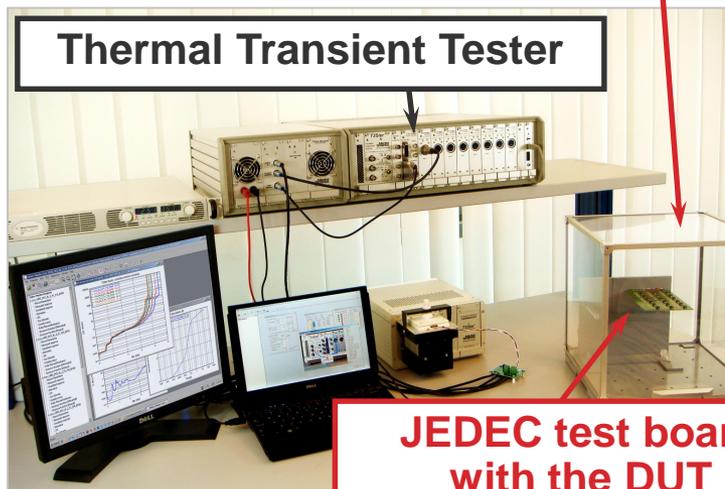
- Besides test equipment, standard test conditions need to be provided
  - test environments
    - natural convection
    - forced convection
    - cold plate
  - device fixtures / test boards

Natural convection: JEDEC JESD51-2A standard

Forced convection: JEDEC JESD51-6 standard

Different test boards: JEDEC JESD51-3, 5, 7, 10, 11

**Still-air chamber**



**Wind tunnel**



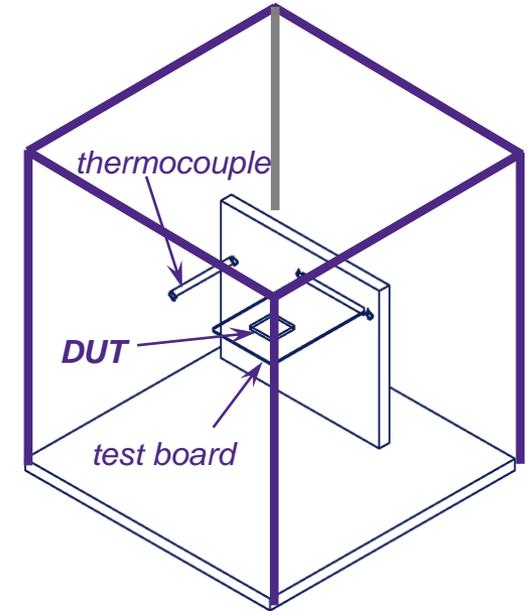
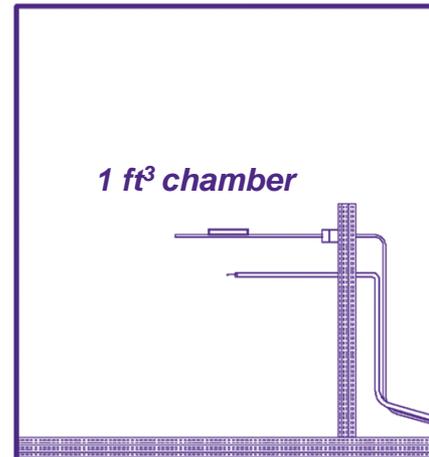
Source of image

[http://www.utacgroup.com/technology\\_contents\\_analysis2.html](http://www.utacgroup.com/technology_contents_analysis2.html)

# Still-air chamber / test board definitions examples

## JEDEC JESD51-2A standard

Low conductivity chamber material  
(e.g. polycarbonat)



## JEDEC JESD51-11 standard



\* = finished thickness:  
2 oz/ft<sup>2</sup> = 70 μm

Figure 1a — Cross section of 1s PCB showing trace and dielectric thicknesses in package placement and trace fan-out regions



\* = finished thickness:  
1 oz/ft<sup>2</sup> = 35 μm  
2 oz/ft<sup>2</sup> = 70 μm

Figure 1b — Cross section of 2s2p PCB showing trace and dielectric thicknesses

Table 1 — PCB sizes for packages

Package Length	PCB Size (+/- 0.25 mm)
Pkg. Length ≤ 40 mm	101.5 mm x 114.5 mm (4.0 in x 4.5 in)
40 mm < Pkg. Length ≤ 65 mm	127.0 mm x 139.5 mm (5.0 in x 5.5 in)
65 mm < Pkg. Length ≤ 90 mm	152.5 mm x 165.0 mm (6.0 in x 6.5 in)

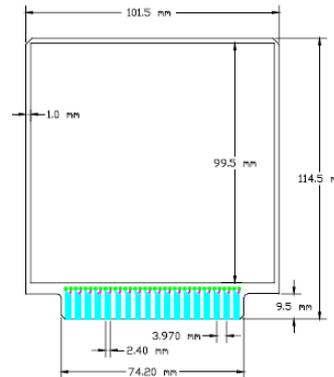


Figure 2 — Example test board outer dimensions and edge connector design

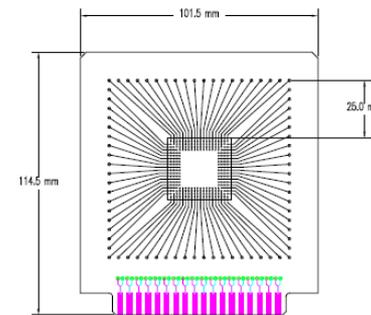


Figure 3 — Traces to outer pin row flared to perimeter 25 mm from package body.

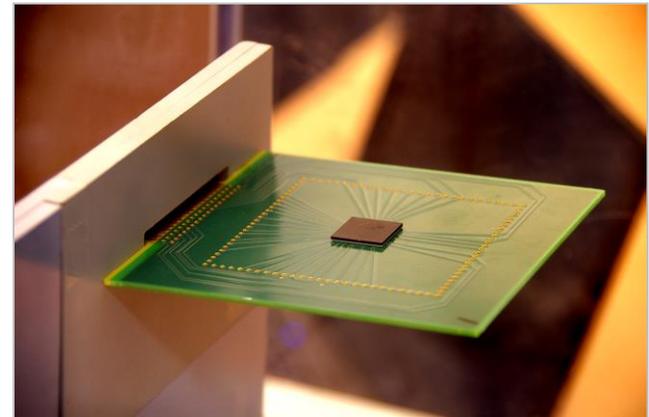
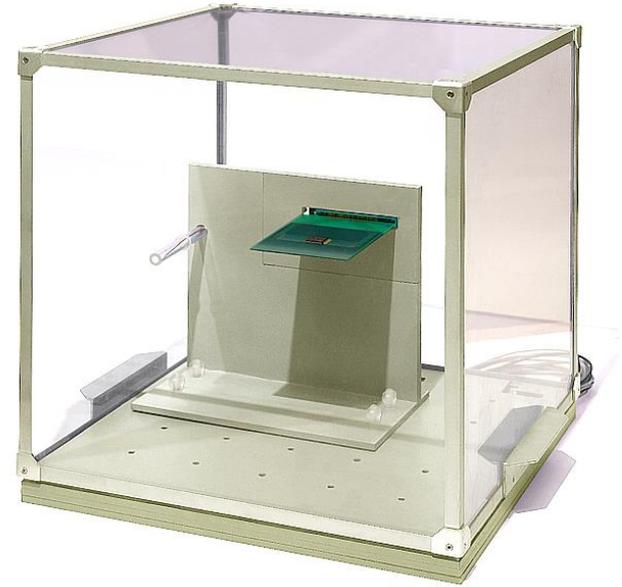
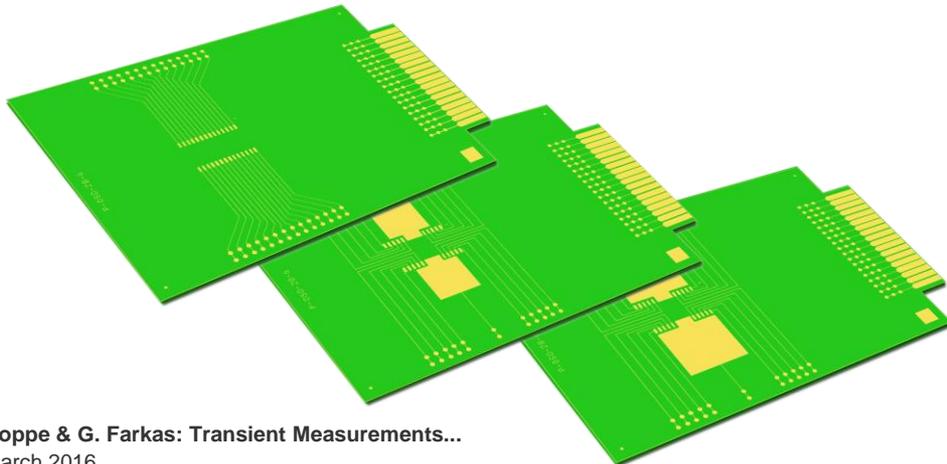
# JEDEC standard test conditions

## ■ Test environments

- natural convection: 1 ft<sup>3</sup> still-air chamber: **JESD51-2A** (2008)
- forced convection: wind tunnel **JESD51-6** (1999)

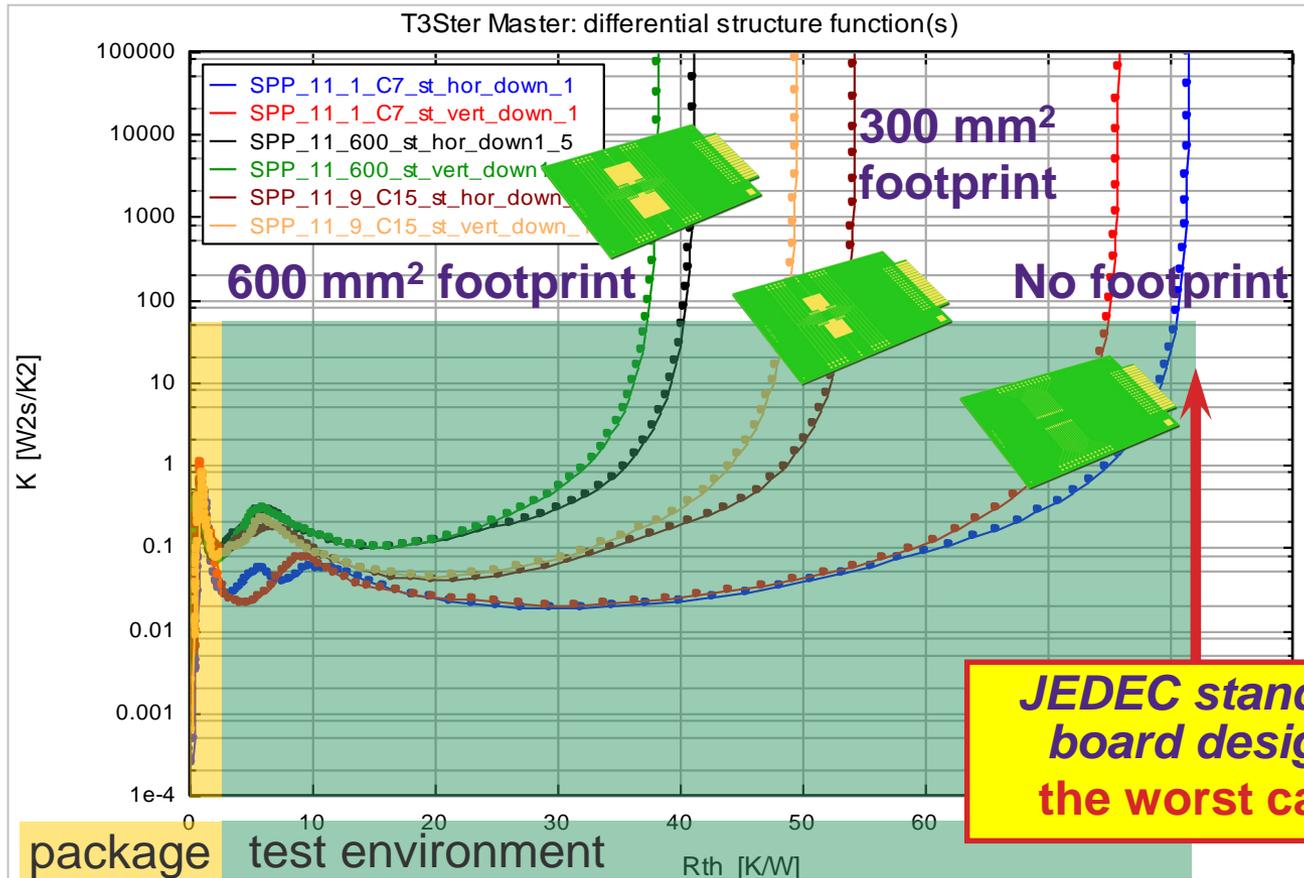
## ■ Test boards

- copper coverage / number of layers
  - high / low conductivity, 1s / 2s
- different designs matching different package styles
- design / orientation counts a lot, as shown by structure functions



# Effect of test board design / orientation

- Tests performed in a JEDEC standard still-air chamber
- Measured transients converted to structure functions



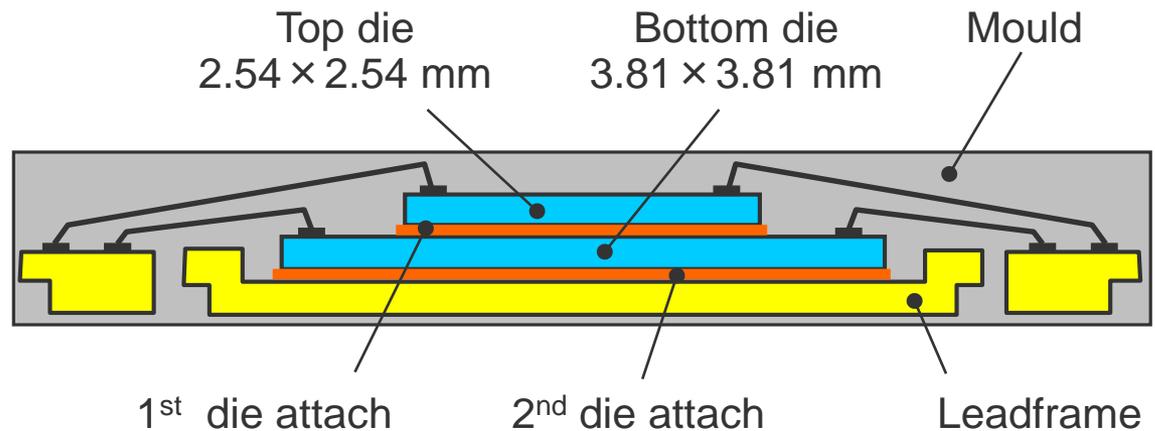
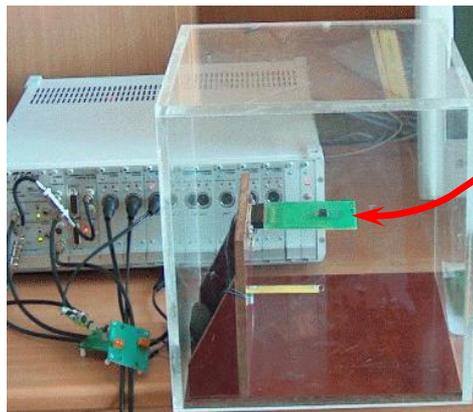
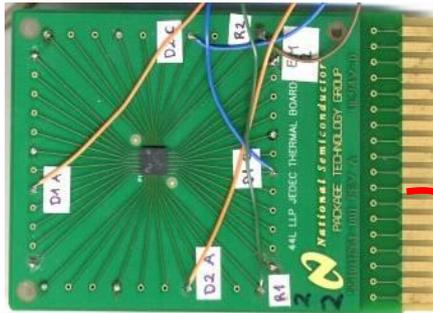
**Board design (Cu area of footprint region) and board position (vertical or horizontal) strongly effects the ultimate  $R_{thja}$  value**

**JEDEC standard board design: the worst case**

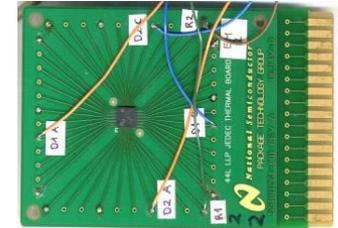
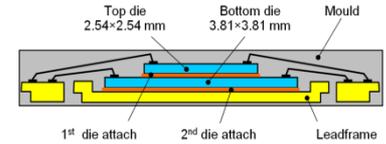
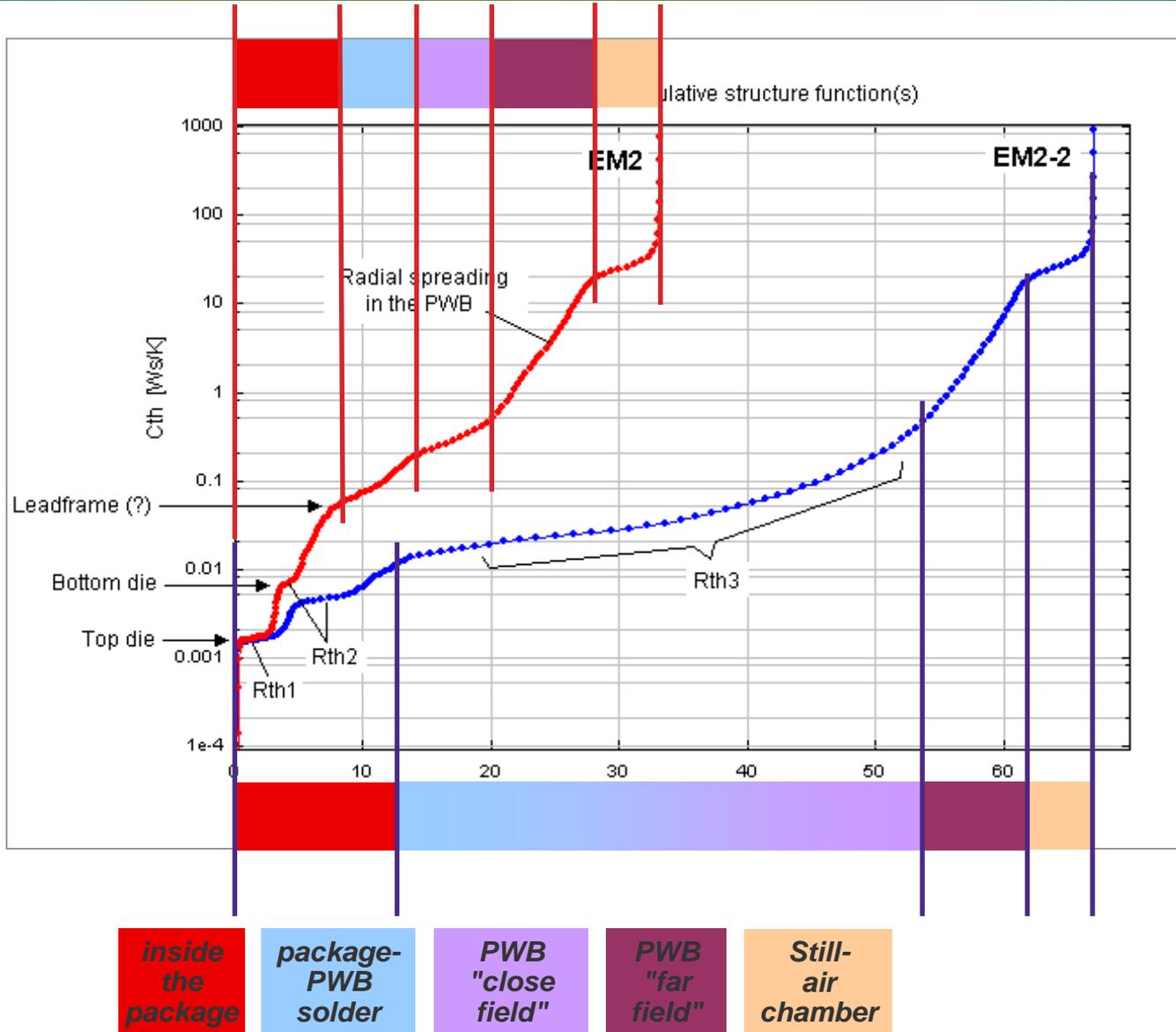
- Measured  $R_{th}$  is mostly due to the test environment
  - measure on cold plate if possible, it is also faster

# Two live chips stacked in a 44L LLP package

- Stacked die package tested in JEDEC standard test environment
- Transient extension of the JESD51-1 static test method was used (**T3Ster** equipment), followed by structure function analysis



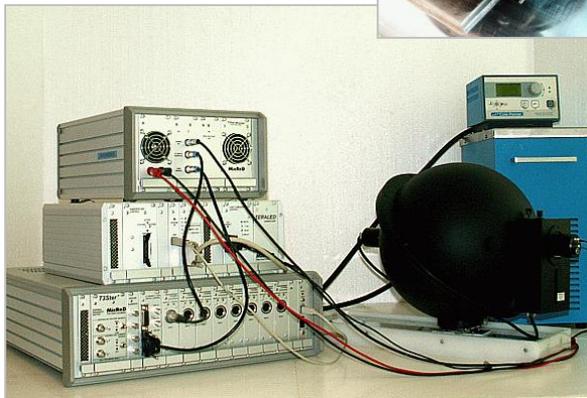
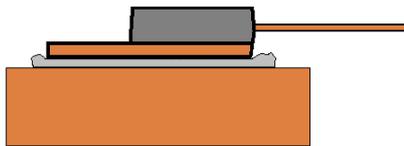
# Results in terms of structure functions



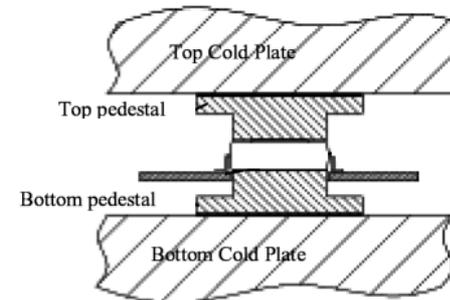
Majority of the  $R_{thja}$  is caused by the JEDEC standard test environment.

# Cold plate as a test environment

- Single cold plate setups for  $R_{thJC}$  measurements
  - also, test based models of power packages (transient extended JEDEC 2R models)
  - LED testing
- Quicker test, shorter heat-flow path, results are characteristic to the package



- Dual cold plate setups for DELPHI boundary conditions
  - validation of detailed models of test set of boundary conditions
  - DCP1, DCP2, DCP3, DCP4 setups

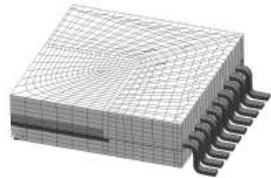
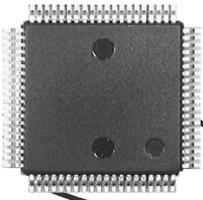


# Test based model validation: for DELPHI models

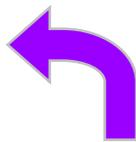
Automated process now in FloTHERM v11

Real package

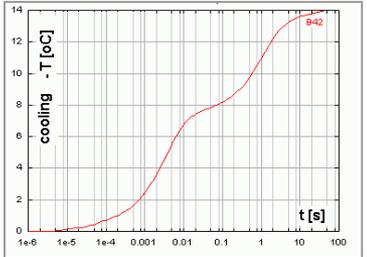
T3Ster



Detailed package model



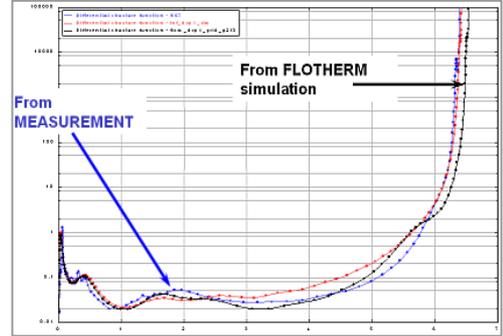
Thermal transient measured by T3Ster



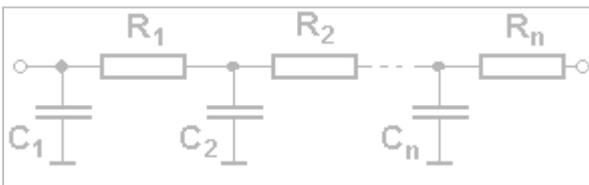
FloTHERM

Structure functions for validation of detailed models

T3Ster software



Structure functions for test based compact model generation



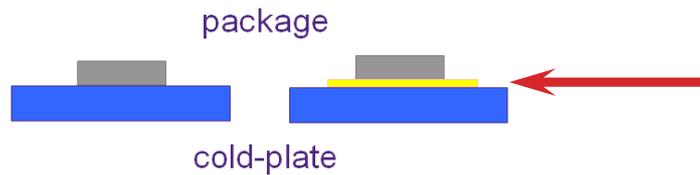
This model structure is characteristic to power semiconductor packages

FloTHERM

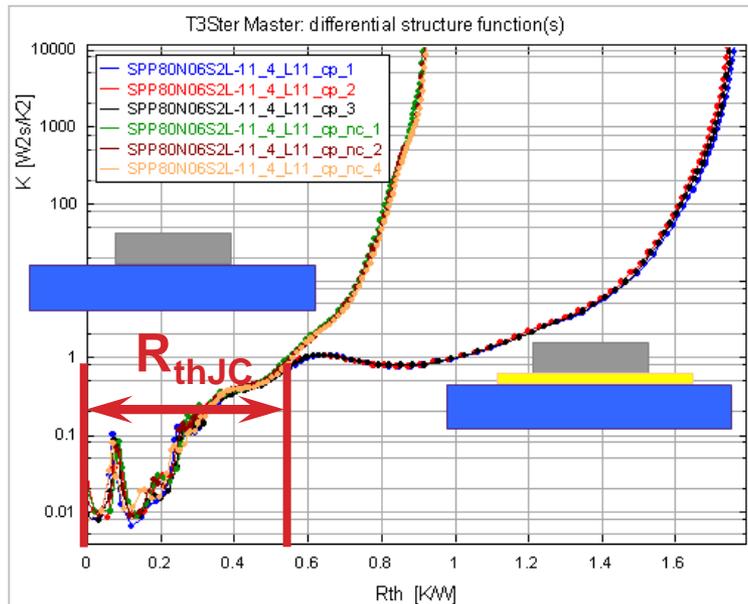
**The process of finding the  $R_{thJC}$   
value in T3Ster Master 2.x  
according to the new JEDEC  
standard JESD51-14**

# The transient dual interface method for $R_{thJC}$

- Original idea from 2005, **standard JESD51-14 published in November 2010**
- Change of thermal interface quality at the ‘case’ surface
- Divergence point in measured structure functions: ‘case’ surface



Change the quality of the thermal interface  
Measurement of 2 setups (2x3 min), **structure functions**



**SEMI-THERM 2005 Best Paper Award**

Methodology for single-chip and lateral or stacked multi-chip structures

SEMI-THERM 21, March 15 – 17, 2005, San José, California

Oliver Steffens<sup>1</sup>, Péter Szabó<sup>2</sup>,  
Michael Lenz<sup>3</sup>, Gábor Farkas<sup>2</sup>

<sup>1</sup>Infineon Technologies AG, Ratisbon, Germany  
<sup>2</sup>MicReD Ltd., Budapest, Hungary  
<sup>3</sup>Infineon Technologies AG, Munich, Germany

**Infineon**

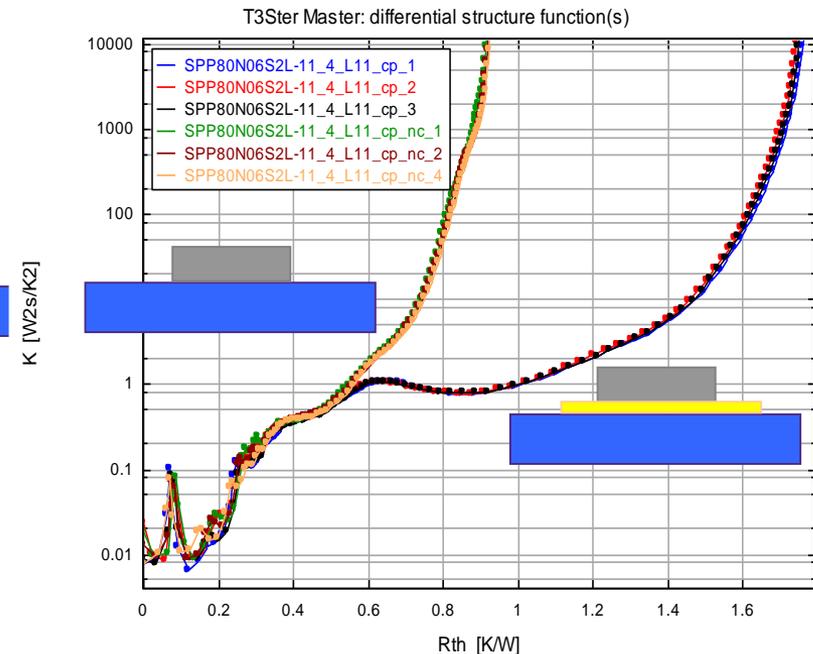
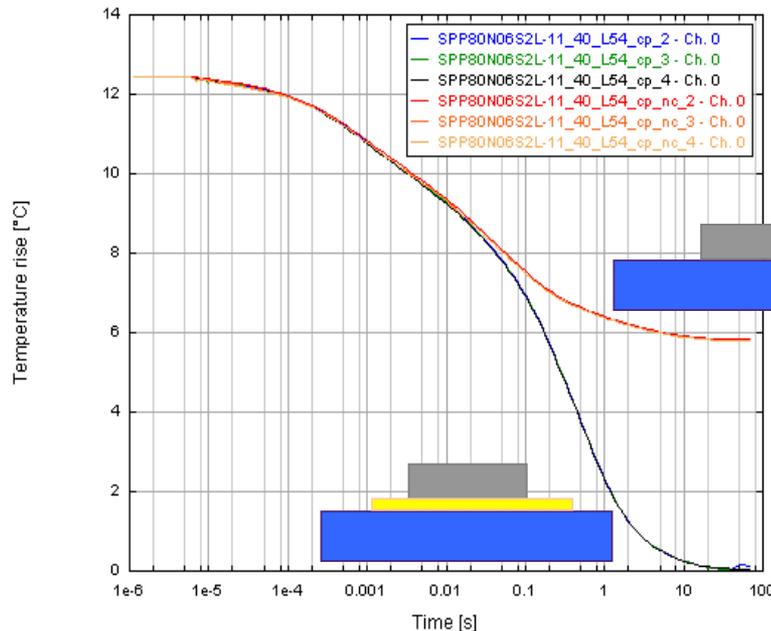
MicReD  
The Cool Company

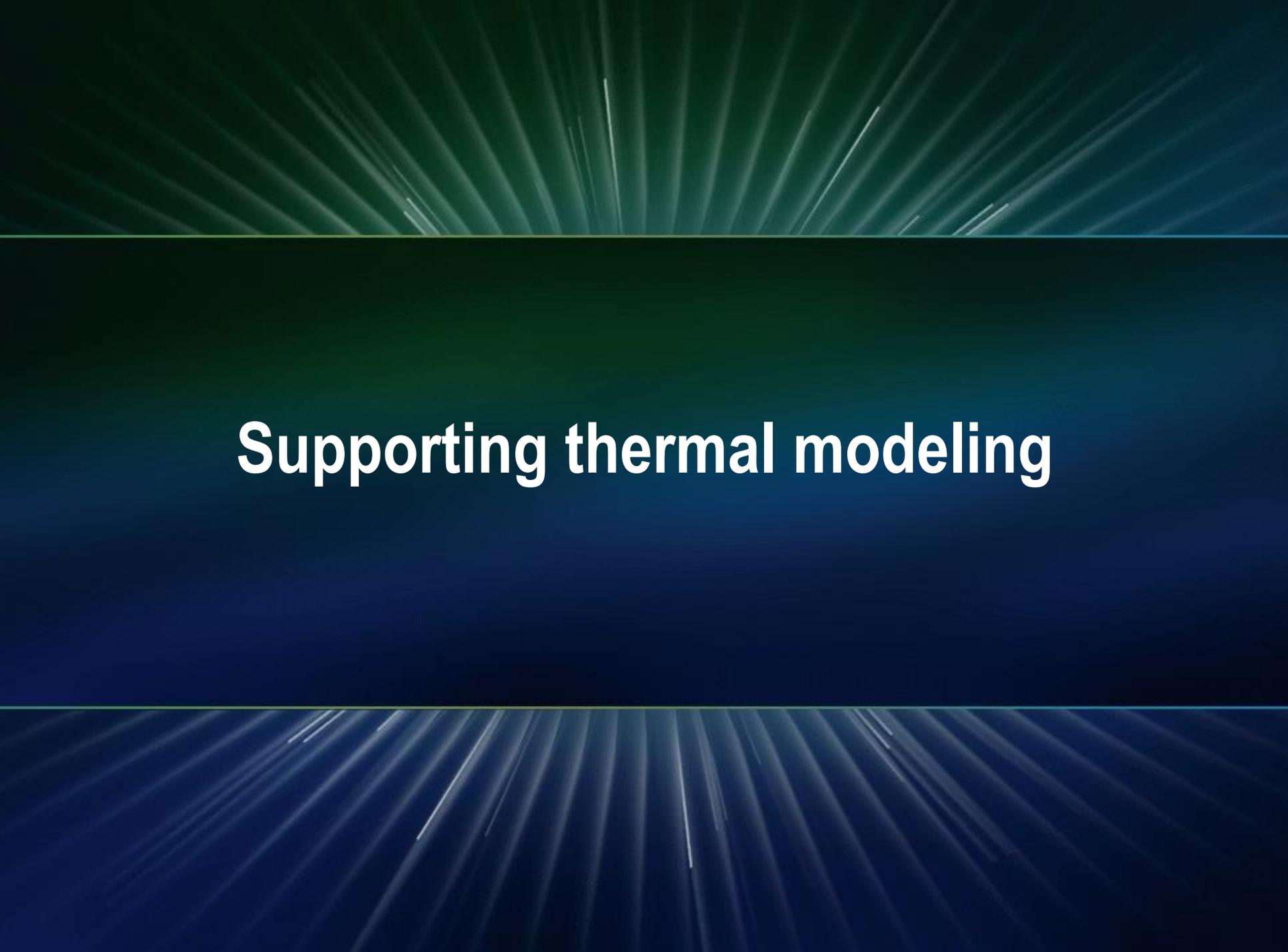
infineon  
technologies

Never stop thinking.

# High accuracy and repeatability

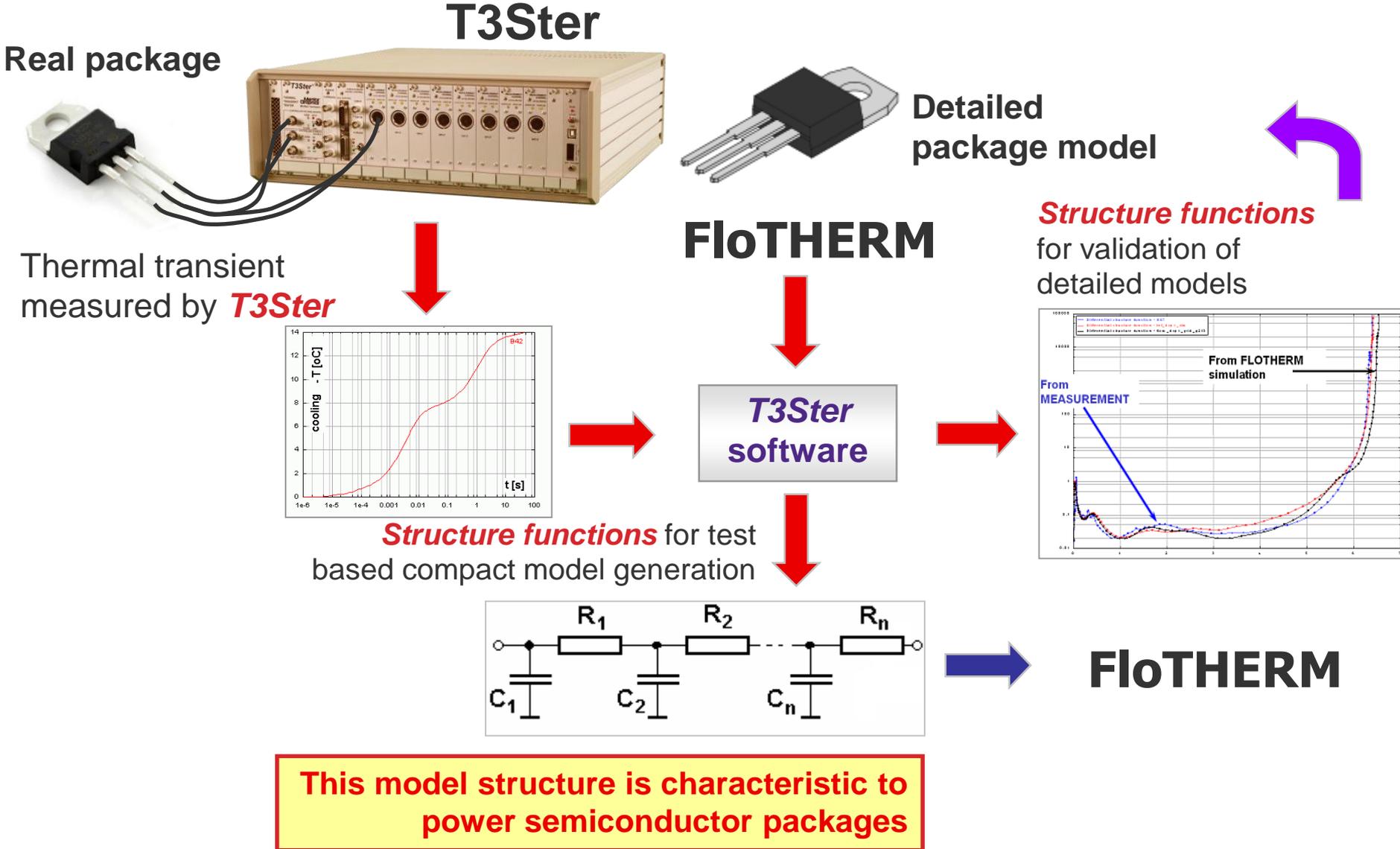
- This type of  $R_{thJC}$  measurement provides high repeatability
  - the continuous measurement of thermal transients is very reliable and highly repeatable if the setup is not changed
  - repeatability is also high among different samples
  - structure functions are derived from the transients by a mathematically well defined numerical procedure, thus, resulting structure functions are also highly repeatable





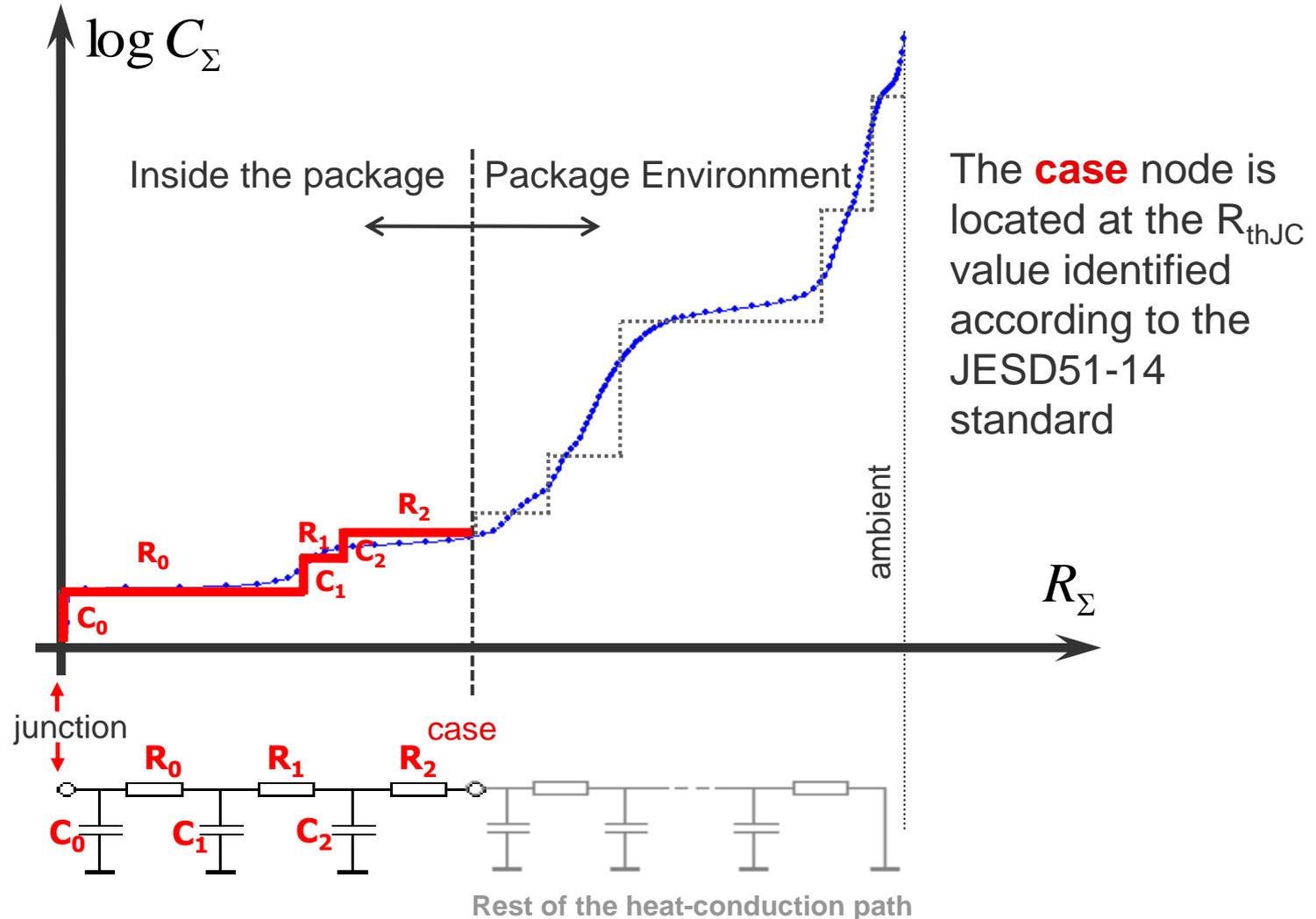
# Supporting thermal modeling

# Test based modeling and model validation



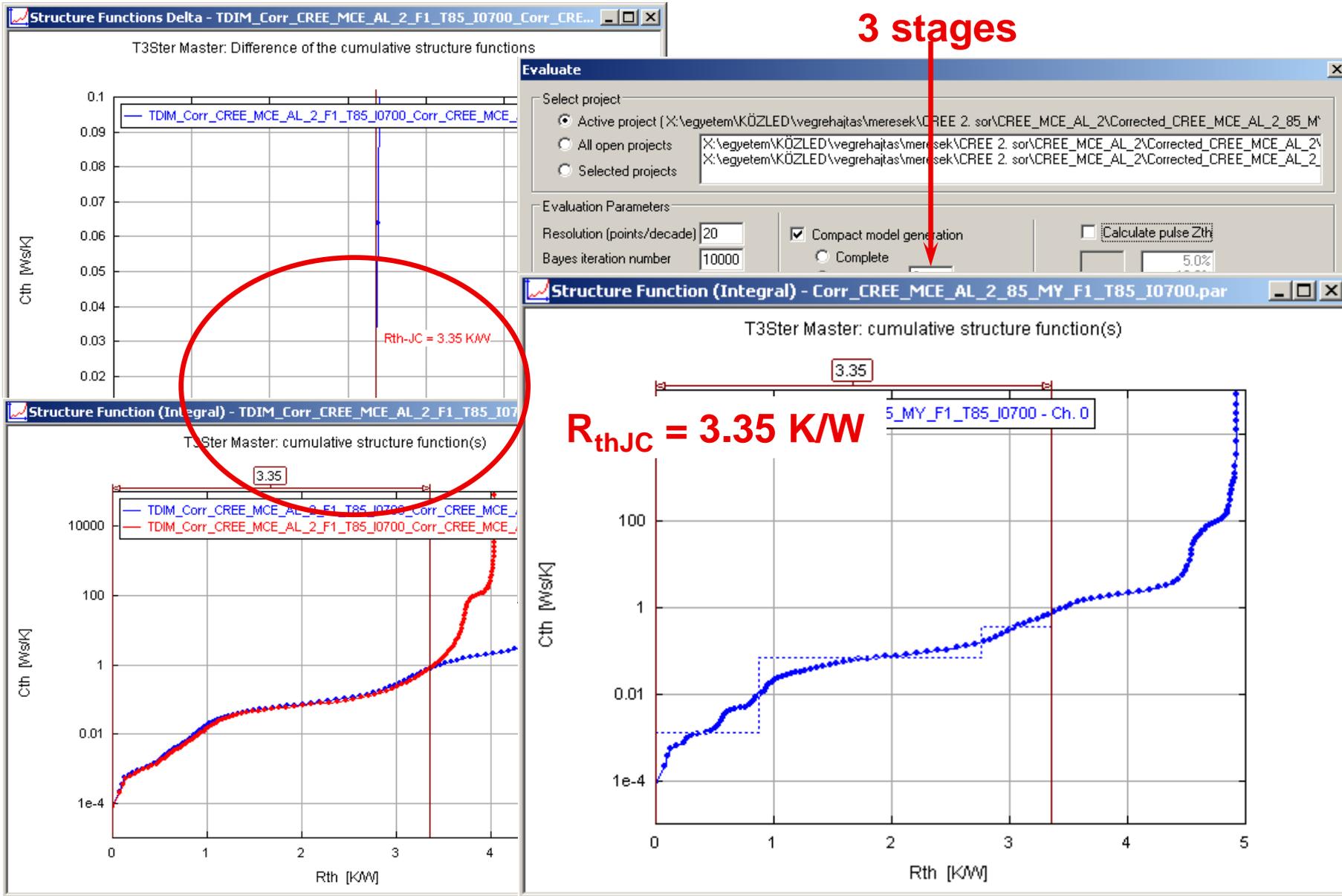
# T3Ster Master → FloTHERM Interface

- Compact thermal model of the heat-flow path is created by a step-wise approximation of the structure function



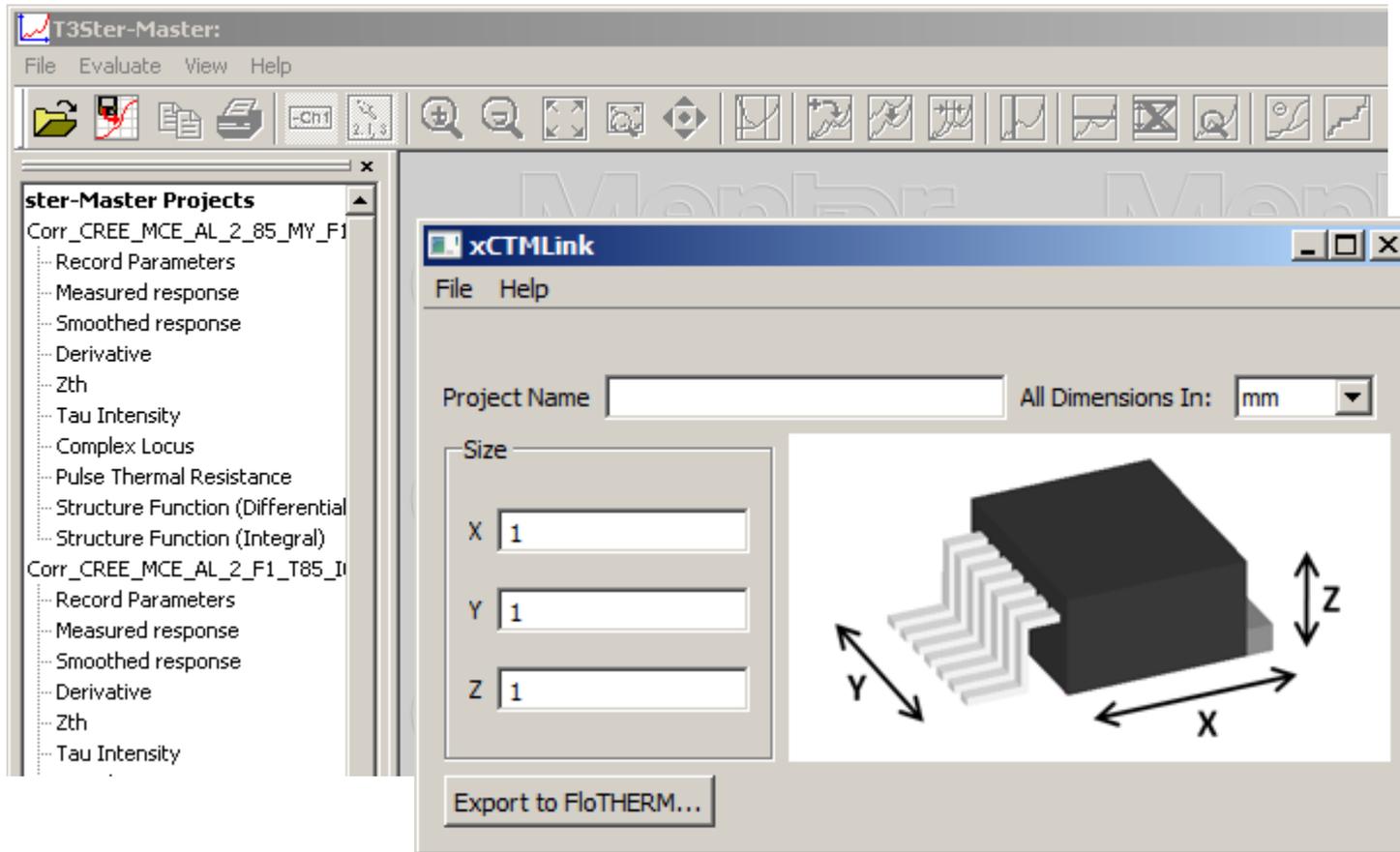
The **case** node is located at the  $R_{thJC}$  value identified according to the JESD51-14 standard

# Creating compact models in general



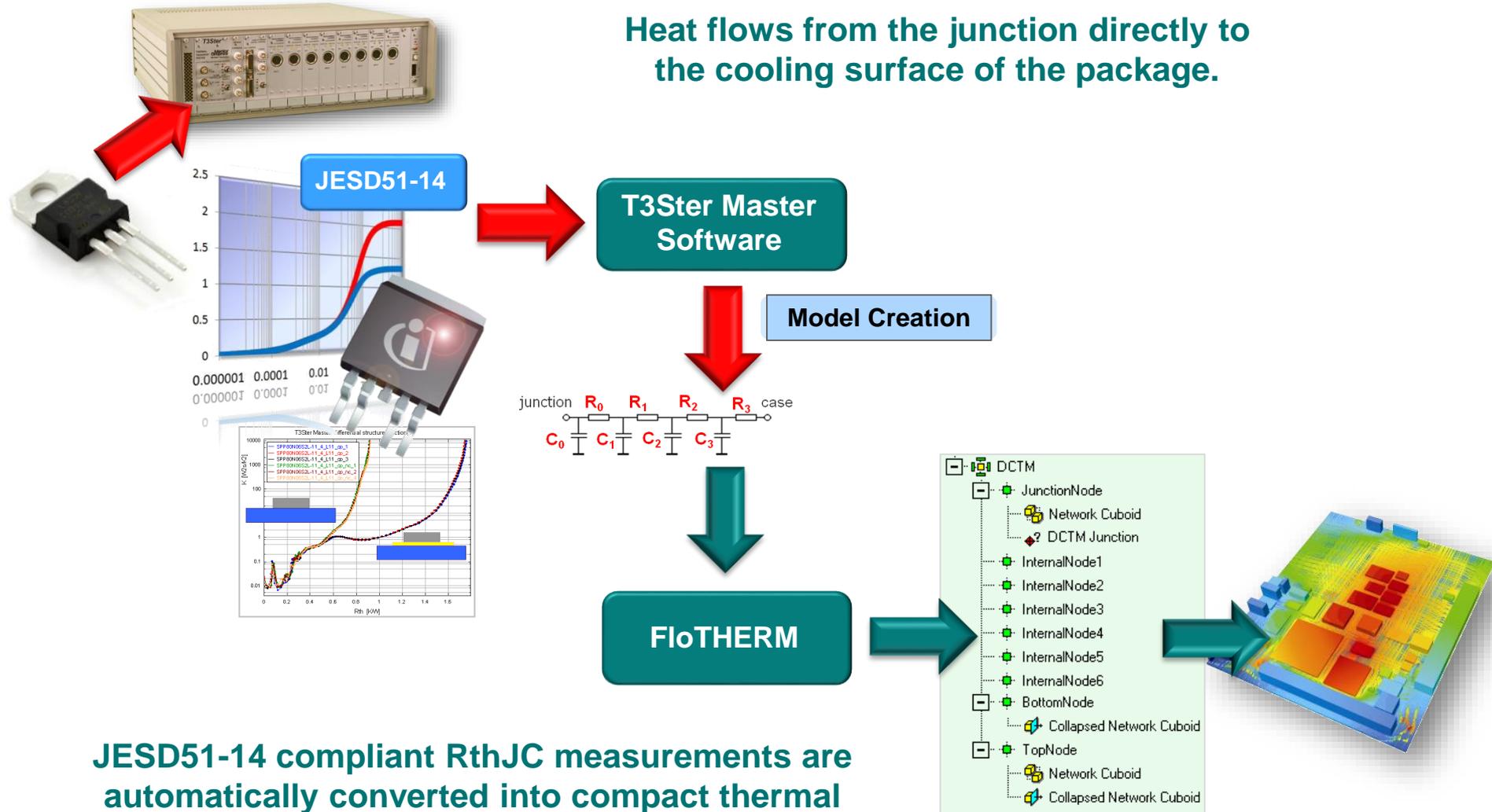
# Creating compact models for FloTHERM

- Package geometry specified on file export from **T3Ster Master**



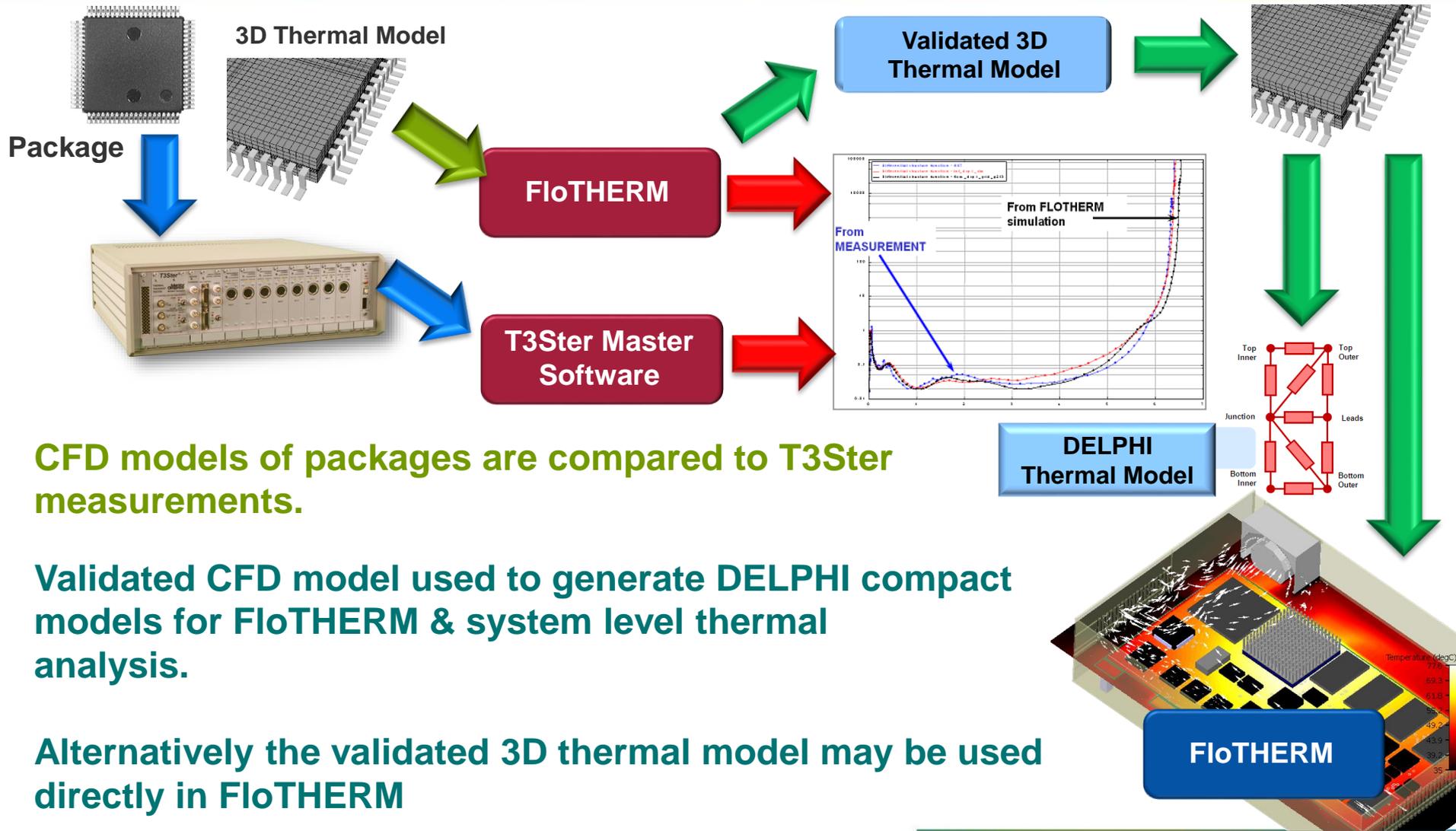
# First and Unique Fully Automatic Measurement-Based Modeling of Power Semiconductor Packages

Heat flows from the junction directly to the cooling surface of the package.



JESD51-14 compliant RthJC measurements are automatically converted into compact thermal models used in FloTHERM.

# First and Unique Measurement and Model Validation of IC Device Packages



CFD models of packages are compared to T3Ster measurements.

Validated CFD model used to generate DELPHI compact models for FloTHERM & system level thermal analysis.

Alternatively the validated 3D thermal model may be used directly in FloTHERM



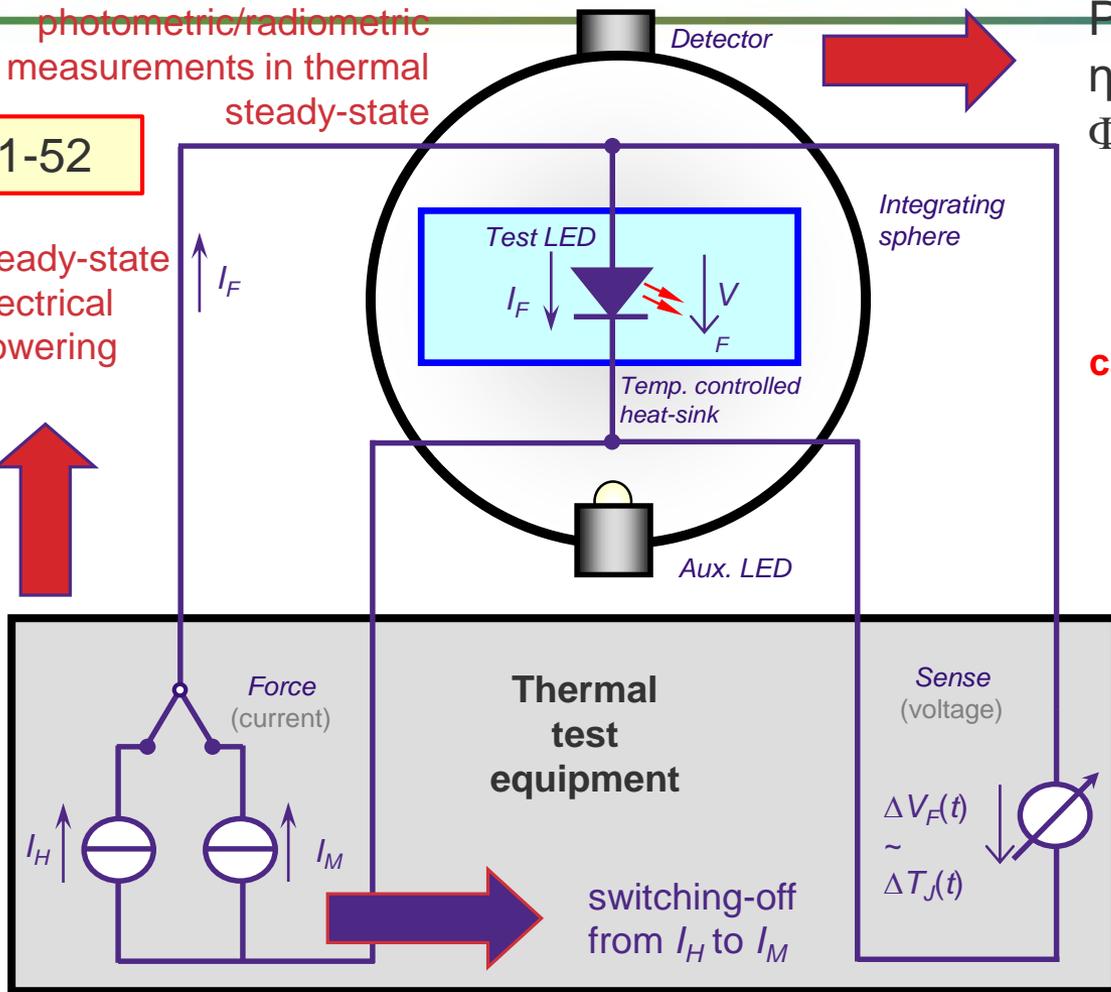
**Special environment for  
power LEDs:  
cold-plate and integrating  
sphere**

# Test environment for LEDs: cold-plate and sphere

photometric/radiometric measurements in thermal steady-state

JESD51-52

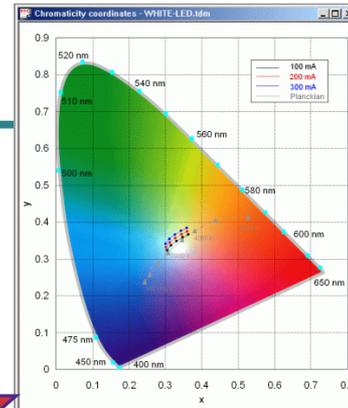
steady-state electrical powering



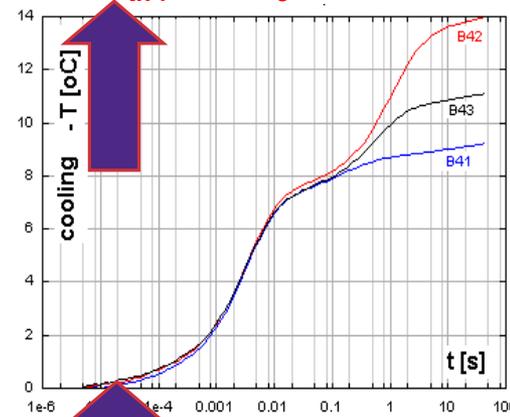
$$P_{opt}(T, I_F)$$

$$\eta_e(T, I_F)$$

$$\Phi_V(T, I_F)$$



calculate  $R_{th-r}$  and  $T_J$

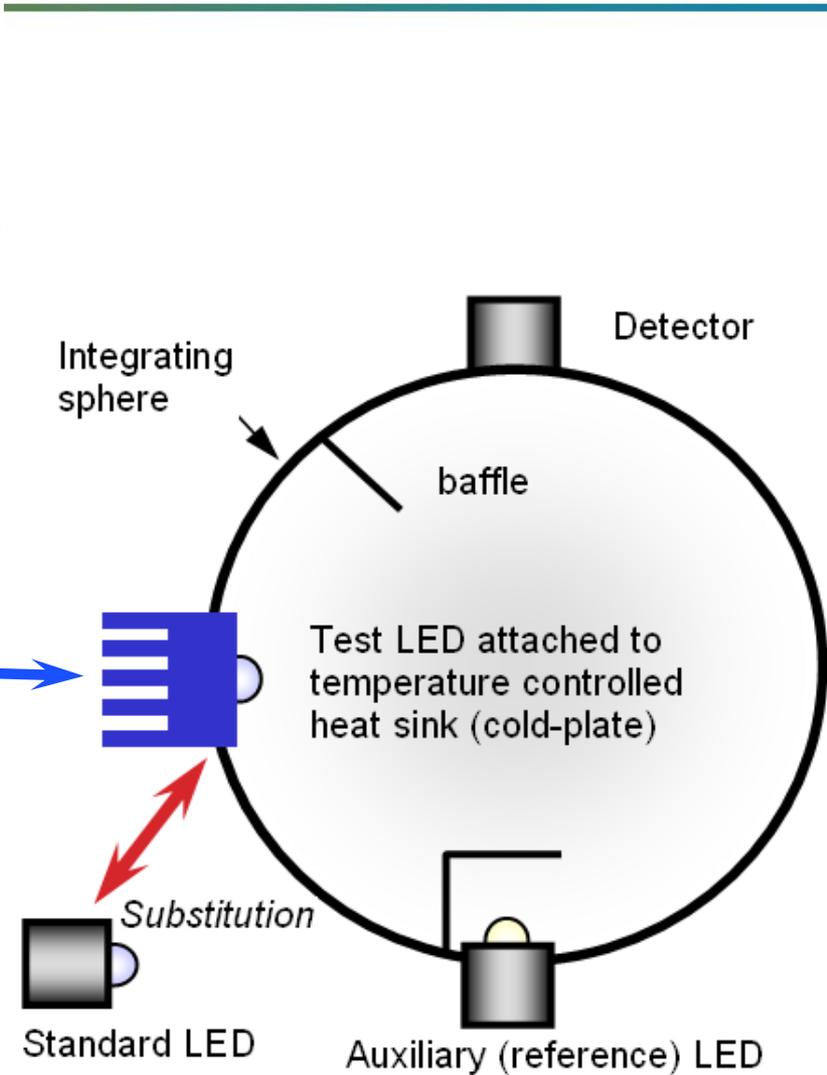
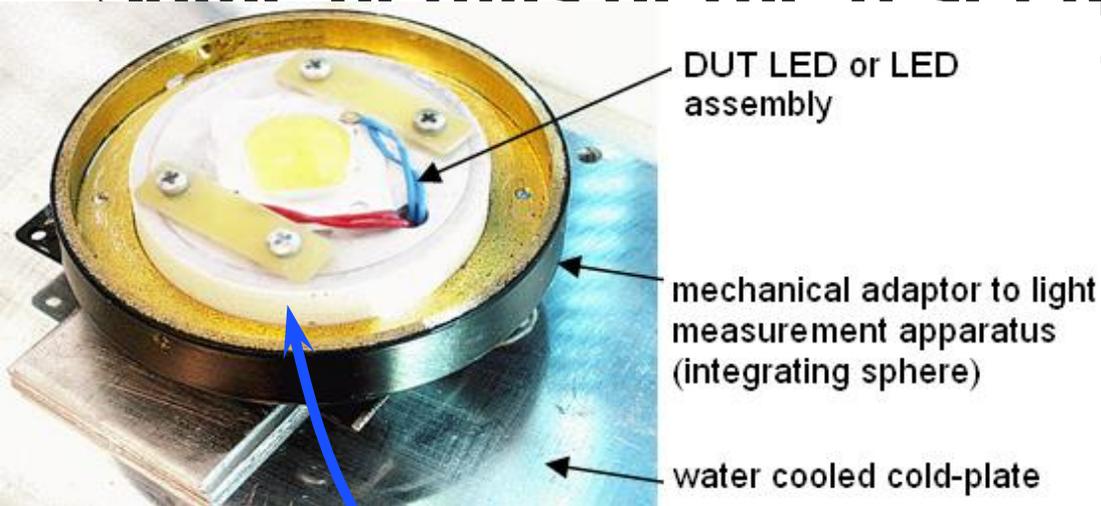


thermal resistance/impedance measurement

JESD51-51

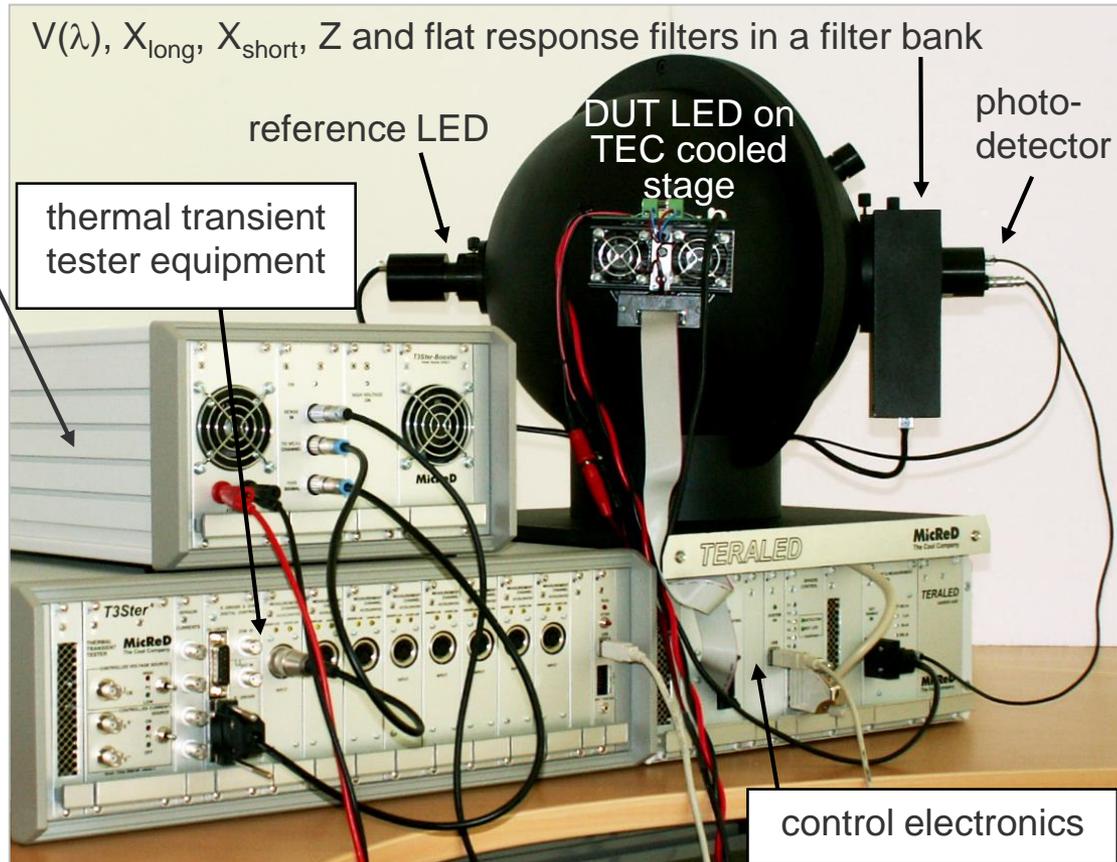
JEDEC JSD51-1 static test method compliant thermal measurement system

# Some details of the test environment

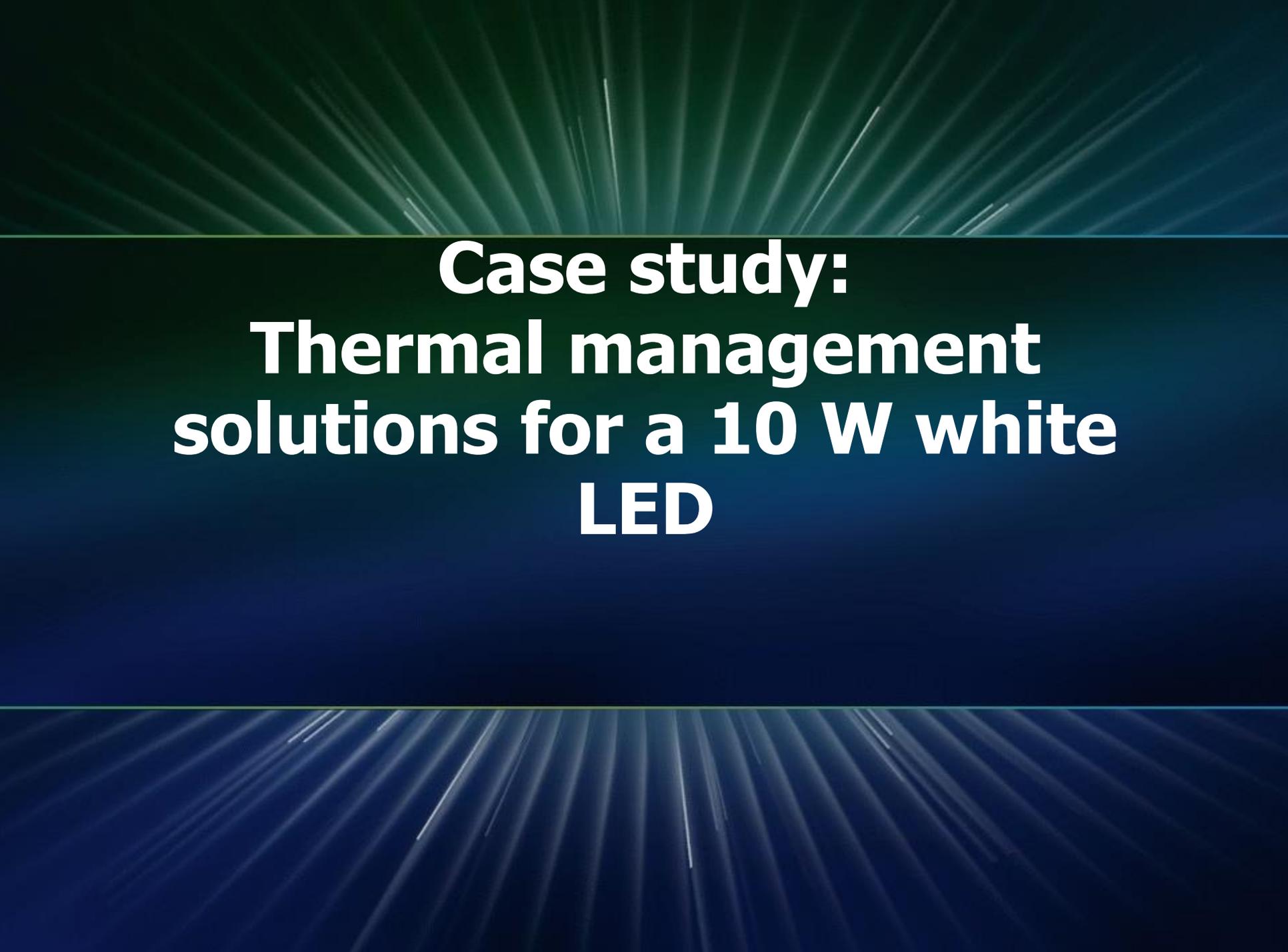


# The Mentor Graphics MicReD implementation:

Special LED booster: allows high voltage across a LED line (overall forward voltage can reach 280V).



It can be added to the system in a plug&play manner if the voltage of the base tester is not sufficient.

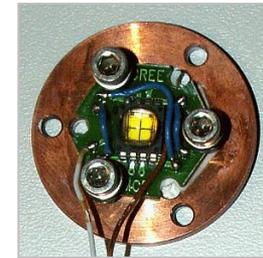
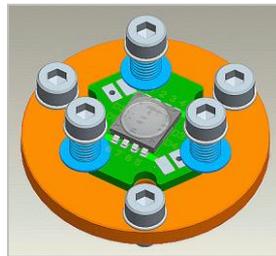
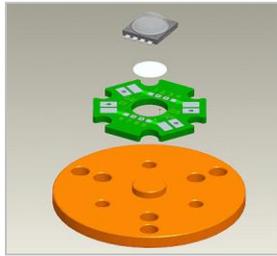


**Case study:  
Thermal management  
solutions for a 10 W white  
LED**

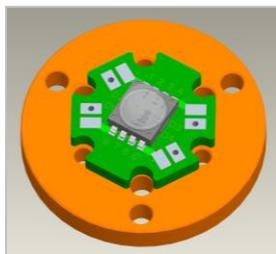
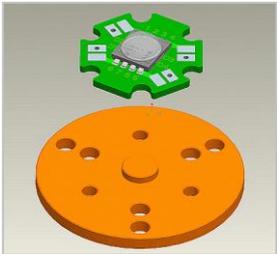
# Case study: 3 setups with Cree MCE 10W

## LEDs different kinds of assemblies:

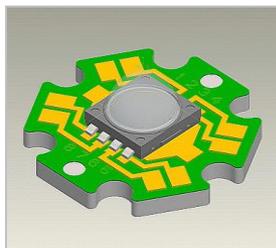
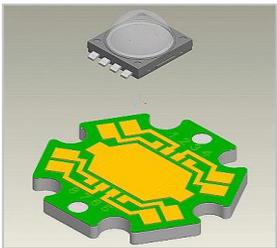
— FR4 PCB, TIM between the heat-slug and the Cu block



— FR4 PCB, heat-slug soldered to the Cu block



— MCPCB-s made of Al and Cu, heat-slug soldered

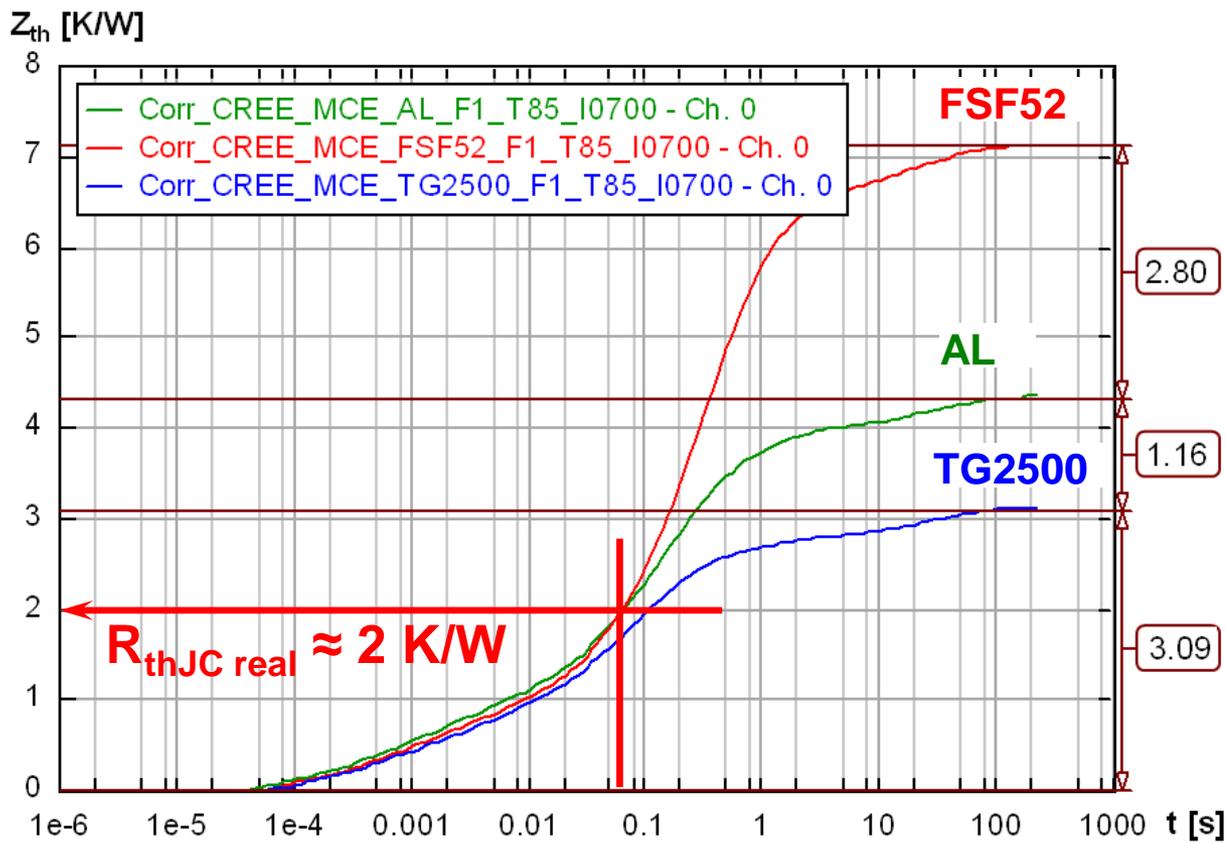


CAD images by courtesy of OptimalOptik Ltd. (Budapest, Hungary), measurements by Budapest University of Technology and Economics (BME).

# Results for 10W Cree MCE white LEDs

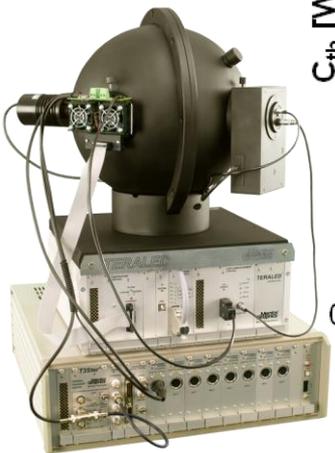
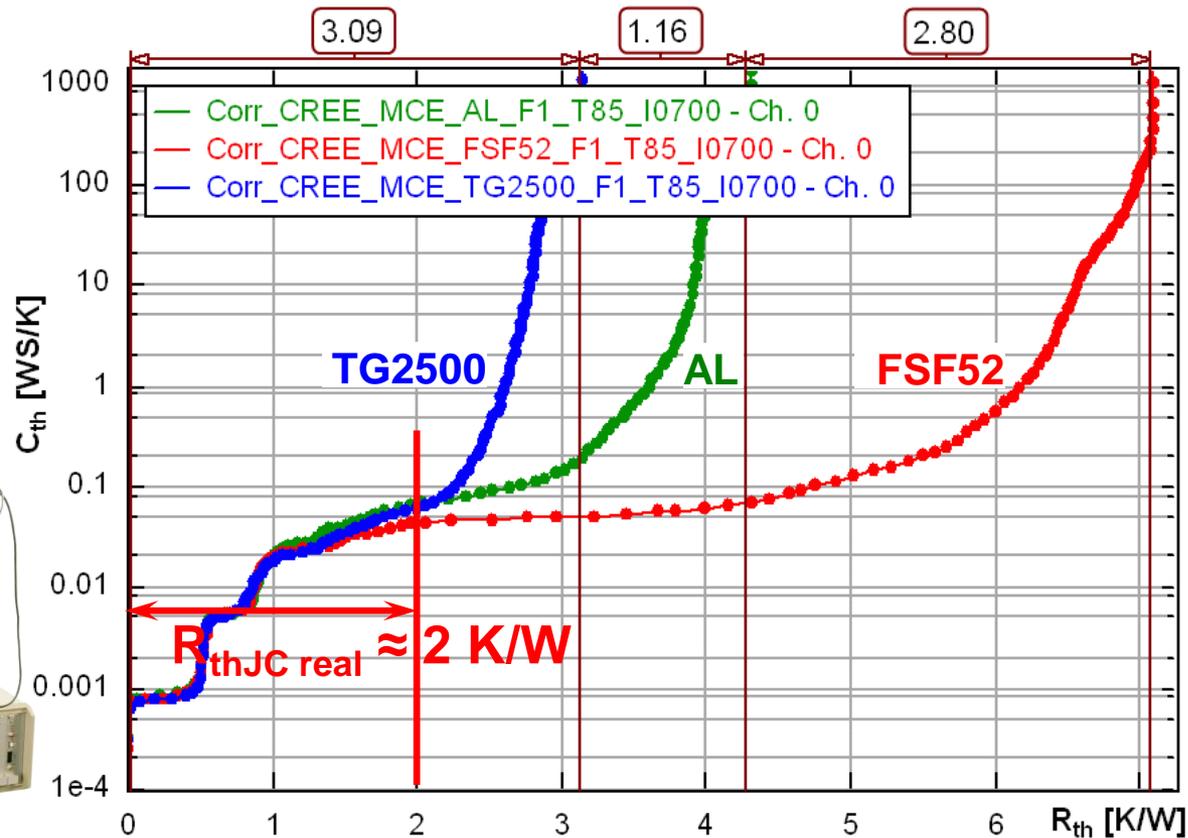


— Thermal impedance of 3 samples, power corrected with  $P_{opt}$



# Results for 10W Cree MCE white LEDs

— Structure functions of 3 samples, power corrected with  $P_{opt}$

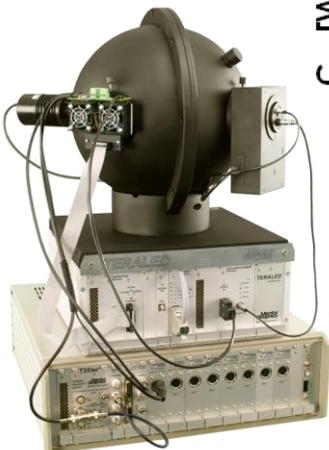
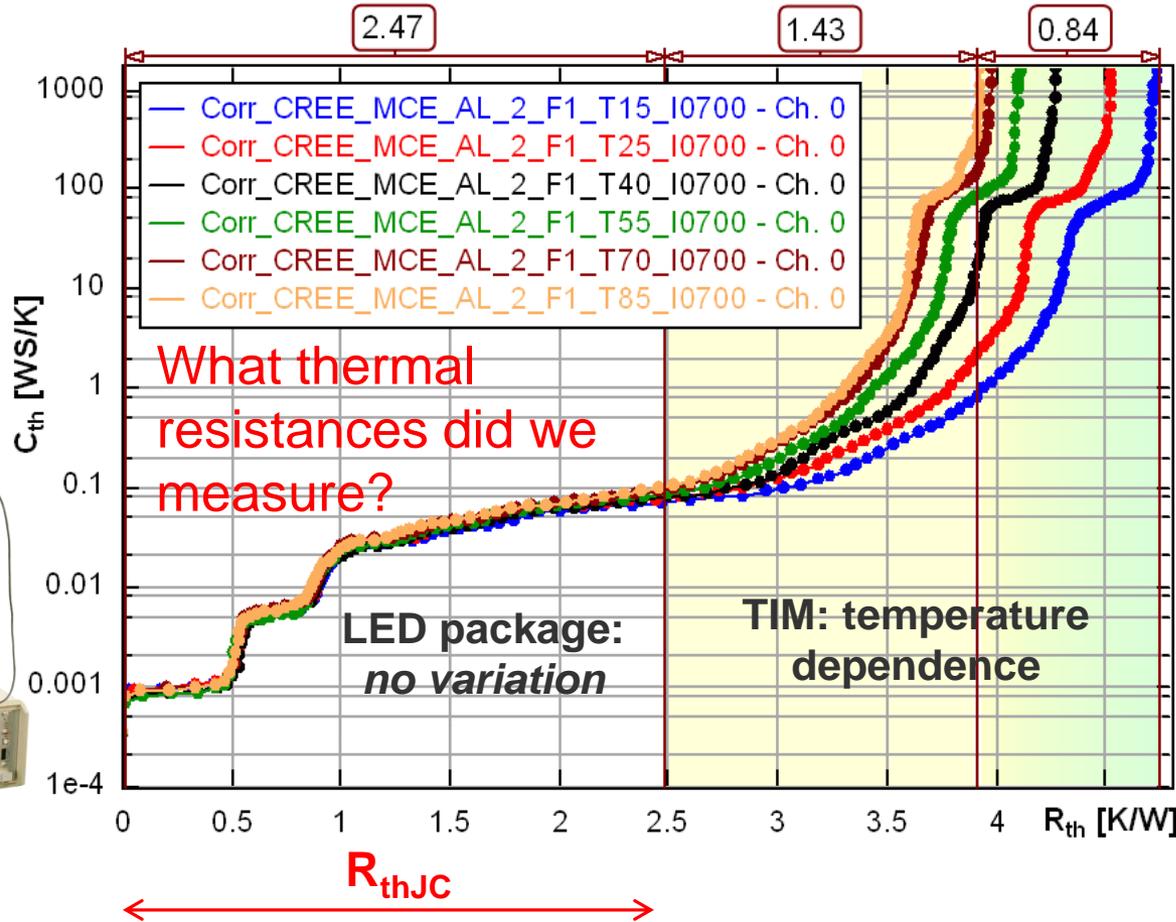


—  $R_{thJC}$  is identified in a way similar to the *transient double interface method*, also being standardized by the JEDEC JC15 committee

# Results for 10W Cree MCE white LEDs



— Structure functions of sample AL-2, power corrected with  $P_{opt}$



We measured the  $R_{thJC}$  of the package and the TIM resistance

**Modeling and industrial QA  
analysis of IGBTs and other power  
component in the 1500 A ... 3000 A  
range**

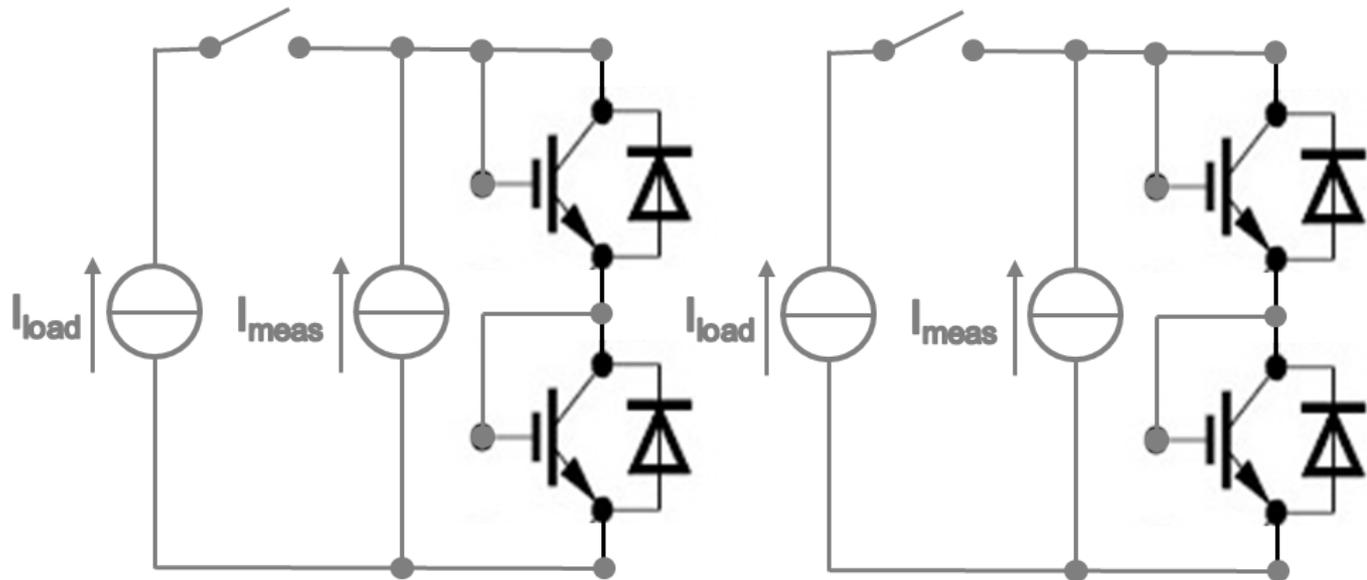
# Testing an IGBT module with kW level of power

- In power electronics industry both proper thermal design and reliability analysis of components such as IGBT modules is needed
- These tests need to be performed under realistic conditions
  - 500 A ... 1500 A ... 3000 A of current needs to be supplied
  - This results in multiple kW-s of heat to handle (needs proper cooling)
- MicReD industrial testing series of solutions
  - Test conditions meet industrial requirements
    - Powering
    - Cooling
    - Safety
  - Automated tests
    - Setup
    - In-situ degradation monitoring
    - Stop criteria

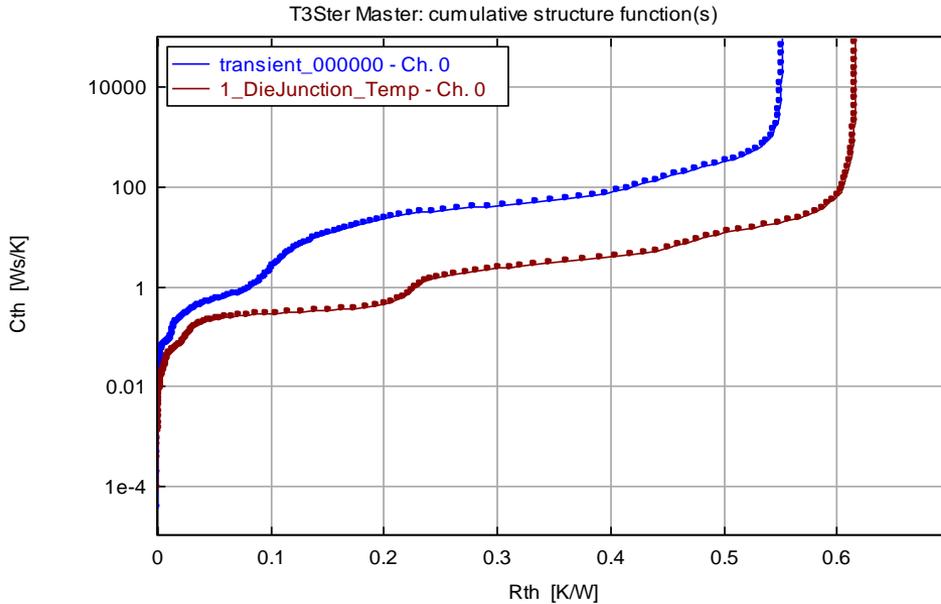


# Test conditions for the half bridge modules

- Devices mounted on a cold-plate with highly stable thermal pad
- Gate and drain electrodes interconnected
- Common powering, but each device connected to a T3Ster channel



# Model calibration

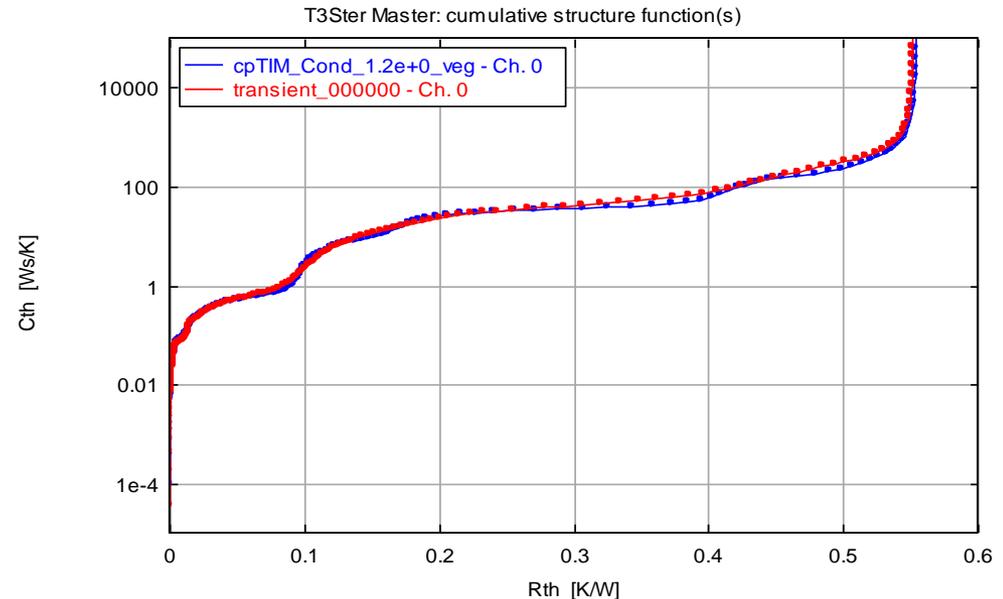


## Initial model

### Calibration steps:

1. Die material parameters
2. Die-source geometry
3. Die attach resistance
4. Conductivity of the ceramics
5. TIM between copper and cold-plate

## Calibrated model



## Automated process in FloTHERM v11.

Learn about this in detail in Mentor Graphics' workshop

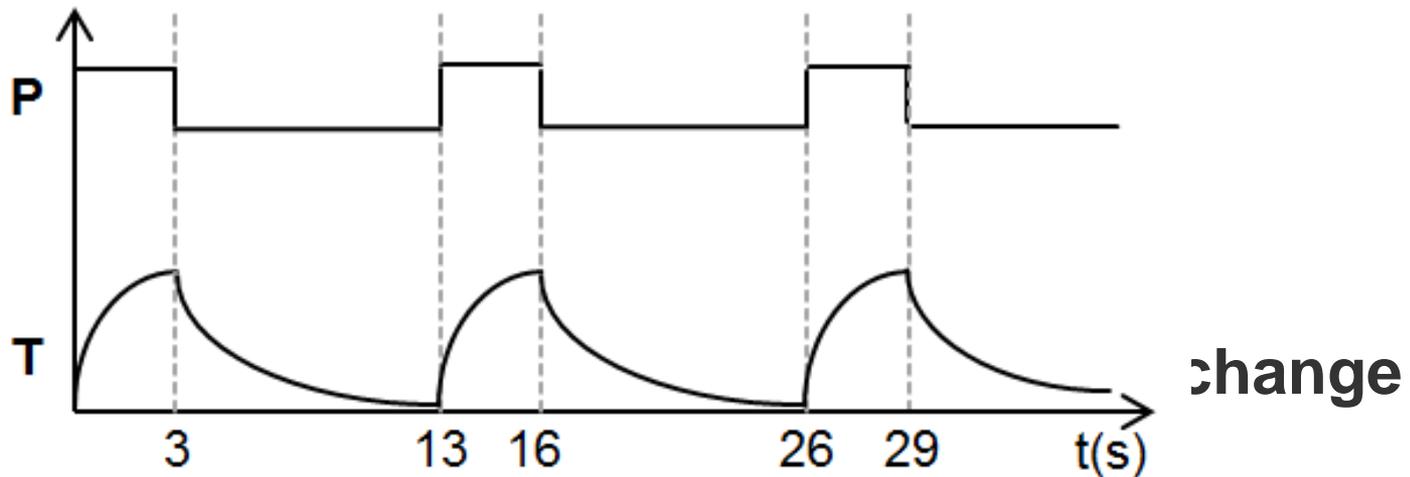
## How to Automatically Calibrate FloTHERM Package Models and Improve Thermal Design Reliability

15 March 2:00 p.m. - 3:00 p.m. (Fir)

# Powering conditions

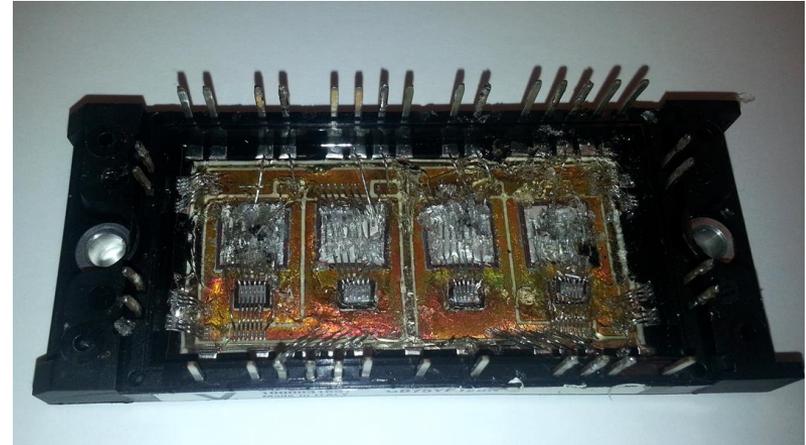
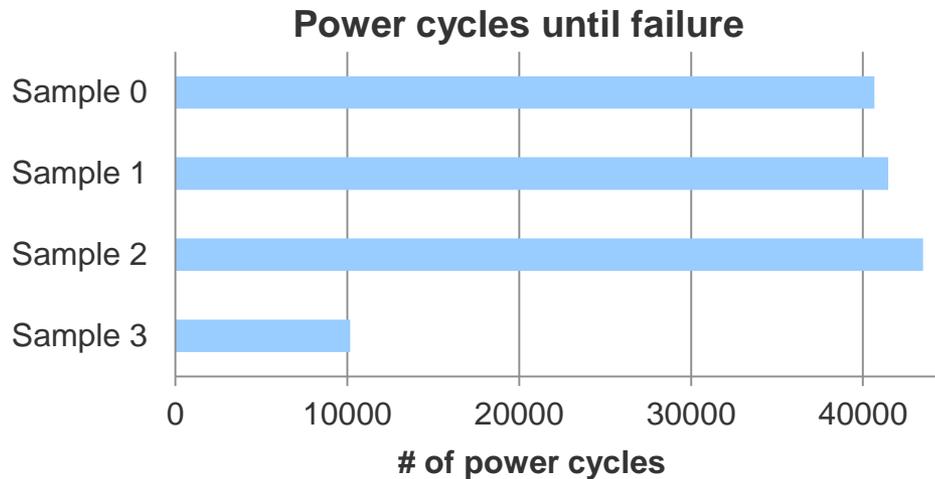
- Base plate temperature: 25° C
- Targeted junction temperature: 125° C
- Input power: 200W @ 25A

- Cor
- Trai



# Results of the reliability tests

- The power cycling was conducted until the total failure of the IGBT-s



## Failures identified by visual inspection

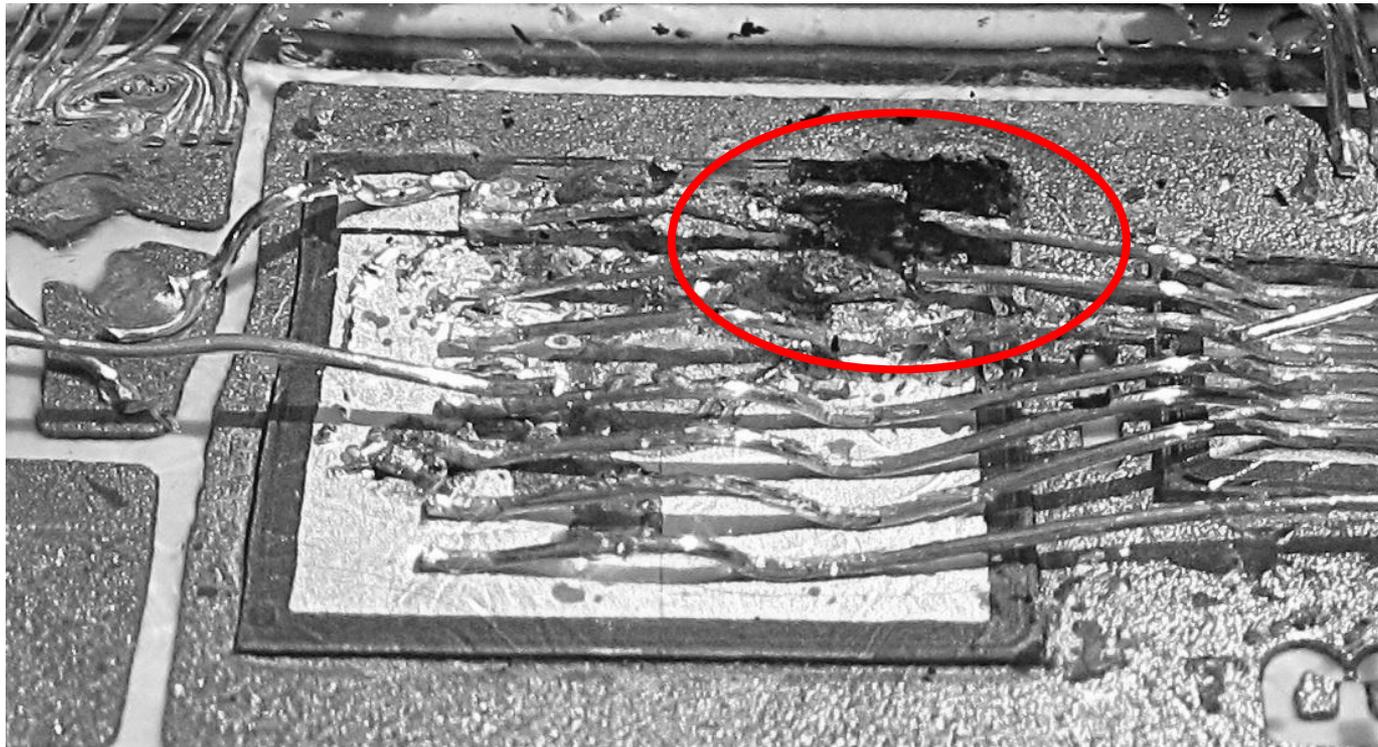
- Broken bond-wires and burnt areas on the chip surface
- In face all IGBT-s failed due to the overheating and damage of the gate-oxide

## Further failure analysis

- Structure functions obtained in situ during power cycling

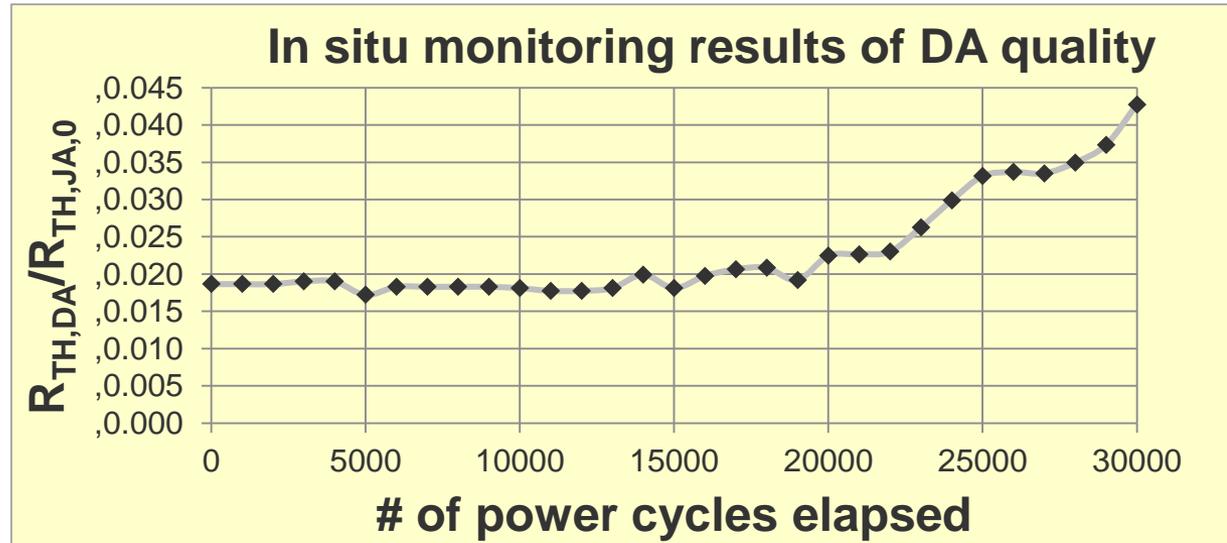
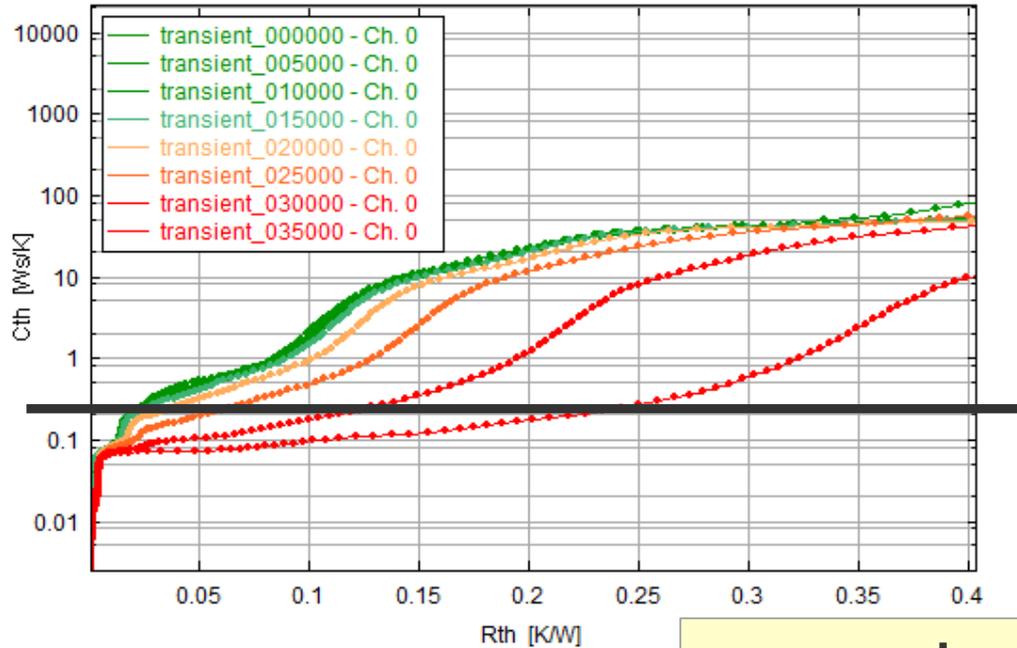
# Results of visual inspection

- Broken bond-wires and burnt areas on the chip surface
- In face all IGBT-s failed due to the overheating and damage of the gate-oxide

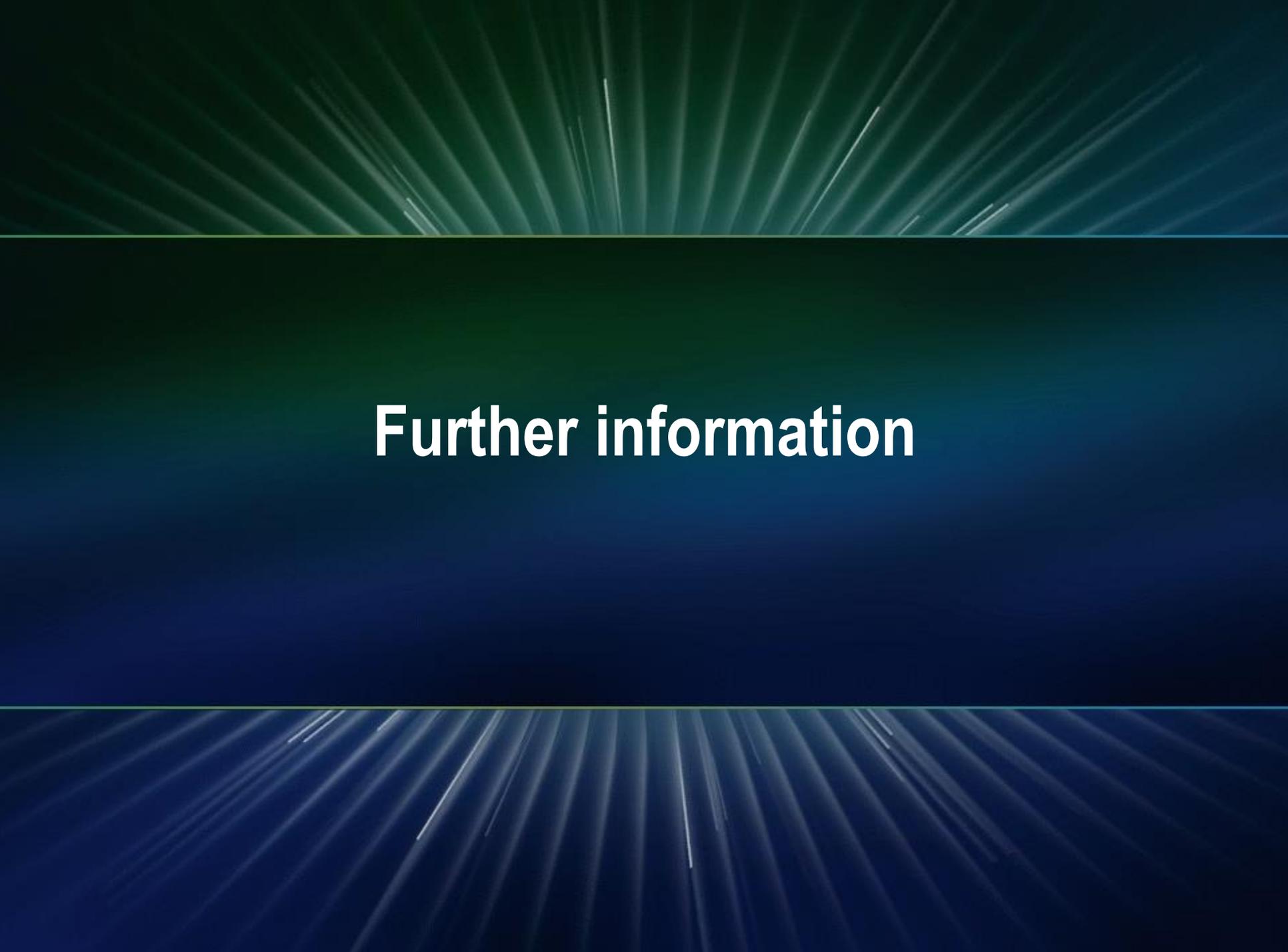


# Structure functions showing die-attach degradation

T3Ster Master: cumulative structure function(s)



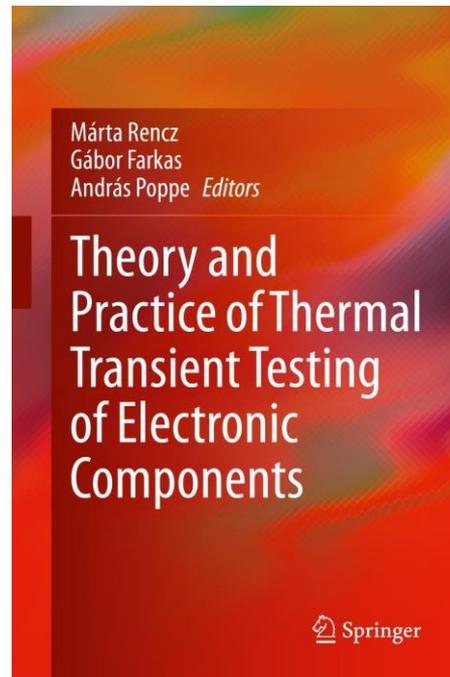




# Further information

# Recommended reading:

- For more details and references of the topics covered in this course please refer to  
**Theory and Practice of Thermal Transient Testing of Electronic Components** (eds.: Márta Rencz, Gábor Farkas, András Poppe)

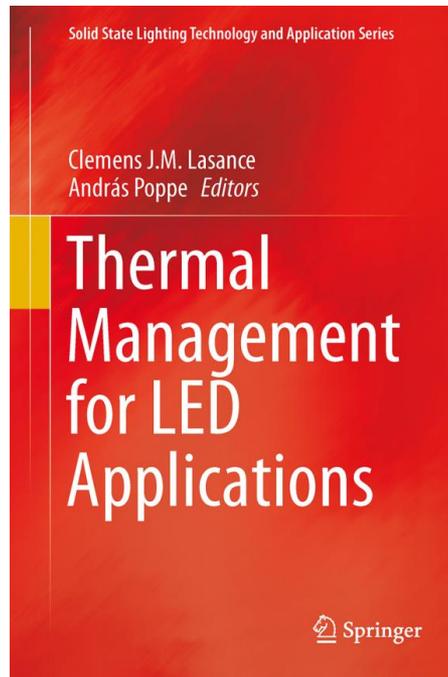


<https://link.springer.com/book/10.1007/978-3-030-86174-2>

# Recommended reading:

- Available from the bme.hu domain:

Chapter 4 Thermal Testing of LEDs (G. Farkas, A. Poppe)  
of a recent book C.J.M. Lasance – A. Poppe (eds): **Thermal  
Management for LED Applications**, September 2014, **Springer**



<http://www.springer.com/engineering/electronics/book/978-1-4614-5090-0>

**Not discussed**